# Light Emitting Diodes (LEDs) for General Illumination

# AN OIDA TECHNOLOGY ROADMAP UPDATE 2002

Full Edition Including Tutorial Source Material



Bridge illuminated by white LEDs in Duisburg, Germany

#### November 2002

Sponsored by:	Optoelectronics Industry Development Association (OIDA)
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Edited by:	Jeff Y. Tsao, Sandia National Laboratories



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## PREFACE

This volume is an update to the OIDA technology roadmap on Light Emitting Diodes (LEDs) for General Illumination, issued in March 2001. The original roadmap, produced in collaboration with the Department of Energy (DOE-BTS), responded to a major opportunity to accelerate the development and commercialization of solid state light sources for general illumination. The new light sources offer savings in energy consumption, reduced pollution, substantial savings to the consumers, and the creation of a new lighting industry.

Both industry and government have responded to this enticing challenge. Both Houses of Congress passed an authorization bill, called the Next Generation Lighting Initiative, to generate an industry-government partnership for the acceleration of this technology. It was in preparation for this national initiative that DOE and OIDA decided to update the first roadmap.

Since the ultimate implementation of solid-state lighting also requires the development of new lighting fixtures and powering, a first look at lighting systems was also included in this update. The third participant in the roadmap update, the National Electrical Manufacturing Association (NEMA), covered that part.

We are indebted to Sandia National Laboratories who provided support in collecting the roadmap material and, in particular, to Jeff Tsao, who assembled and edited the final report. Dr. Tsao has done an exceptionally thorough job. He not only enumerated the decision points and recommendations for the future R&D activities, but also provided a comprehensive tutorial of all the building blocks that must be assembled to produce a solid state lighting system. As a result, this update containing the includes tutorial source material recommendations describing the various technical areas. Note that "challenges" and "recommendations" are interchangeable in the vocabulary of the report since all recommendations are aimed at meeting the challenges.

In assembling this comprehensive report, we had the benefit of contributions from all resources in solid-state lighting: industry, academia and national laboratories. We especially acknowledge contributions to the various chapters of this roadmap from:

Chuck Becker	Kate Bogart	John Bumgarner	Chips Chipalkatti
Weng Chow	Mike Coltrin	George Craford	Randy Creighton
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## **EXECUTIVE SUMMARY**

#### **SSL-LEDs and their Benefits**

Solid-State Lighting through Light-Emitting Diodes (SSL-LEDs) is the use of solid-state, inorganic semiconductor light-emitting diodes to produce white light for illumination. Like inorganic semiconductor transistors, which displaced vacuum tubes for computation, SSL-LED is a disruptive technology that has the potential to displace vacuum or gas tubes (like those used in traditional incandescent or fluorescent lamps) for lighting.

The enhanced efficiency and versatility associated with SSL-LEDs over traditional vacuum or gas tubes will enable:

- Substantial reductions in electrical energy consumption
- Substantial reductions in carbon-related pollution
- Substantial improvement in the overall human visual experience
- Creation of new semiconductor technologies with spin-off benefit for national security and economic competitiveness
- Creation of a new optoelectronics-based lighting industry, with many new, high-quality jobs
- Substantial savings for the consumer

#### The Opportunity for the Nation

The science and technology base underlying semiconductor optoelectronics has advanced rapidly over the past decade, and SSL-LEDs have already begun to penetrate color, and some specialty white, lighting markets.

Nevertheless, tremendous challenges must be met for SSL-LEDs to achieve its potential for general white lighting. The opportunity for the United States is to create and execute a Government-sponsored Industry-driven initiative that harnesses our National Laboratories and Universities, and that accelerates the development of the science and technology base of SSL-LEDs. In doing so, penetration of SSL-LEDs into general white lighting will also be accelerated, along with its tremendous benefits.

#### **SSL-LED Roadmaps**

The first SSL-LED I Roadmap,<sup>1</sup> completed in March 2001, had as its objective the development of an industry-national-laboratory-university consensus on:

- The major commercial and military applications of SSL-LEDs, and their long-term benefits
- The technology performance targets needed to support these applications
- Some of the research challenges that would need to be met to achieve those target performances

This updated SSL-LED Roadmap, completed in August 2002, has as its objectives:

- An overall updating of the first roadmap
- A more quantitative enumeration of key SSL-LED technology attributes and targets
- A more detailed enumeration and prioritization of the research challenges that will be faced in meeting these technology targets, possible approaches to surmounting them, and some of the key decisions that must be made between competing approaches
- A first look at the lighting systems issues necessary to achieve mass penetration of SSL-LEDs into the marketplace

We note that this Roadmap focuses on general white lighting. Along the way, many niche intermediate lighting applications are already being, and will surely continue to be, developed. These "practice" applications are crucial for improving the performance and reducing the cost of solidstate lighting. However, because these applications are believed to be economically self-sustaining and do not involve the high simultaneous risk and reward associated with general white lighting, we do not include them in this Roadmap.

#### **Technology Targets**

The technology performance targets of SSL-LED II, assuming a major government-sponsored industry-driven

<sup>&</sup>lt;sup>1</sup> Eric D. Jones, "Light Emitting Diodes (LEDs) for General Illumination: An OIDA Technology Roadmap" (Optoelectronics Industry Development Association, Mar, 2001).

Year	2002	2007	2012	2020
Luminous	25	75	150	200
Efficacy				
(lm/W)				
Lifetime	20	>20	>100	>100
(khr)				
Flux	25	200	1,000	1,500
(lm/lamp)				
Lumens	200	20	<5	<2
Cost (\$/klm)				
Color	75	80	>80	>80
Rendering				
Index (CRI)				
Lighting	Low-flux	Incande-	Fluore-	All
Markets		scent	scent	
Penetrated				

initiative with full participation from Industry, National Laboratories and Universities, are:

Meeting these technology performance targets would enable penetration of incandescent lighting by 2007 and of fluorescent lighting by 2012, with massive displacement of incandescent lighting by 2012 and of fluorescent lighting by 2020. In addition, not listed in the table but equally important will be the development of new science and technology with significant spin-off national security and economic benefits, and of a new lighting culture that takes advantage of unique attributes of SSL-LEDs such as energy-efficiency, compactness, reliability and digital controllability ("smart" lights).

#### **The Research Areas and Challenges**

The technology targets listed above are believed achievable. The efficiency targets, even the year 2020 target of 200lm/W, are consistent with fundamental physics; and the equivalent electrical-to-optical power-conversion efficiency of 50% has already been achieved in similar technologies at non-visible wavelengths. The cost targets, even the year 2020 target of <2%/klm, are consistent with comparisons to more-mature high-volume semiconductor technologies.

Nevertheless, the targets are challenging: we are currently 6x away from the year 2012 efficiency target and >40x away from the year 2012 cost target. In order to achieve these targets, significant challenges must be overcome in three building-block technologies:

- 1. Substrates, Buffers and Epitaxy
- 2. Physics, Processing and Devices
- **3**. Lamps, Luminaires and Systems

These building-block technologies range from fabrication of high-efficiency, low-cost semiconductor materials and epistructures; to the physics, design and processing of high-efficiency optoelectronic devices; to the packaging, white-light conversion, fixturing, and system issues associated with lighting for the 21<sup>st</sup> century and beyond.

We note that of these areas, lighting systems is the least mature. Lighting systems follow (and are pushed by) the development of the underlying technology; but also they must respond to (and are pulled by) market needs that can be difficult to anticipate. Nevertheless, lighting systems are the ultimate vehicle for implementing solid-state lighting, so we include a first look, however imprecise and incomplete, at their issues here.

#### **Organization of Roadmap**

The remainder of this Roadmap is organized as follows.

The first Chapter, "Roadmap Recommendations," contains a discussion of our overall SSL-LED lighting technology targets, as well as our lamp (chip and phosphor) technology sub targets. This Chapter also summarizes the key technology Decision points, key Challenges, and Possible Approaches for overcoming those Challenges.

The next four Chapters 0-4 contain a more detailed discussion of the building block technologies that underlie SSL-LEDs. Each building block technology is divided into Challenge Areas, within each of which we give: background material, a quantitative statement of the Challenge, and background material on Possible Approaches for overcoming the Challenge.

The last Chapter is an Appendix containing the processes and resources used in putting together this Roadmap.

## **R ROADMAP RECOMMENDATIONS**

TECHNOLOGY	SSL-LED 2002	SSL-LED 2007	SSL-LED 2012	SSL-LED 2020	Incandescent	Fluorescent
Luminous Efficacy (lm/W)	25	75	150	200	16	85
Lifetime (khr)	20	>20	>100	>100	1	10
Flux (lm/lamp)	25	200	1,000	1,500	1,200	3,400
Input Power (W/lamp)	1	2.7	6.7	7.5	75	40
Lumens Cost (\$/klm)	200	20	<5	<2	0.4	1.5
Lamp Cost (\$/lamp)	5	4	<5	<3	0.5	5
Color Rendering Index (CRI)	75	80	>80	>80	95	75
Lighting Markets Penetrated	Low-flux	Incandescent	Fluorescent	All		

Table 1. SSL-LED Lamp Targets. Note that metrics for color quality appropriate for SSL-LEDs have not yet been developed; hence the CRI values should be thought of as interim targets. The lumens and lamp costs are "street" costs, roughly 2x higher than OEM costs.

In this Chapter, we summarize the recommendations of this Roadmap.

First, we discuss the key attributes (luminous efficacy, lifetime, flux/package, purchase and ownership cost, color temperature and rendering) that are common to all lighting technologies, and discuss targets for the evolution of these attributes for SSL-LED technology over the next 18 years.

Second, we break these key attributes apart into "derivative" attributes (chip input power density and cost per unit area, and chip and phosphor wavelengths and efficiencies) for the semiconductor chips, phosphors, and packaging that SSL-LED technology will be based on, and discuss targets for the evolution of these attributes over the next 18 years.

Third, we summarize the building blocks, or "Challenge Areas", and organize them according to their risk and reward relative to SSL-LED technology.

Fourth, we summarize the major technology Decision Points that are likely to be faced as SSL-LED technology evolves.

Fifth, we summarize the quantitative statements of the Challenges and Possible Approaches associated with the various Challenge Area.

## **R-1 Lamp Targets**

Because solid-state lighting is a new technology, it will bring with it a number of new system-level attributes. These include programmability, small volume, ruggedness and immunity to vibration, compatibility with environmental extremes (cold and heat), and an enhanced efficiency in directed illumination. Ultimately, these system-level attributes are expected to enhance considerably the competitiveness of solid-state lighting relative to traditional incandescent and fluorescent lighting technology.<sup>2</sup>

At this stage, however, it is difficult to assess quantitatively the impact of these system-level attributes, and it is difficult to quantify targets for their evolution. Hence, in this Roadmap we focus on lamp-level attributes that are universal to all lighting technologies: luminous efficacy, lifetime, flux/lamp, purchase cost and colorrendering index. A summary of targets for these attributes is shown in Table 1. The targets for 2007 are intended to enable SSL-LED technology to compete with incandescent lamps; the targets for 2012 are intended to enable SSL-LED technology to compete with fluorescent lamps.

The general intent is that these targets would be met simultaneously, in a single SSL-LED lamp. However, the targets are quite aggressive, and the end-use markets in their infancy, so we leave open at this point the question of whether only subsets of the targets will be met in any single SSL-LED lamp, depending on its intended white lighting application.

<sup>&</sup>lt;sup>2</sup> For example, although the luminous efficacy of a 15W fluorescent lamp may nominally be 60 lm/W, after fixturing it may only be 35 lm/W, and after accounting for wasted undirected illumination, may only be 30 lm/W. A solid-state lamp is likely to suffer fewer of these system-level inefficiencies. Chips Chipalkatti, "LED Systems for Lighting: Where the Rubber Hits the Road," OIDA Solid-State Lighting Workshop (Albuquerque, 30 May 2002).



Figure 1. The luminous efficacy,  $K(\lambda)$ , of monochromatic radiation at wavelength  $\lambda$ . Also shown are the state-of-the-art luminous efficacies of monochromatic LEDs (data points), and of various white light technologies (arrows at the right). Courtesy of M.G. Craford, LumiLeds.

In this Section, we discuss each of these target attributes, in the order listed. We also discuss two additional "derived" attributes. The first is ownership cost, which depends on efficiency, lifetime and purchase cost. The second is the correlated color temperature (CCT), which, together with the color-rendering index (CRI), defines the overall color quality of the light.<sup>3</sup> Ownership cost and overall color quality are arguably the most important attributes of lighting technologies.

#### **R-1.1 Luminous Efficacy**

A primary attribute of a lighting source is its luminous efficacy (Im/W): the efficiency of the conversion from electrical power (W) to optical power (W), combined with the efficiency of the conversion from optical power (W) to the luminous flux (lumen = Im) sensed by the human eye within its spectral responsivity range.

The luminous efficacy of monochromatic radiation  $K(\lambda)$ at wavelength  $\lambda$  is shown in Figure 1, and is defined by  $K(\lambda) = K_m \times V(\lambda)$ , where  $K_m = 683 \text{ lm/W}$ , and  $V(\lambda)$  is the CIE-defined wavelength-dependent spectral luminous efficiency of photopic vision.  $K(\lambda)$  represents the theoretical maximum light source efficacy at a given wavelength. Monochromatic light at 555 nm, at which the human photopic vision sensitivity peaks, has a maximum luminous efficacy of 683 lm/W; monochromatic light at 450 nm has a maximum luminous efficacy of only 26 lm/W.

The luminous efficacy of polychromatic radiation is a convolution of its spectral power distribution  $S(\lambda)$  with the luminous efficacy of radiation  $K(\lambda)$ :

$$K[lm/W] = \frac{K_m \int S(\lambda) V(\lambda) d\lambda}{\int S(\lambda) d\lambda}$$
 Eq 2

Hence, in order to produce a high luminous efficacy, the spectral power distribution  $S(\lambda)$  of the light source should overlap as best as possible the luminous efficiency of photopic vision  $V(\lambda)$ .

Indeed, the difference between the luminous efficacies of broadband and narrowband emitters is described by Eq 2. The huge disadvantage of a broadband blackbody light emitter is that it emits light at wavelengths where the luminous efficiency of photopic vision is near zero. The huge advantage of a narrowband light emitter is that it can be tailored to emit light at wavelengths where the luminous efficiency of photopic vision is high.

The past-four-decade evolution of total luminous efficacy of various monochromatic solid-state lighting sources is illustrated in Figure 2. Progress has been nothing short of spectacular. Recently, LumiLeds and Philips announced a 610 nm (orange/red) LED with a luminous efficacy of 100lm/W; and LumiLeds has reported green InGaN-based LEDs having luminous efficacies in the range 50 lm/W.

Progress of this sort cannot continue indefinitely, since luminous efficacies are limited by  $K(\lambda)$  for monochromatic light and by Eq 2 for white light. Nevertheless, we anticipate significant continued progress. Currently, luminous efficacies for white light LEDs are of the order 25 lm/W. Our technology targets are to achieve 75 lm/W by 2007, 150 lm/W by 2012, and 200 lm/W by 2020. For comparison, the luminous efficacies of incandescent and fluorescent lights are 16 lm/W and 85 lm/W, respectively, which are roughly 10x and 2x lower than our 2012 targets for SSL-LEDs.

<sup>&</sup>lt;sup>3</sup> A general reference on color technology is: Roy S. Berns, Billmeyer and Saltzman's Principles of Color Technology,

Third Edition (John Wiley and Sons, Inc., New York, 2000).



Figure 2. The evolution of total efficacy of solid-state lighting technologies. Also shown are typical efficacies for traditional incandescent and fluorescent technologies. [Courtesy of George Craford, LumiLeds Lighting.]

#### **R-1.2 Lifetime**

A second primary attribute of a lighting source is lamp lifetime.

This can be (and has been) defined in different ways, depending on the light source. In the Incandescent age of Edison, lifetime was defined as the point at which 50% of the bulbs fail. For SSL-LEDs, lifetime is sometimes a similar mean-time-before-failure (MTBF) number, but now is more commonly taken to be the 50% lumen depreciation level.

No matter how it is measured, lifetimes for SSL-LEDs are generally long – a significant factor in the penetration of LEDs into signaling applications (traffic lights, displays, automotive) with high labor costs for replacement and high safety-consequence costs for failure.

Of course, the replacement and safety costs vary greatly with application, and we expect there to be a spectrum of needs for various lifetimes. For the dominant use of white light, industrial and office lighting, a lifetime of 20,000 hrs can already be considered very long. In a typical office, where a lamp might be on 60 hours per week, 50 weeks per year, 20,000 hrs would correspond to a lifetime of about 7 years. However, in a heavy-use factory running "24x7," 20,000 hrs would correspond to a lifetime of only about 2.3 years.

Our technology targets are to achieve lifetimes of >20,000 hrs by 2007, and >100,000 hrs by 2012 and

beyond. We target >100,000 hrs so that solid-state lighting will satisfy even the most demanding applications; as discussed above >20,000 should be more than sufficient for mainstream applications.

#### R-1.3 Flux/Lamp

A third attribute of a lighting source is the total light output produced per bulb, or lumens per lamp.

Figure 3 shows the substantial progress that has been made in the past three decades in increasing the luminous flux obtained from monochromatic red LED lamps.

Typical conventional LED indicator lamps are (0.25mm)<sup>2</sup> square, are mounted in packages that can handle about 0.1 W of input power, and emit about 1-2 lumens. Larger chips, up to about 1 mm<sup>2</sup> in size, packaged to handle several watts, are now available with outputs of tens of lumens and hundreds of milliwatts of optical power. Such packages are increasingly used for red, amber, and green traffic signaling lights.

Even larger chips, emitting hundreds or even thousands of lumens at tens of watts input power, will be required to compete with traditional incandescent and fluorescent technologies. A traditional 75 W incandescent bulb, with a luminous efficacy of 16 lm/W, puts out approximately 1.2 klm; a traditional tube-type 40 W fluorescent bulb, with a luminous efficacy of 85 lm/W, puts out approximately 3.4 klm. These outputs are yet another two orders beyond those of currently available single-chip SSL-LEDs.

Our technology targets are to achieve fluxes/package of



Figure 3. The evolution of lm/package and cost/lm for red LEDs. [Courtesy of Roland Haitz, Agilent Technologies.]

200 lm/lamp by 2007, 1,000 lm/lamp by 2012, and 1,500 lm/lamp by 2020.

Note that the input power to the lamp is the flux/lamp divided by the luminous efficacy, so these targets can be deduced to be 2.7 W/lamp by 2007, 6.7 W/lamp by 2012, and 7.5 W/lamp by 2020.

#### **R-1.4 Purchase Cost**

A fourth attribute of a lighting source is OEM manufacturing cost (for the supplier), or, with suitable mark-up, street purchase cost (for the consumer), in units of \$/klm.

The current street price of white LEDs is approximately \$200/klm. As discussed in the next Subsection 0.3.5, in order for the ownership cost of solid-state lighting to become competitive with that of traditional fluorescent lighting, the purchase cost must be roughly \$5/klm. Hence, our technology targets are to achieve costs per lumen of \$20/klm by 2007, <\$5/klm by 2012, and <\$2/klm by 2020.

Note that the cost of lighting per lamp is the cost per lumen times the lumens per lamp. Hence, the target street purchase cost per lamp can be deduced to be <\$5/lamp by 2012. The OEM manufacturing cost of a lamp will be less than this, by roughly 2x.

Note also that the cost per klm must decrease by a factor 40x from the current cost per klm. Clearly, this decrease represents a tremendous challenge. We know some of the ways costs can decrease over time. One way might be through increases in power-conversion efficiency (perhaps 6x). We note that it is mainly through such increases in power-conversion efficiency that the cost of red LEDs, illustrated in Figure 3, has fallen so fast over the years -- about 10x per decade. Another way might be through increases in input power density to, and improved thermal management of, the chip (perhaps another 5x); and yet another way might be through decreases in the manufacturing cost of the chip itself (perhaps another 1.5x). The product of these factors is approximately 40x.

#### **R-1.5 Ownership Cost**

A fifth attribute of any lighting source, one that represents a combination of the previously discussed attributes, is "ownership" cost.

Ownership cost can be viewed as a single figure-of-merit for the economic case for SSL-LEDs. It is the sum of two costs: operating and capital:<sup>4</sup>

$$Cost_{Ownership} = Cost_{Operating} + Cost_{Capital}$$
 Eq 3

The operating cost is the ratio between the cost of the fuel and the luminous efficacy (the efficiency with which the fuel is burned to create usable light). This cost is straightforward to calculate, given an end-user price of electricity, and the luminous efficacies discussed previously. Here, we assume an end-user electricity cost of 10 ¢ / (kW-hr).

$$Cost Operating = \frac{Electricit \ yCost \ (\notin /[kW \cdot hr])}{Lu \ min \ ousEfficac \ y(lm/W)} \qquad Eq 4$$

The capital cost is the cost to purchase the bulb or lamp, plus the labor cost to replace the bulb or lamp when it burns out, both amortized over its lifetime.<sup>5</sup> For purchase cost, we use the costs discussed above. However, for lifetime, we assume a cut-off at 20,000 hrs – in other words, once a lamp has a lifetime greater than 20,000 hrs, it may, for most applications, be considered infinite – the fixture itself, or some other aspect of the lighting system or infrastructure, will need replacing before the lamp will. For the labor cost to replace the lamp, we use \$1 per replacement, divided by the flux/lamp (lm/lamp) numbers also given above. This labor cost assumes a labor rate of \$15/hr and 4 minutes per lamp change.

$$Cost_{Capital} = \frac{Cost_{Pur}(\frac{\phi}{klm}) + Cost_{Lab}(\frac{\phi}{klm})}{Lifetime(hr)} \xrightarrow{Eq 5}$$

The operating and purchase costs associated with traditional lighting technologies, as well as the targets for SSL-LEDs discussed above, are illustrated graphically and tabularly in Figure 4.

<sup>&</sup>lt;sup>4</sup> This Equation is similar to that given in Equation 25-1 of M. S. Rea, Editor, The IESNA Lighting Handbook, 9th Edition (Illumination Engineering Society of North America, New York, 2000).

<sup>&</sup>lt;sup>5</sup> In principle, this cost also includes the disposal cost of the bulb or lamp. This cost can be substantial for fluorescent lamps containing toxic elements such as mercury. Here, we neglect such costs, though it should be included in future Roadmaps.



Figure 4. Purchase and Operating Costs associated with traditional lamps and SSL-LED target lamps. The sum of the two costs is the Ownership cost. The green curve is an iso-ownership cost curve for incandescent lighting, the purple curve is an iso-ownership cost curve for fluorescent lighting.

For incandescent and fluorescent lamps, ownership costs are determined mainly by operating costs and, for a common price of electricity, by luminous efficacies. Since fluorescent lamps are roughly 5x more efficient than incandescent lamps, their ownership cost, and "isoownership-cost" contour, is also roughly 5x less.

For solid-state lighting, the opposite is true: ownership costs are currently determined mainly by capital cost. Hence, a major challenge for SSL-LEDs will be to reduce this capital cost.

If the SSL-LED targets on both purchase and operating costs are met, however, one can see from Figure 4 that the ownership cost will decrease dramatically. Currently, SSL-LED ownership cost is 2x that of incandescent and 10x that of fluorescent life-ownership costs. By 2007, the ownership cost will be lower than incandescent, but still higher than fluorescent, ownership costs. By 2012, the ownership cost will be comparable to, and somewhat lower than, fluorescent ownership costs. And, by 2020, the life-



Figure 5. Estimated ownership costs of light, in 1992 dollars. Data for Fire and Incandescence for operating cost are from the work of W. Nordhaus,<sup>6</sup> to which estimates of capital cost have been added. Data for Fluorescence are from our estimates. Data for SSL-LEDs are the targets of this Roadmap.

ownership cost will be about half of that of fluorescent lamps.

To put these targets in a larger historical perspective, Figure 5 shows estimated ownership costs of light for the past 200 years. This trend represents a tenfold decrease in cost every 50-60 years. Also shown on the plot are the SSL-LED II targets, illustrating that our year 2007, 2012 and 2020 targets are consistent with this trend.

Note, though, that this trend must eventually run its course. When the capital cost of SSL-LEDs becomes so low that ownership costs are dominated by operating costs, and once luminous efficacies approach 100%, there is little room left for improvement. Further decreases in ownership cost will need to come from decreases in the cost of electricity, or in the efficiency with which light is utilized.

#### **R-1.6 Color Rendering**

The sixth attribute of a lighting source is its ability to faithfully render the colors of non-white objects that it illuminates. One quantitative measure of the faithfulness of color rendering is the color-rendering index (CRI).

<sup>&</sup>lt;sup>6</sup> William D. Nordhaus, "Do Real-Output and Real-Wage Measures Capture Reality? The History of Lighting Suggests Not," in Timothy F. Breshnahan and Robert J. Gordon, The Economics of New Goods (The University of Chicago Press, Chicago, 1997).

This measure is based on comparing the colors rendered by a given light source to the colors rendered by a "perfect" reference light source with the same CCT – daylight illumination for CCTs > 5,000 K and Planckian blackbody radiation for CCTs < 5,000 K. The comparison is made for a set of sample colors; the weighted average of the color rendering for each of these sample colors gives the General Color Rendering Index  $R_a$  for the light source.

With a maximum value of 100,  $R_a$  gives a scale that matches reasonably well with the visual impression of color rendering of illuminated scenes. For example, lamps having  $R_a$  greater than 80 are considered high quality and suitable for interior lighting, while lamps having  $R_a$  greater than 95 are suitable for visual inspection applications.

However,  $R_a$  is not a perfect measure of color rendering quality. It is based on the assumption that a continuous blackbody spectrum will render colors best. Because of the complexity of the human visual system, this may not always be true: removing certain wavelength regions (e.g., the 590 nm wavelength region in GE's recently developed "Reveal" incandescent lamps) may sometimes enhance the human visual system's perception of color.<sup>7</sup> Hence, it will be important to develop new measures for color quality, particularly for SSL-LEDs, which have the capability for tailored, selective filling of the wavelength spectrum.

In the meantime, as the CRI is the best currently accepted measure for color rendering, we use it as an "interim" metric for SSL-LEDs. Our technology targets are to achieve CRIs of 80, appropriate for medium-quality lighting, by 2007, and CRIs of >80, appropriate for high-quality lighting, by 2012 and beyond.

Note that there are strong trade-offs between good color rendering and luminous efficacy. The best color rendering is achieved by light of many wavelengths, while the highest luminous efficacy is achieved by light concentrated at the yellowish-green wavelength (555 nm) to which the human eye is most sensitive. At one extreme, a low pressure sodium lamp (having a light orange color, used in some highways and parking lots) has a luminous efficacy of about 200 lm/W, the highest among available discharge lamps, but colors are not very distinguishable: a red car would appear to be gray. At the other extreme, a xenon arc lamp, with a spectrum very similar to that of daylight and exhibiting excellent color rendering, has a luminous efficacy of only 30 lm/W.

To illustrate the trade-off between CRI and luminous efficacy, Figure 6 shows results of simulations in which, for



Figure 6. The envelope of maximum CRI and luminous efficacy for multi-LED white light sources with 30nm FWHM line widths and a 4870K color temperature. After A. Zukauskas, R. Vaicekauskas, F. Ivanauskas, R. Gaska, and M. S. Shur, "Optimization of white polychromatic semiconductor lamps," Applied Physics Letters 80 (2002) 234-6.

a fixed color temperature and fixed line widths, the wavelengths and power densities of 2-, 3-, 4- and 5-color white light sources were varied to deduce the envelope of maximum CRI and luminous efficacy. As the maximum luminous efficacy decreases, the maximum CRI increases, as the wavelengths "fill" and move farther to the extremes of the visible spectrum. Moreover, the envelope of maximum CRI and luminous efficacy depends strongly on the number of wavelengths. The maximum CRI begins to saturate at 3 for a 2-color source, at 85 for a 3-color source, at 95 for a 4-color source, and at 98 for a 5-color source.

Of course, the more colors, the more complex the lamp must be. Hence, it is likely that a tri-color source, which can achieve our target CRIs of 80 or greater, will provide the best balance between CRI, luminous efficacy, and lamp complexity.

Indeed, the situation for tri-color white light sources composed of broadband phosphors, or of a combination of narrowband LEDs and broadband phosphors, is even more favorable, and CRIs greater than 85 should be possible. Here, SSL-LED technology has advantages and disadvantages relative to fluorescence technology. On the one hand, their initial narrowband light is available in a much greater range of wavelengths, including the visible and the near UV, rather than limited to the available emissions from a gas. On the other hand, phosphors that can simultaneously be excited by these wavelengths while emitting at wavelengths optimal for good CRI have thus far been limited.

<sup>&</sup>lt;sup>7</sup> N. Narendran, "Solid-State Lighting Systems / Applications Issues," OIDA Solid-State Lighting Workshop (Albuquerque, May 30, 2002).



Figure 7. The CIE 1931 chromaticity diagram. The horseshoe boundary, called the spectrum locus, represents monochromatic light. The curve in the center, called the Planckian locus, represents white light. This curve traces the chromaticity coordinates of blackbodies at temperatures between 1,000 and 20,000K, which are perceived by the human visual system to be white. The vertices of the white triangle, at 460, 540 and 610nm, are the centers of the target wavelength ranges for tri-color solidstate white lighting. The interior of the triangle is the "gamut" of colors that would be available to such a light source.

#### **R-1.7 Color Temperature**

A seventh attribute of a lighting source is its apparent color when viewed directly, or when illuminating a perfectly white object.

This attribute can be quantified through use of chromaticity coordinates (x,y) on the CIE 1931 chromaticity diagram shown in Figure 7. These chromaticity coordinates apply both to monochromatic as well as white light.

The chromaticity coordinates of monochromatic light are represented by the boundary of the horseshoe (the "spectrum locus"). The chromaticity coordinates of mixtures of monochromatic light are intensity-weighted linear combinations of the chromaticity coordinates of the individual monochromatic lights. In other words, a mixture of two colors will produce a chromaticity coordinate falling on the line between their respective chromaticity coordinates.

The chromaticity coordinates of white light lie along the curved "Planckian" locus in the center of the diagram. The type of white on the Planckian locus is specified by the blackbody temperature in Kelvin and is called the color temperature. For example, mixing two equal-intensity LEDS with wavelengths at 485 nm (blue) and 583 nm (orange) will produce white color with a color temperature of about 4,000 K.

Strictly speaking, color temperature cannot be used for color coordinates (x,y) off the Planckian locus. In these cases, the correlated color temperature (CCT) is used. CCT is the temperature of the blackbody whose perceived color most resembles that of the light source in question. In principle, the CCT can be deduced by constructing "iso-CCT" lines, which intersect the Planckian locus. In practice, white light sources must lie very close to the Planckian locus, as the human eye is extremely sensitive to even small deviations.

Note that the CCT, though important, is not difficult to engineer. For a tri-color SSL-LED lighting source, the gamut of colors available, as indicated by the white triangle in Figure 7, is more than enough to specify virtually any desired CCT.

However, as with the CRI, there is a strong trade-off between CCT and luminous efficacy. This trade-off is illustrated in Figure 8 for a tri-color white light source. As CCT decreases, the proportion of red to blue light increases. Since, in order to achieve reasonable color rendering, the blue wavelength is so short that the eye is actually more sensitive to the red than to the blue, the overall luminous efficacy increases. At a color temperature of about 3900K, in between those for typical incandescent lamps and daylight, the maximum luminous efficacy is 400lm/W. This is the number we use throughout this Roadmap to represent the luminous efficacy of a 100%efficient tricolor solid-state lighting source.



Figure 8. Maximum luminous efficacy as a function of color temperature for a tricolor white light source with a CRI of 80 and FWHM line widths of 20nm. The table below lists the wavelengths of the three colors. Results were obtained using a spreadsheet-based simulator/solver: Yoshi Ohno, "White LED Simulator II" (NIST, Jul 11, 2002)..

Also listed in Figure 8 are the wavelengths of the tri-color white light source that maximizes luminous efficacy at fixed CRI=80 as a function of CCT, where the chromaticity coordinates are exactly on the Planckian locus. The wavelengths are similar to those of the tri-phosphor blends used in fluorescent lamps, and are of course near the "three-peaked" spectral response of the human visual system.

Hence, in this Roadmap, we assume target ranges of wavelengths centered at those colors: red (590-630 nm), green (520-560 nm), and blue (440-480 nm).

# **R-2 Chip and Phosphor Sub targets**

Note that the attributes and targets discussed in Section 0.3 apply to SSL-LED lamps as a whole. These lamps will be composed of pieces, each of which will have derivative attributes and targets that must be met in order for the

lamp targets to be met. In the three approaches to producing white light, the two major pieces will be: the semiconductor chip, which is the primary light "engine"; and the phosphor, which is the secondary light producer.

In this Section, we discuss the derivative attributes and targets of these chips and phosphors. Two of these, chip input power density and chip cost per unit area, are related and are discussed in Subsection R-2.1. Another two, chip and phosphor wavelengths and efficiencies, are also related and are discussed in Subsection R-2.2.

# R-2.1 Chip Input Power Density and Cost per Unit Area

In Subsection R-1.4 we discussed the targets for the retail cost, in \$, to purchase, after suitable mark-up, a packaged lamp which produces a certain number of lumens. This cost folds into it three costs: lamp "mark-up" from OEM to the street, packaging, and the semiconductor chip itself. Here, we assume the following approximate breakout of these costs: 50% for the mark-up, 25% for the packaging, and 25% for the chip.

Because of the importance of the semiconductor chip in the lamp, we focus special attention on its OEM cost. Typically, though, chip cost is in units of \$ per unit area or per cm<sup>2</sup>, rather than in \$ per klm. Hence, we need to derive \$/cm<sup>2</sup> chip targets from \$/klm lighting targets. This we can do, provided we know the chip percentage of the lamp cost discussed above, the target lamp luminous efficacies, in lm/W, and the input power density to the chip, in W/cm<sup>2</sup>. Then, OEM cost per cm<sup>2</sup> can be calculated from \$/cm<sup>2</sup> = 25% x \$/lm x lm/W x W/cm<sup>2</sup>.

Luminous efficacy has already been discussed; but input power density has not. The higher the input power density the more lumens can be created per cm<sup>2</sup> of semiconductor chip, and the more expensive per cm<sup>2</sup> the chip can be. The limits on input power density will depend on the ability to extract heat from the chip and phosphor, and on the ability of the chip and phosphor to maintain their conversion efficiencies at high operating temperatures.<sup>8</sup>

Two extreme scenarios can be imagined.

At one extreme, semiconductor material quality remains relatively low, causing internal radiative quantum efficiencies to roll over with increasing junction temperature. Then, allowable junction temperatures are low, and input power densities are limited. For example, the input current densities for GaN-based white LEDs on

<sup>&</sup>lt;sup>8</sup> Paul S. Martin, "Performance, Thermal, Cost and Reliability Challenges for Solid State Lighting," OIDA Solid-State Lighting Workshop (Albuquerque, May 30, 2002).

CHIP AND PHOSPHOR	SSL-	SSL-LED	SSL-	SSL-LED	AlGaInP/	GaInPA	Si	HP
POWER AND COST	LED	2007	LED	2020	GaAs HB-	s/Ge PV	CMOS	810nm
TARGET RANGES	2002		2012		LEDs			Lasers
Chip Temperature (C)	75	125-175	175-225	200-250				
Phosphor Temperature (C)	75	100-150	150-200	175-225				
Input Power Density (W/cm <sup>2</sup> )	100	300-600	500-750	600-1000				1,000
OEM Chip Cost (\$/cm <sup>2</sup> )	125	110-70	90-50	60-30	30	10	5	200
OEM Packaging Cost (\$/cm <sup>2</sup> )	125	110-70	90-50	60-30				
	1							

Table 2. Chip and phosphor power and cost target ranges.

the market now are limited to roughly 33 A/cm<sup>2</sup> which, with a voltage drop of about 3 V, gives an input power density of 100 W/cm<sup>2</sup>. If semiconductor material quality remains this low, and input power densities remain limited to this value, then the chips themselves must become very inexpensive.

At the other extreme, semiconductor material quality improves, enabling high internal radiative quantum efficiency to persist to junction temperatures as high as 200-300C. Combined with improved thermal management technology, this would enable much higher input power For example, the input current densities densities. (averaged over chip, not device, area) for GaAs-based highpower infrared lasers are of the order 0.5 kA/cm<sup>2</sup>; for a voltage drop of roughly 3V, the input power density can be inferred to be roughly 1.5 kW/cm<sup>2</sup>. Note that this comparison to GaN-based LEDs is somewhat tricky: GaN-based lasers in principle could operate at even higher junction temperatures than GaAs-based lasers, but the quality of GaN material is unlikely to be as high as that of GaAs. Nevertheless, it gives a reasonable estimate to an upper bound on allowable input power densities.

In this Roadmap, we assume a scenario intermediate between these two extremes, but biased towards improved semiconductor material quality, higher junction temperatures, higher input power densities, and higher chip costs. The reason is that improved semiconductor material quality is likely to be necessary to enable high luminous efficacy not just at higher temperatures, but also at any temperature.

Our target ranges for chip and phosphor temperature, and for chip input power densities and costs, are listed in Table 2. They are listed as ranges. The first number in the range is the minimum necessary to meet the lighting targets listed in Table 1. The second number in the range is an aggressive target that would enable the lighting targets to be exceeded, or would enable one of the other sub targets to be "missed," while still meeting the overall lighting targets.

For allowable chip temperatures, we assume steady increases from 75C in 2002, to 125-175C in 2007, to 175-

225C in 2012, and finally to 200-250C in 2020. For allowable phosphor temperatures, we assume steady increases from 75C in 2002, to 100-150C in 2007, to 150-200C in 2012, and finally to 175-225C in 2020.<sup>9</sup>

For allowable chip input power density, we assume that the combination of improvements in chip and phosphor temperatures and in thermal management technology will enable a steady increase in input power density from 100 W/cm<sup>2</sup> in 2002, to 300-600 W/cm<sup>2</sup> in 2007, to 500-750 W/cm<sup>2</sup> in 2012, and finally to 600-1000 W/cm<sup>2</sup> in 2020.

We note that whether these increases in chip input power densities are achieved mostly through increases in chip and phosphor temperatures or through improvements in thermal-management technology is not clear. On the one hand, if allowable chip and phosphor operating temperatures remain low, then thermal management technology will need to improve dramatically. On the other hand, if thermal management technology proves too costly, than the burden will be on increasing the allowable chip and phosphor operating temperatures.

Finally, using these targets for allowable input power density, we can deduce targets for OEM chip cost per cm<sup>2</sup>: from  $125 \cm^2$  in 2002 to 110-70  $\cm^2$  by 2007, to 90-50  $\cm^2$  by 2012, and to 60-30  $\cm^2$  by 2020. Note that from these chip cost targets one can estimate (very) approximate allowable costs for the various "wafer level" fabrication steps: 20% for substrates, 40% for epi and 40% for wafer processing.

<sup>&</sup>lt;sup>9</sup> Note that the targets for phosphor temperature are 25C lower than the targets for chip temperature. On the one hand, if the phosphor is applied directly to the chip, and is not separately heat sunk, then the phosphor temperature will be very close to that of the chip. On the other hand, if the phosphor is partially thermally isolated from the chip, and is separately heat sunk, than its temperature can be significantly lower. Because finding phosphors with high quantum efficiencies and long lives at high temperatures is believed to be extremely difficult, we assume here that some degree of thermal management will be required to keep the phosphor somewhat cooler than the chip.

CHIP AND PHOSPHOR $\lambda$ AND				
EFFICIENCY TARGETS	SSL-LED 2002	SSL-LED 2007	SSL-LED 2012	SSL-LED 2020
Wavelength Conversion Approach				
LED $\lambda s$ (nm)		UV(370-410)	UV(370-410)	UV(370-410)
		R(590-630)	R(590-630)	R(590-630)
		G(520-560)	G(520-560)	G(520-560)
Phosphor $\lambda$ s (nm)		B(440-480)	B(440-480)	B(440-480)
Stokes Efficiency		0.73	0.73	0.73
Phosphor Quantum Efficiency		0.75	0.85	0.95
Package Efficiency		0.75	0.90	0.95
Chip Efficiency		0.46	0.67	0.76
Color Mixing Approach				
		R(590-630)	R(590-630)	R(590-630)
		G(520-560)	G(520-560)	G(520-560)
LED $\lambda s$ (nm)		B(440-480)	B(440-480)	B(440-480)
Phosphor $\lambda s$ (nm)		, , ,		, , , , , , , , , , , , , , , , , , , ,
Stokes Efficiency				
Phosphor Quantum Efficiency				
Package Efficiency		0.75	0.90	0.95
Chip Efficiency		0.25	0.42	0.53
Hybrid Approach				
LED $\lambda s$ (nm)	B(460)	B(440-480)	B(440-480)	B(440-480)
	Y(580)	R(590-630)	R(590-630)	R(590-630)
Phosphor $\lambda$ s (nm)		G(520-560)	G(520-560)	G(520-560)
Stokes Efficiency	0.88	0.86	0.86	0.86
Phosphor Quantum Efficiency	0.60	0.70	0.80	0.90
Package Efficiency	0.50	0.75	0.90	0.95
Chip Efficiency	0.24	0.42	0.61	0.68

Table 3. Chip and phosphor wavelength and efficiency targets.

We also list in Table 2 some representative OEM costs for similar but more mature technologies. The cost of AlGaInP/GaAs high-brightness LEDs chips is roughly \$30/cm<sup>2</sup>. The cost of triple-junction GaInPAs/Ge space solar cells is roughly \$10/cm<sup>2.10</sup> The cost of Si CMOS is roughly \$5/cm<sup>2.11</sup> Hence, for these three relatively mature semiconductor technologies, purchase costs are much lower than our targets for SSL-LEDs. This indicates that our targets are reasonable, and that indeed there may be "headroom" for improvement beyond our targets.

Moreover, even a relatively complex technology, highpower 810 nm GaAs-based lasers, has costs that are in the \$200/cm<sup>2</sup> range. It is not clear how these costs might translate to high-power visible/UV GaN-based lasers. However, the costs are already within 3-5x of our targets, even without the high manufacturing volumes and associated cost reductions that penetration into the general lighting markets would enable. And, costs continue to decline<sup>12</sup> in response to demand for high-power diode lasers for materials processing.

#### **R-2.2 Chip and Phosphor Wavelengths and Efficiencies**

In Section R-1, we discussed the targets for luminous efficacy of the fixtured lamp. This luminous efficacy folds into it five separate efficiencies:

1. The efficiency of the semiconductor chip itself in converting electrical power into primary optical power.

<sup>&</sup>lt;sup>10</sup> James Gee, "SSL 2020 Cost Targets" (Sandia National Labs, 2001, unpublished).

<sup>&</sup>lt;sup>11</sup> Jason Blackwell, "Foundry wafer prices: Still hanging tough, but for how long?," Semiconductor Business News (Nov 6, 2001) .

<sup>&</sup>lt;sup>12</sup> Roy Szweda, "NOVALAS (Innovative Laser Systems based on High-Power Diode Lasers) in its final round," III-Vs Review 15 (2002) 36-39.

- 2. The sensitivity of the human visual system to the color(s) of the primary light generated by the semiconductor chip, or to the color(s) of the secondary light generated by the phosphor, or both.
- 3. The energy lost in converting a blue or UV photon to a longer wavelength photon (the Stokes shift).
- 4. The Stokes conversion efficiency due to the different energies of the photons absorbed and emitted by the phosphor.
- 5. The overall package efficiency, currently between 40-60% due to light absorption by internal package components such as the chip, lead frame or sub mount.

If the last four efficiency targets are known (or estimated), and if the overall lamp luminous efficacy target is known, then one can deduce what the first efficiency target, the power conversion efficiency of the semiconductor chip, needs to be.

For the fifth efficiency, we assume that it will be approximately the same for the three approaches – for the color-mixing approach, difficulties in combining separate sources of light are offset, for the wavelength conversion and hybrid approaches, by difficulties in reducing phosphor scatter. Our target efficiencies are 0.75 by 2007, 0.9 by 2012, and 0.95 by 2020.

For the middle three efficiencies, we need to make assumptions about wavelengths and numbers of wavelengths. Assuming a tri-color source with the target wavelengths discussed in the previous Section, we can deduce derivative targets for phosphor quantum efficiency, Stokes conversion efficiency, and for the opticalengineering efficiency associated with the lamp packaging. These three efficiencies will depend on the approach to white lighting that is taken – wavelength conversion, color mixing, or a hybrid approach.

The phosphor quantum efficiency is likely to be somewhat better for the wavelength conversion approach, since there is a wider range of available phosphors that absorb in the UV. Hence, for the wavelength conversion approach, we assume that phosphor quantum efficiencies will steadily increase from 0.75 in 2007 to 0.85 in 2012 to 0.95 in 2020. For the hybrid approach, which downconverts blue rather than UV light, we assume that phosphor quantum efficiencies will increase more slowly, from 0.7 in 2007 to 0.8 in 2012 to 0.9 in 2020. For the color-mixing approach, of course, there is no phosphor and hence no phosphor-related losses.

The phosphor Stokes conversion efficiency, in contrast, will be lowest for the wavelength-conversion approach, since there is a larger energy difference between the UV and red/green/blue light than between blue and red/green light. Here, we calculate a Stokes conversion efficiency averaged over the down-converted wavelengths using the formula  $3\lambda^{in}/(\lambda_1^{out} + \lambda_2^{out} + \lambda_3^{out})$ .

A last and more difficult assumption to make is wavelength for the UV LED in the wavelength-conversion approach. This wavelength is likely to be determined by balancing: the efficiency of the LED (so far, the shorter the wavelength the less efficient); the quantum efficiency of the phosphors (so far, the shorter the wavelength the more efficient); and the phosphor Stokes conversion efficiency (the shorter the wavelength the less efficient). Based on current knowledge, we assume in this Roadmap that a reasonable target wavelength will be in the range of 370-410 nm.

These derivative assumptions and targets are summarized in Table 3 for the three different approaches to white-light production. As can be seen, the wavelength conversion approach imposes the highest requirements on chip powerconversion efficiencies – they must approach 0.7 to meet our 2012 SSL-LED lamp targets. In contrast, the colormixing approach "only" requires chip power-conversion efficiencies of roughly 0.4 to meet our 2012 SSL-LED lamp targets. The hybrid approach, as expected, is in between, and requires chip power-conversion efficiencies of 0.6 to meet our 2012 SSL-LED lamp targets.



We note that these efficiencies are high, and it is not yet clear whether they can be achieved. However, as illustrated in Figure 9, the power conversion efficiencies of infrared (710-850 nm) lasers and red (650 nm) LEDs are in the 40-60% range. Both of these are relatively mature semiconductor technologies, and serve as existence proofs that comparable efficiencies might be achievable in the visible spectrum.

# **R-3 Challenge Areas**

We argued, in Sections R-1 and R-2, that our SSL-LED targets are physically reasonable and consistent with our knowledge of fundamental physics and with other, more mature, semiconductor manufacturing technologies. Nevertheless, solid-state lighting is in its infancy, just as silicon integrated circuits were in their infancy two decades ago.

Hence, in order to meet the lighting targets and lamp sub targets discussed in Sections R-1 and R-2, significant Challenges must be overcome in a number of areas. We organize these areas into three overall building blocks:

- 1. Substrates, Buffers and Epitaxy
- 2. Physics, Processing and Devices
- 3. Lamps, Luminaires and Systems

The Challenge Areas will differ, of course, in their risk and reward relative to solid-state lighting. High-risk Challenge Areas are revolutionary (no known approach yet exists); while low-risk Challenge Areas are evolutionary (at least some approaches exist). High-reward Challenge Areas are those that need immediate progress, while low-reward Challenge Areas are those that need steady progress to circumvent issues that are believed will arise as time goes on. These Challenge Areas are summarized in the following Table, organized according to their perceived risk and reward.

		1.3.2 OMVPE chemistry	2.2.3 Etching, chip shaping,	1.1.1 GaN and AlN substrates			
		1.3.3 OMVPE reactive flow and tools	texturing	1.4.2 AlGaInN epitaxy			
		*****	2.3.2 Green, Blue and UV LEDs	1.4.3 Doping and passivation			
		1.3.4 OMVPE In situ diagnostics	2.4.1 Resonant cavity and super- luminescent LEDs	1.4.4 Novel epimaterials			
		2.1.1 AlGaInN material properties		2.1.2 High-efficiency radiative recombination			
		3.2.2 Color-mixing and	3.1.1 Phosphor materials	2.1.3 Photon manipulation			
	Ξ	wavelength conversion	3.4.2 Aesthetic, intelligent	2.3.3 Monolithic white LEDs			
	HIGH	3.3.2 Optics for directing and diffusing	buildings 3.1.2 Phosphor synthesis and	2.3.3 Wohonthic white LEDs 2.4.3 VCSELs			
	H	annusing	application	2.4.5 VCSEL8			
			3.1.3 Encapsulants				
			3.2.1 Power lamps				
			3.4.1 Human factors and				
			productivity				
RD			produced vity				
REWARD							
RE		3.2.3 Drive electronics	1.2.2 ELO GaN buffers	1.2.1 Thin GaN buffers			
		3.3.1 Power luminaires	1.2.3 Thick, removable GaN	1.3.1 MBE tools and mechanisms			
			buffers	2.4.2 Edge-emitting lasers			
	Y		1.4.1 AlGaInP epitaxy				
	MEDIUM		2.2.1 Wafer bonding and film				
	Q		transfer				
	W		2.2.2 Metallization and thin films				
			2.3.1 Red LEDs				
			3.3.3 Luminaire reliability and				
			disposal				
		1.1.2 Sapphire substrates	1.1.3 SiC substrates				
	TOW		2.4.4 Optoelectronic simulation				
	Ĕ		tools				
		LOW	MEDIUM	HIGH			
		RISK					

## **R-4 Decisions**

The remainder of this Roadmap is organized around the various Challenge Areas listed in Section R-3.

Note that not all of the Challenge Areas will be needed as the technology evolves. At present, there are many "forks in the road." As one or another of these forks is taken, one or another individual Challenge Area may become more or less important. However, lacking full knowledge, it will often be the case that more than one fork will need to be taken for some time, before clear technology decisions can be made.

The most important of these technology decisions, or "forks in the road," are discussed and highlighted in Chapters 1-3 of the Roadmap. They are gathered together in the following Table.

#### **0** Technology Overview

Decision: Will the SSL-LED chip "engine" be driven at low input power densities with low  $cost/cm^2$  and  $T_{oper}$ , or will it be driven at high input power densities at high  $cost/cm^2$  and  $T_{oper}$ ?

Decision: Will SSL-LED white light production be through a wavelength conversion, color mixing, or a hybrid approach?

Decision: How many colors (and in what wavelength ranges) will best balance the three constraints of pure white, high color rendering and high luminous efficacy?

#### 1 Substrates, Buffers and Epitaxy

Decision: Which semiconductor materials family will form the basis for the SSL-LED chip "engine" -- AlGaInN only, or a combination of AlGaInP and AlGaInN?

Decision: Which low-defect-density substrate or substrate+buffer combination will form the basis for epitaxial AlGaInN devices: Native GaN, Sapphire/SiC + Buffer, or Removable GaN?

#### 2 Physics, Processing and Devices

Decision: Will the SSL-LED light chip "engine" be based on spontaneous (LEDs) or stimulated (lasers) emission devices?

Decision: Will the SSL-LED light chip "engine" be a single-function generator of monochromatic light, or will it monolithically integrate other functions, such as white-light production and programmable drive electronics?

#### 3 Lamps, Luminaires and Systems

Decision: Will SSL-LED white lighting compete with conventional lighting by emphasizing traditional attributes such as low cost-of-ownership, high efficiency and environmental friendliness, or will it compete by emphasizing new attributes such as programmability and improved interplay with building architectures and the human visual system?

## **R-5 Challenges and Possible Approaches**

In this Section, we gather all quantitative statements of Challenges and Possible Approaches associated with the various Challenge Areas. For each Challenge, we specify which of the three approaches to white light production (wavelength conversion, color mixing, or hybrid) it will have impact on. We also indicate the High-Medium-Low risk and reward scores discussed above. In addition, unless otherwise specified, whenever we refer to a quantitative target in a Challenge, we refer to Year 2012 (10-year) targets.

#### 0 Technology Overview

#### 0.1 History

0.1.1 Fire: chemically fueled blackbody emission

0.1.2 Incandescence: electrically fueled blackbody emission

0.1.3 Discharge/Fluorescence: electrically fueled narrowband emission from gases 0.1.4 Solid-State Lighting: electrically fueled narrowband emission from solids

#### 0.2 Benefits

0.2.1 Energy and Environment 0.2.2 Quality of Lighting and Human Productivity

0.2.3 National Security and other Spin-Offs

0.3 Birth-Death Life Cycle of Photons

0.3.1 Delivering electrons from the power grid

0.3.2 Injecting electrons and holes into the semiconductor

0.3.3 Transporting and trapping the electrons and holes

0.3.4 Creating photons

0.3.5 Extracting photons from the chip

0.3.6 Transforming monochromatic into white light

0.3.7 Delivering light to the viewer

0.4 Technology Building Blocks

#### 1 Substrates, Buffers and Epitaxy

#### 1.1 Substrates

1.1.1 GaN and AlN

Recommendation: Develop technology for high (<1e4 defects/cm<sup>2</sup>) quality, moderate (<\$25/cm<sup>2</sup>) cost GaN or AlN substrates. Impact=WC+CM+Hy; Risk=H; Reward=H. Possible Approaches: High-Pressure Solution Growth. Low-Pressure Solution Growth. Pressure-Controlled Solution Growth. Vapor Transport Growth.

Ammonothermal Approach

#### 1.1.2 Sapphire

Recommendation: Develop technology for manufacturing larger ( $\geq 6$ "), cheaper ( $\leq 5/cm^2$ ), better surface-finish (0001) sapphire substrates. Impact=WC+CM+Hy; Risk=L; Reward=L.

Possible Approaches:

Scale-up of traditional growth processes.

Heat-exchanger method

#### 1.1.3 SiC

Recommendation: Develop technology for manufacturing larger ( $\geq$ 4" diameter), lower ( $\leq$ 1e4/cm<sup>2</sup>) defect density, cheaper ( $\leq$ \$15/cm<sup>2</sup>), SiC substrates.

Impact=WC+CM+Hy; Risk=M; Reward=L. Possible Approaches:

Close-spaced sublimation growth.

#### 1.2 Buffers

#### 1.2.1 Thin GaN Buffers

Recommendation: Develop buffer layers on sapphire, SiC or silicon, with decreased (1e7/cm<sup>2</sup> by 2007 and 1e5/cm<sup>2</sup> by 2012) defect density, increased reproducibility, and with variable lattice constants to enable flexibility in strain-engineering of epitaxial devices. Impact=WC+CM+Hy; Risk=H; Reward=M.

#### Possible Approaches:

Relationship between surface conditions and buffer quality.

Mechanisms for nanostructure evolution during buffer formation. Increased use of in situ monitoring.

Strain engineering. MBE studies.

#### 1.2.2 ELO GaN Buffers

Recommendation: Develop ELO technologies that enable large (1mm<sup>2</sup>) area devices to be fabricated on low (≤1e6/cm<sup>2</sup> by 2007) defect density areas, at moderate (≤\$20/cm<sup>2</sup>) cost per cm<sup>2</sup> of "good" material. Impact=WC+CM+Hy; Risk=M; Reward=M. Possible Approaches: Extensions of ELO. ELO on cheap substrates. Thin, super-anisotropic ELO. Alternative mask materials with no auto doping. Time-engineering of facet orientation evolution Self-assembled ELO. Variable-composition ELO.

#### 1.2.3 Thick, Removable GaN Buffers

Recommendation: Develop ultra-high-quality (<1e5 defects/cm<sup>2</sup>) thick, variable-latticeconstant, removable buffers to be used either stand-alone or with subsequent single or multiple film transfers to other substrates, with final overall substrate+buffer cost <\$25/cm<sup>2</sup>). Impact=WC+CM+Hy; Risk=M; Reward=M. Possible Approaches. Hydride vapor phase epitaxy (HVPE). Defect evolution during thick buffer formation. Variable composition buffers. Multiple layer transfer. Close-spaced sublimation.

#### 1.3 Epitaxy Tools

#### 1.3.1 MBE Tools and Mechanisms

Recommendation: Develop MBE tools and processes that enable epitaxy of ultra-highefficiency (>70%) visible light-emitting devices. Impact=WC+CM+Hy; Risk=H; Reward=M. Possible Approaches:

P-doping.

Ultra-sharp interfaces and extreme composition control.

Materials with cubic crystallography.

Surfactant-controlled growth.

Novel alloys.

Different polarity growth modes.

#### 1.3.2 OMVPE Chemistry

Recommendation: Develop fundamental understanding of precursor chemistries that apply to actual OMVPE growth conditions and that enable design of new tools and processes for improved material quality and more efficient precursor usage.

Impact=WC+CM+Hy; Risk=L; Reward=H.

Possible Approaches:

Studies in conventional OMVPE reactors. Studies in special-purpose experimental set-ups. Computational chemistry.

Novel Precursors and Carrier Gases.

#### 1.3.3 OMVPE Reactive Flow and Tools

Recommendation: Develop, through an understanding of chemistry mechanisms and fluid flow, a completely new generation of AlGaInN OMVPE tools with high compositional and growth rate uniformity, and ultra-high material quality.

Impact=WC+CM+Hy; Risk=L; Reward=H.

Possible Approaches.

Computational fluid dynamics studies.

Relationship between material quality and growth conditions. Novel OMVPE tool designs.

#### 1.3.4 OMVPE In Situ Diagnostics

Recommendation: Develop in situ diagnostics for AlGaInN OMVPE tools, and implement strategies for calibrating and controlling growth parameters (e.g., temperature, partial pressures, rates) for both buffer layers and device heterostructures.

Impact=WC+CM+Hy; Risk=L; Reward=H. Possible Approaches: Optical pyrometry. Normal-Incidence Reflectometry Spectroscopic Ellipsometry.

New probes.

## 1.4 Epitaxy Processes

#### 1.4.1 Quaternary AlGaInP

Recommendation: Develop AlGaInP materials and heterostructures with high (>95%) internal radiative quantum efficiencies at wavelengths <620 nm.

Impact=CM; Risk=M; Reward=M. Possible Approaches. Suppression of ordering. Higher-purity Al, Ga, In, P sources. MBE.

Strain-engineered structures.

#### 1.4.2 Quaternary AlGaInN

Recommendation: Develop epitaxy processes for high-quality materials and nanostructures over the entire AlGaInN quaternary composition range, to achieve high (>95%) internal radiative quantum efficiencies throughout the UV and visible (370-630 nm), and very-high (>1e19/cm<sup>3</sup>) effective p-type doping levels.

Impact=WC+CM+Hy; Risk=H; Reward=H.

Possible Approaches.

Variable-pressure OMVPE.

Tailoring the material nanostructures (e.g., quantum dot nucleation away from extended defects)

Modified OMVPE processes.

Quantum dots without In

Quantum dots with both In and Al

Control of parasitic pre-reactions.

Molecular beam epitaxy.

Widen OMVPE growth conditions.

Strain-engineered buffers.

Composition engineering at interfaces.

Growth interruptions for smoother interfaces

#### 1.4.3 Doping and Passivation

Recommendation: Develop very-high-doped (1e19/cm<sup>2</sup> equivalent) heterostructures for

lateral and vertical hole transport, over the entire AlGaInN composition range. Impact=WC+CM+Hy; Risk=H; Reward=H. Possible Approaches:

p-doping life-cycle. H uptake and release. Surface barrier engineering. Novel p-type dopants. Piezoelectric-field-induced artificial sheet charges MBE (with and without H) Co-doping. Point defect structure.

#### 1.4.4 Novel Epimaterials

Recommendation: Explore novel nitridereplacement epimaterials for high internalradiative-efficiency (>80%) in the wavelength ranges UV(370-410), R(590-630) G(520-560) and B(440-480). Impact=WC+CM+Hy; Risk=H; Reward=H. Possible Approaches: GaNAs and GaNP.

#### 2 Physics, Processing and Devices

#### 2.1 Semiconductor Physics

#### 2.1.1 AlGaInN Material Properties

Recommendation: Firmly establish the physical constants of AlGaInN alloys – including mechanical properties, electron band-structure and transport, phonons and piezoelectric effects, and defects.

Impact=WC+CM+Hy; Risk=M; Reward=H. Possible Approaches:

EXAFS.

Samples with controlled strains and electric fields.

Ternary and quaternary electronic band structure.

Taxonomy of point and point defect clusters. Trapping and escape of hot carriers.

Electron and hole scattering.

#### 2.1.2 High-Radiative-Efficiency Electron-Hole Recombination

Recommendation: Understand and control electron-hole interactions and exciton formation in heterostructures, so as to enable high internal-radiative-recombination efficiencies (Year 1 60% at 100C at 50A/cm<sup>2</sup>; Year 3 60% at 125C at 150A/cm<sup>2</sup>; Year 5 90% at 150C at 250A/cm<sup>2</sup>) over the full range of wavelengths (370-630 nm). Impact=WC+CM+Hy; Risk=H; Reward=H.

Possible Approaches.

Engineering of Imperfect Heterostructures.

Time-resolved PL and PLE.

Controlled microstructures.

Controlled heterostructures.

Electric and polarization fields. Spatially resolved luminescence. Transport and recombination models.

#### 2.1.3 Photon Manipulation

Recommendation: Explore novel micro- and nanostructures for dispersive, guided-wave manipulation of photons for higher-externalefficiency (Year 1 30%, Year 3 50%, Year 5 70%) light-emitting devices.

Impact=WC+CM+Hy; Risk=H; Reward=H. Possible Approaches. Heterogeneous media. Fabrication. Surface plasmons.

Photon-mode engineering.

#### 2.2 Device Processing

#### 2.2.1 Wafer Bonding and Film Transfer

Recommendation: Develop scaled-up (4") high-yield GaN wafer bonding and single or multiple film-transfer processes to enable economical removable-substrate technologies, as well as improved optical engineering and integration.

Impact=WC+CM+Hy; Risk=M; Reward=M. Possible Approaches: Laser lift-off Smart-Cut (implantation-based layer removal) Selective etching GaN/on Si liftoff Metal/film transfer

#### 2.2.2 Metallization and Thin Films

Recommendation: Develop metallization processes for n and especially p type AlGaInN materials with low (Year 1 1e-3 ohms-cm<sup>2</sup> at 100C and 50A/cm<sup>2</sup>, Year 3 1e-4 ohm-cm<sup>2</sup> at 125C and 150A/cm<sup>2</sup>, Year 5 1e-5 ohm-cm<sup>2</sup> at 150C and 200A/cm<sup>2</sup> lead-free) electrical contact resistance, and desirable optical properties such as high (>90%) reflectance or transmission.

#### Impact=WC+CM+Hy; Risk=M; Reward=M.

Possible Approaches:

Polarization-field enhanced contacts

Bi-metal contacts for high reflectance and low contact resistance

Metal oxides (e.g., ITO) for optically

transparent contacts

Improved processing of conventional Ti-based n and Ni-based p contacts

#### 2.2.3 Etching, Chip-Shaping, Texturing

Recommendation: Develop economical  $(<10\$/cm^2)$  designs and processes for etching, shaping and texturing devices and chips for >90% external extraction efficiencies, while minimizing surface damage and active-area (<10%) loss.

Impact=WC+CM+Hy; Risk=M; Reward=H.

Possible Approaches. Ray tracing and waveguide modeling. Photoenhanced electrochemical etching. Laser ablation for etching and polishing. Novel shapes.

Mechanical shaping methods.

#### 2.3 LEDs and Integrated LEDs

#### 2.3.1 Red LEDs

Recommendation: Provide red LED with wavelengths of <620nm and increase input power density to 600 W/cm<sup>2</sup> while maintaining high (>40%) power-conversion efficiency and reasonable (<70\$/cm<sup>2</sup>) cost.

Impact=CM Risk=M; Reward=M.

Possible Approaches.

Alternative High-Extraction Structures. Enhance barrier heights through strain engineering. Quantum dots. InN-rich Alloys. Degradation mechanisms.

#### 2.3.2 Green, Blue and UV LEDs

Recommendation: Reduce UV (370-410nm) blue (440-480nm) and green (520-560nm) LED wafer manufacturing cost to 70\$/cm<sup>2</sup>, increase power conversion efficiency (Year 1 25-35%, Year 3 35-45%, Year 5 50-60%, Year 10 60-70%), and increase power density to 600 W/cm<sup>2</sup>.

Impact=CM+Hy; Risk=M; Reward=H. Possible Approaches: Epimaterial improvement. Optical engineering. Improved current spreading.

#### 2.3.3 Monolithic White LEDs

Recommendation: Explore schemes to create monolithic white LEDs, in which package and fixture level functionality (such as color mixing, wavelength conversion, optical focusing and directing, and control circuitry) have been integrated into the chip, while maintaining high luminous efficacies (Year 1 40lm/W, Year 3 50lml/W, Year 5 75lm/W).

Impact=WC+CM+Hy; Risk=H; Reward=H.

Possible Approaches

Thin film wavelength converters.

Selective-growth multiple wavelength chips Integration with MEMS

Multi-quantum well emitting layers (RGB).

#### 2.4 Directional Emitters 2.4.1 Resonant-Cavity and Super-

#### Luminescent LEDs

Recommendation: Develop cost-effective RCand SL-LEDs with high power-conversion efficiency and low output FWHM angular spreads (Year 1 35°, Year 3 25°, Year 5 20°). Impact=WC+CM+Hy; Risk=M; Reward=H. Possible Approaches: Novel resonant cavities. Dielectric DBRs. Side-emitting LEDs.

#### 2.4.2 Edge-Emitting Lasers

Develop economical Recommendation: (<90\$/cm<sup>2</sup>), high input power density (500W/cm<sup>2</sup> averaged over entire chip), highpower-conversion efficiency (Year 1 20%, Year 3 40%, Year 5 60%, Year 10 70%) edgeemitting semiconductor lasers in the four wavelength ranges UV(370-410nm), R(590-630nm), G(520-560nm), B(440-480nm). Impact=WC+CM+Hy; Risk=H; Reward=M. Possible Approaches. Improved AlGaInN materials. Improved heterostructure designs. Buried Heterostructures Wafer-scale facet creation. Novel designs for lower thermal resistance Strain tailoring

#### 2.4.3 VCSELs

Recommendation: Develop economical  $(<75\)/cm^2$ , high input power density  $(600W/cm^2 \text{ averaged over entire chip})$ , high-power-conversion efficiency (Year 1 pulsed, Year 3 cw 20%, Year 5 cw 50%, Year 10 cw 70%) VCSELs in the four wavelength ranges UV(370-410nm), R(590-630nm), G(520-560nm), and B(440-480nm).

Impact=WC+CM+Hy; Risk=H; Reward=H.

Possible Approaches:

Novel strain-engineered DBRs. Novel concepts for lateral current injection. Novel concepts for heat sinking.

#### 2.4.4 Optoelectronic Simulation Tools

Recommendation: Develop commercial software tools for simulation of high-efficiency high-power optoelectronic devices (Year 1 RCLED capability with prototypes, Year 2 Textured surfaces capability, Year 3 VCSELs with beta availability, Year 5 Photonic Crystals with commercial availability).

#### Impact=WC+CM+Hy; Risk=M; Reward=L.

Possible Approaches.

Materials properties.

Novel, Fast Approaches in Device Simulation Tools.

Light Extraction Algorithms. Finite Differencing Approaches. Simulation of Material Layers Growth.

#### 3 Lamps, Luminaires and Systems

#### 3.1 Phosphors and Encapsulants

#### **3.1.1 Phosphor Materials**

Recommendation: Develop UV (370-410nm) and blue (440-480 nm) absorbing phosphor materials with >80-85% quantum efficiency in the red (590-630 nm), green (520-560 nm) and blue (440-480 nm), >1000/cm optical absorption coefficient, low degradation over 100,000hrs, and low-variation in efficiency and absorption at high (175C) operating temperatures.

Impact=WC+Hy; Risk=M; Reward=H.

Possible Approaches.

Multiple wavelength conversions. High-vibrational-frequency phosphors. Novel sensitizers.

Nanocrystalline Semiconductors The optical properties (absorption and luminescence spectra, and scattering cross section) of nano-scale semiconductors can be tuned through quantum size effects. This property can be used to develop custom red, green, and blue emitters for solid-state lighting that are not restricted to atomic transitions. In addition, such luminescence conversion materials would exhibit much lower scattering optical scattering due to the small size. Organic coordination-compound phosphors. Combinatorial discovery. Improved evaluation techniques.

Charge-state engineering.

#### 3.1.2 Phosphor Synthesis and Application

Recommendation: Develop phosphor synthesis and application methods that are environmentally friendly, maintain high phosphor quantum efficiency, cause no dissipative optical absorption or scattering, are compatible with a variety of lamp packaging techniques, and maintain lumen performance over lifetimes >100,000 hours.

Impact=WC+Hy; Risk=H; Reward=H.

Possible Approaches: New synthesis techniques. Ink "printing". Phosphor slurries. Coated phosphors. Nanocrystalline phosphors. Integration with encapsulants.

#### 3.1.3 Encapsulants

Recommendation: Develop encapsulants for high-power lamps that are: water clear with index >1.6; have >80% transmission through 3mm thick layer from 440nm to 650nm after exposure to 150C and low ppm H2O for 50,000hrs; are able to block wavelengths shorter than 440nm (for the wavelengthconversion approach); and with mechanical properties consistent with low cost manufacture and use. Impact=WC+CM+Hy; Risk=H; Reward=H. Possible Approaches: Novel heat-resistant materials. Novel additives. Thermally managed encapsulants. UV-filtering encapsulants.

#### 3.2 Lamps and Electronics

#### 3.2.1 Power Lamps

Recommendation: Develop low-cost (<90\$/cm<sup>2</sup> of chip area used) substrate packaging approaches with die-to-lamp thermal resistance of <25C/W, and that accommodate total input powers  $\geq 10W$ . Impact=WC+CM+Hy; Risk=H; Reward=H. Possible Approaches. Chip-up vs. Chip-down mounting. New package architectures. New materials for mounting and heat sinking. Direct chip on board. Low-attachment-stress wire bonding. 3.2.2 Color-Mixing and Wavelength Conversion

Recommendation: Optics for color-mixed, wavelength-conversion, or hybrid lamps with CCT and CRI variation < 10%, over large viewing angles and temperature ranges (175C), with parasitic optical losses <10%, at costs < 0.40\$/klm, and over lifetimes >100,000 hrs. Impact=CM; Risk=M; Reward=H. Possible Approaches: Modeling Tools.

Transmission vs. Reflective Approaches. Integration with sensors.

Encapsulant-based optics.

Compact light randomizers.

Optics that compensate for light-scattering phosphors.

#### 3.2.3 Drive Electronics

Recommendation: Power supplies and drive electronics that transform 100 VAC to 2-5 VDC with >95% efficiency, good quality factor, that have long (150,000 hour) lifetimes, and that can be externally programmed to alter color type and quality, and lamp intensity. Impact=WC+CM+Hy; Risk=L; Reward=M. Pagesible Approaches:

Possible Approaches:

Switching power supplies. Variable pulse-amplitude or pulse-width drive circuits.

Monolithic drive electronics.

#### 3.3 Luminaires

#### 3.3.1 Power Luminaires

Recommendation: Luminaire materials and designs that present a thermal impedance to the

lamp less than 25C/W, and that themselves can be passively cooled through convection from the environment. Impact=WC+CM+Hy; Risk=L; Reward=M. Possible Approaches. Multi-lamp luminaires. Heat sinks. Location selection. Compact luminaires.

#### 3.3.2 Optics for Directing and Diffusing

Recommendation: Develop efficient (>90%), low-cost, low-aberration plastic optics for homogenizing, diffusing and safely directing light from point-source single and multiple lamps.

Impact=WC+CM+Hy; Risk=L; Reward=H.

Possible Approaches. Miniature optics for thin, compact luminaires. Modeling tools.

Reflective, refractive and guided-wave optics. Low-cost, manufacturing-tolerant optics.

#### 3.3.3 Luminaire Reliability and Disposal

Recommendation: Luminaires constructed of materials with lifetimes greater than 150,000 hrs, and without environmental disposal concerns.

Impact=WC+CM+Hy; Risk=M; Reward=M. Possible Approaches: Long-life Plastics. Lead-free Solders. Corrosion-free wires and connectors.

#### 3.4 Lighting Systems

#### 3.4.1 Human Factors and Productivity

Recommendation: Quantify visual and nonvisual effects on humans of lighting as producible by solid-state lighting. Impact=WC+CM+Hy; Risk=H; Reward=H. Possible Approaches. Color quality. Dynamic lighting. Human health and productivity. Animal health and productivity. Application-specific lighting optimization. Visual stress and safety. Direct vs. indirect lighting Intensity-dependent color.

#### 3.4.2 Aesthetic, Intelligent Buildings

Recommendation: Novel concepts in building architectures that exploit unique characteristics of SSL-LEDs to simultaneously optimize energy efficiency, human comfort and productivity.

Impact=WC+CM+Hy; Risk=M; Reward=H.

Possible Approaches.

Intelligent networked lights. Integration with sensors.

LEDs for General Illumination Update 2002 – Full Edition © OIDA Member Use Only Integration with environmental systems (HVAC). Integration with building security systems. Intelligent lighting solutions for human factors engineering. Integration with architectural materials. Integration with office information systems. Low-profile ceiling integration

## **0 TECHNOLOGY OVERVIEW**

In this Chapter, we introduce SSL-LED technology.

First, to put this technology in perspective, we briefly review the history of lighting technologies. The major technologies are: Fire, Incandescence, Fluorescence, and, most recently, Solid-State.

Second, we discuss the energy, environment, quality of lighting and human productivity, national-security, and economic benefits of SSL-LED technology, assuming the targets outlined in Chapter R are met.

Third, we describe SSL-LED technology from the point of view of the birth-death lifecycle of photons, along with the three major design approaches to white-light production: wavelength conversion, color mixing, and hybrid approaches.

Fourth, we introduce the three overall building blocks (or core competencies) associated with solid-state lighting.

## 0.1 History

Lighting technologies are substitutes for sunlight in the 425-675 nm spectral region where sunlight is most concentrated and to which the human eye has evolved to be most sensitive. The history of lighting<sup>13</sup> can be viewed as the development of increasingly efficient technologies for creating visible light inside, but not wasted light outside, of that spectral region.

The three traditional technologies are Fire, Incandescence, Fluorescence; the technology discussed in this Roadmap constitutes a new, fourth technology, Solid-State Lighting. These four technologies can be differentiated by the type of material (gas or solid) that emits the light, by the spectral bandwidth (broadband blackbody or narrowband) of the light emission, and by the fuel (chemical or electrical) used to create the light. These differences, in turn, have consequences on the fundamental costs and performance of the technologies.

# **0.1.1 Fire: chemically fueled blackbody emission**

The first lighting technology is Fire. This technology involves the burning of a chemical fuel (usually a

combination of gases, solids or liquids) to heat a gas or solid that emits broadband blackbody light. Because the light is broadband blackbody, most of which lies outside of the visible spectrum, fire is inherently inefficient.

Moreover, because the fuel is chemical and must be transported into the reaction zone, the transport mechanism itself (typically convective flow) can make it difficult to achieve high temperatures. Hence, most of the emitted light lies outside the visible spectrum, with the peak of that blackbody spectrum in the invisible infrared.

The history of Fire can be viewed as attempts to control the mechanism for fuel transport and burning, to increase the temperature of the emitting gas, and to enhance the amount of visible light emission. Hence, the evolution from: open fires (1.42 million years ago), to torches, to wax candles, to oil and kerosene lamps. The culmination of fire can be thought of as gas-fired lamps, first introduced by William Murdock in 1792, in which the fuel is converted into a continuous incoming stream of gas before being burned.

# 0.1.2 Incandescence: electrically fueled blackbody emission

The second lighting technology is Incandescence. This technology involves the use of electricity as the fuel to heat a gas or solid that emits broadband blackbody light. Because, as with Fire, the light is broadband blackbody, most of which lies outside the visible spectrum, Incandescence is also inherently inefficient.

However, because the fuel is electrical, and can be transported more easily into a small emitting zone than can chemical fuels, the emitting zone can be very hot. Hence, the peak of the blackbody spectrum can be arranged to be near the visible portion of the spectrum, and the efficiency of Incandescence can be much higher than that of Fire.

The history of Incandescence can be viewed as an attempt to increase the temperature of the emitting filament while maintaining an acceptable lifetime. Hence, the evolution from: electric arc, to carbon-filament, to metal-filament lamps. The culmination of Incandescence can be thought of as the tungsten-filament lamp with a trace amount of lifetime-enhancing halogen gases.

<sup>&</sup>lt;sup>13</sup> Brian Bowers, Lengthening the Day: A History of Lighting Technology (Oxford University Press, Oxford, 1998).

#### 0.1.3 Discharge/Fluorescence: electrically fueled narrowband emission from gases

The third lighting technology is Discharge/Fluorescence. This technology involves the use of electricity as a fuel to excite (but not heat) a low-pressure gas that emits narrowband atomic line emission. This primary narrowband light can be used as is, or it can be absorbed and re-emitted as secondary light at different (longer) wavelengths through use of fluorescent or luminescent materials.

Because the light is narrowband, and can be concentrated in the visible portion of the spectrum, the efficiency of Discharge/Fluorescence is much higher than Incandescence. Indeed, the highest-efficiency lamp of any type is the sodium lamp, at 200 lm/W, which emits narrowband yellow light at 589 nm.

However, because the primary light is narrowband, it does not fill the visible spectrum, and appears colored. For general lighting, it is necessary to convert this narrowband emission into semi-broadband emission that optimally fills the visible spectrum and gives the appearance of white light. The history of Discharge/Fluorescence for general lighting has been driven by development of luminescent materials that can perform this conversion while surviving direct exposure to reactive gas plasma discharges. Hence, the evolution from early fluorescent lamps, which had a greenish, low-quality color, to modern fluorescent lamps with phosphor blends and relatively good-quality color.

# 0.1.4 Solid-State Lighting: electrically fueled narrowband emission from solids

The fourth and most recent lighting technology is Solid-State Lighting. This technology involves the use of electricity as a fuel to inject electrons and holes into a solidstate semiconductor material. When the electrons and holes recombine, light is emitted in a narrow spectrum around the energy bandgap of the material. Because the light is narrowband, and can be concentrated in the visible portion of the spectrum, it has, like Fluorescence, a much higher light-emission efficiency than Incandescence.

However, as with Fluorescence, because the light is narrowband, it does not fill the visible spectrum with light, and appears colored. Hence, the evolution of Solid-State Lighting must eventually include overcoming similar challenges associated with converting the narrowband emission into semi-broadband emission that fills the visible spectrum to give the appearance of white light.

Unlike in Fluorescence technology, the wavelength of the narrowband emission can be tailored relatively easily, hence can be adjusted either to increase the quantum efficiency, or to minimize the quantum energy (or Stokes-shift) inefficiency associated with its conversion to semibroadband emission. Hence, this technology is potentially even more efficient than Fluorescence.

Both inorganic and organic semiconductors are being considered for this new generation of lighting technology.<sup>14</sup> Inorganic semiconductors (SSL-LEDs), which are much further developed, are the focus of this Roadmap; organic semiconductors (SSL-OLEDs) are the focus of a parallel and separate Roadmap.

The technology of inorganic-semiconductor-based solidstate lighting has been reviewed recently.<sup>15</sup> Light emission from inorganic semiconductors was first observed<sup>16</sup> by H.J. Round in 1907. The first device in which such light emission was controlled was the light-emitting diode (LED), demonstrated by Nick Holonyak and co-workers at the General Electric Corporation in 1962. The first commercial LED products were introduced in 1968: indicator lamps by Monsanto and electronic displays by Hewlett-Packard.

The initial performance of LEDs was poor, with maximum output fluxes of around one thousandth of a lumen, and only one color, deep red, available. However, steady progress has been made: at this point efficiencies and brightness are comparable to those of Incandescence, and the color range has been extended to the entire visible spectrum.

This progress has enabled significant penetration of monochrome applications such as traffic and automotive signaling, and limited penetration of specialty white lighting such as flashlights, walkway lights and LCD display backlighting. By analogy with the history of other disruptive technologies,<sup>17</sup> we expect these applications to provide crucial vehicles for evolutionary improvements in SSL-LED cost and performance. In addition, if

<sup>&</sup>lt;sup>14</sup> A Bergh, M. G. Craford, A. Duggal, and R. Haitz, "The promise and challenge of solid-state lighting," Physics Today 54 (2001) 42-47.

<sup>&</sup>lt;sup>15</sup> G. B. Stringfellow and M. G. Craford, High Brightness Light Emitting Diodes (Academic Press, San Diego, 1997).
<sup>16</sup> H. J. Round, "A Note on Carborundum," Electrical World 49 (1907) 309.

<sup>&</sup>lt;sup>17</sup> C. M. Christensen, The Innovator's Dilemma: When New Technologies Cause Great Firms to Fail (Harvard Business School Press, Boston, 1997).

accompanied by the revolutionary improvements anticipated in this Roadmap, it is likely that massive penetration of white lighting will occur, with the huge benefits discussed below in Section 0.5.

# 0.2 Benefits

A vital and growing use of energy is the generation of electricity. In the US alone, producing electricity costs about \$50 billion a year. In addition, the cost of electrical energy is not measured in dollars alone -- there is also the environmental cost of smog and carbon dioxide pollution associated with electricity production.

Just as fluorescent and HID sources have provided tremendous energy savings over the last few decades, SSL-LEDs, with their potential for significant improvements in energy efficiency, offer significant potential for energy savings over the next few decades. In this Section, we discuss these and other potential benefits.

#### **0.2.1 Energy and Environment**

The most significant benefit of massive replacement of traditional with SSL-LED lighting technology will be on the energy and environment. In the U. S., about 20% of all generated electricity is used for lighting; worldwide usage patterns are similar. Consequently, significant improvements in lighting efficiency would have a major impact on worldwide energy consumption.

In addition, electricity generation from burning of coal and petroleum is a major source of environmental pollution – there is an increasingly strong link between carbon emissions, the greenhouse effect, and global warming. Hence, SSL-LEDs, through their higher efficiency, could reduce significantly environmental pollution. In addition, a side benefit is that SSL-LEDs are mercury-free, and easier to dispose of than fluorescent lamps.

If SSL-LED's ultimate target of 50% efficiency (200lm/W) is realized, along with complete market penetration, the benefits to the U.S. would be spectacular:

- A 50% decrease in the 600 TW-hr/yr of electricity used for lighting, or a savings of 300 TW-hr/yr, or \$25B/yr.
- A freeing-up of over 30 GW of electric generating capacity for other uses, or, alternately, elimination of the need for 30 power generating plants.
- A 50% decrease in the 50 Mtons/yr of carbon emissions created during generation of electricity for lighting, or 25 Mtons/yr.

Of course, the actual realized benefits will depend on a complex interplay between how quickly the market is penetrated and how quickly the technology is advanced. This interplay can be thought of as a "virtuous cycle": as technology advances (increased performance and decreased cost), market penetration increases, spurring increased investment in further technology advances.

Several scenarios have been proposed for the evolution of market penetration and technology advance, and have been discussed in the white paper by Haitz, et al,<sup>18</sup> and a more recent market penetration study by Arthur D. Little.<sup>19</sup>

In Japan's "Light for the 21<sup>st</sup> Century" national project,<sup>20</sup> a market penetration of 13% with an efficiency of 120 lm/W by 2010 was targeted. Our targets are similarly aggressive, and are comparable to those envisioned in the "price breakthrough" scenario discussed in the Arthur D. Little report. In that scenario, for medium (70-79) CRI applications, efficiency and purchase cost reach 110 lm/W and 7 \$/klm by 2010, and 120 lm/W and 0.5 \$/klm by 2020.

We note that this scenario is so aggressive that it was not even considered in the original April, 2000 white paper by Haitz, et al, and was even viewed as "radical" in the Arthur D. Little report itself. Such is the pace of innovation over the past 2-3 years, however, that, by August 2002, this scenario is now viewed essentially as this Roadmap's targets.

The general conclusions from the Arthur D. Little report for this "price-breakthrough" scenario are shown in Figure 10. SSL achieves nearly 50% market penetration by 2012, and nearly 90% market penetration by 2020. About 0.3 quads/yr of primary energy (27 TW-hr/yr of end-use electricity) is saved by 2012, and about 2.7 quads/yr of primary energy (246 TW-hr/yr of end-use electricity) is saved by 2020. This represents over 35 percent of the projected energy consumption per year for lighting in 2020.

The carbon savings associated with these energy savings forecasts are also substantial. About 3 Mtons/yr of Carbon

<sup>&</sup>lt;sup>18</sup>Roland Haitz, Fred Kish, Jeff Tsao, and Jeff Nelson, "The Case for a National Research Program on Semiconductor Lighting" (Optoelectronics Industry Development Association, Oct, 1999).

<sup>&</sup>lt;sup>19</sup> Mark Kendall and Michael Scholand, "Energy Savings Potential of Solid State Lighting in General Lighting Applications" (U.S. Department of Energy, Office of Building Technology, State and Community Programs, Apr, 2001).

<sup>&</sup>lt;sup>20</sup> T. Taguchi, "Light for the 21st Century Year 2000 Report of Results" (The Japan Research and Development Center of Metals, 2001).



Figure 10. Market penetration and energy savings in both quads of primary energy and terawatt-hours of on-site electricity use. Note that these energy savings and market penetration estimates were based on a draft inventory of US lighting technologies. Estimates based on a revised lighting inventory are expected to be available in early 2003. Mark Kendall and Michael Scholand, "Energy Savings Potential of Solid State Lighting in General Lighting Applications" (U.S. Department of Energy, Office of Building Technology, State and Community Programs, Apr, 2001).

equivalent is saved by 2012, and about 42 Mtons/yr by 2020.

#### 0.2.2 Quality of Lighting and Human Productivity

Perhaps the second most significant, though less easily quantified, benefit will accrue as entirely new technologydriven lighting applications and a new lighting culture are created. These new applications and culture will change the way we use and interact with light.

Among the unique features that will enable these new uses are:

- Steady output color at all levels of illumination
- Ability to continuously vary output color
- Simplified and flexible design for mounting and fixtures

- Ease of integration into advanced building controls
- Low voltage and safe power distribution
- Ease of miniaturization due to the small size of the light source -- the lighting equipment would be smaller, thinner and lighter
- Simple structure -- no special devices would be needed to control the lighting equipment, and the number of components in the equipment would be reduced.
- High reliability due to the use of all-solid-state devices without any gases or filaments -- very reliable against mechanical shock.
- Flexible and efficient distribution of light -- SSL devices can be manufactured as flat packages of any shape that can be placed on floors, walls, ceilings, or even furniture, and coupled to light pipes and other distribution systems.

#### 0.2.3 National Security and other Spin-Offs

Much of the technology being developed for solid-state lighting (SSL) is based on AlGaInN materials. These materials are complex, but are the basis for many other technologies vital to national security.<sup>21</sup> These include:

- High-power electronics for wireless communications and radars. For example, synthetic aperture radars (SARs) currently rely on heavy and bulky traveling wave tubes and gimbaled antennas. These could be replaced with compact AlGaInN-based electronics and arrayed antennas, resulting in dramatic reductions in weight and opportunities for placement on smaller unmanned aerial vehicles (UAVs) that can fly longer and farther and present a smaller target to any enemy.
- Solar-blind detectors for detecting characteristic spectral signatures associated with missile launches, crucial for early-warning and treatyverification purposes. AlGaInN materials are ideally suited for these applications, since their bandgaps may be tuned across the visible and UV spectrum where the crossover between sunlight and missile-launch signatures occurs.
- UV light sources for chemical and biological

<sup>&</sup>lt;sup>21</sup> Don Cook, "National Security Applications of Solid State Lighting Technology," OIDA Solid-State Lighting Workshop (Albuquerque, May 30, 2002),

warfare agent detection. This application is perhaps the most closely related to solid-state lighting. When illuminated with deep ultraviolet (UV) light, bacteria, including anthrax, will fluoresce (re-emit light at a slightly longer wavelength) and can be detected. However, at present the sources of UV-light are heavy tabletop-sized instruments. SSL-LED technology could be used to develop much more compact deep UV LEDs and laser diodes. Indeed, the Defense Advanced Research Projects Agency (DARPA) recently announced a major initiative to develop just such UV LEDs and lasers, and to demonstrate their use in a compact prototype anthrax detector.22

- Visible and UV light sources for medical applications, spectroscopy, and photosynthesis. LEDs have been shown to emit a radiant flux high enough for photo therapy of neonatal jaundice, photodynamic therapy, and dental composite curing. And, owing to their high output power, low noise, ability to generate sub nanosecond pulses, and their simple means of high-frequency modulation, blue and UV LEDs can replace costly lasers in some applications of fluorescence excitation, including time-resolved measurements. And, finally, plant growth under completely solid-state lighting using red AlGaAs and blue InGaN chips has been demonstrated.
- Severe-environment lighting for military use. SSL-LED technology is inherently resistant to impact and vibration, to high and low ambient temperatures. Combined with its energy efficiency and compatibility with battery operation, SSL-LEDs will be the ideal lighting source for military use.

Fundamental understanding of GaN materials physics and growth chemistry underlies not only SSL-LEDs, but also these (and others not yet discovered) technologies vital to national security interests. Hence, a deeper understanding plus manufacturing volumes associated with SSL-LEDs will enable spin-off benefit to these national security applications.

# 0.3 Birth-Death Life Cycle of Photons

SSL-LED technology can be viewed from two perspectives: how it is fabricated (form), and how it performs (function). Form and function are inter-related, of course: how any technology performs depends on what can be fabricated, and what needs to be fabricated is driven by desired performance. In this Section, we introduce SSL-LED technology from the point of view of function. In the next Section, we introduce SSL-LED technology from the point of view of fabrication.

SSL-LED technology can be thought of as a birth-death lifecycle of photons. At the heart of the technology is an LED. Electricity is supplied to the LED by an external power grid. The electricity is applied as a forward current to the p-n junction of the semiconductor that forms the LED, and negatively charged electrons and positively charged holes are injected into the semiconductor. The electrons and holes are trapped in special "active" layers where they recombine, producing monochromatic photons at energies near the bandgap of the semiconductor. These photons are extracted from the semiconductor, and converted into white light. Finally, they are delivered to the environment and eventually to the human visual system.

The overall efficiency,  $\eta$ , of that lifecycle can be thought of as the product of six individual (and interconnected) efficiencies:

$$\eta = \eta_{del} \cdot \eta_{inj} \cdot \eta_{int} \cdot \eta_{tra} \cdot \eta_{ext} \cdot \eta_{conv} \cdot \eta_{illum} \qquad \text{Eq 1}$$

- η<sub>del</sub> -- the efficiency with which electrons and holes are delivered to the semiconductor
- η<sub>inj</sub> -- the efficiency with which electrons and holes are injected into the semiconductor
- η<sub>tra</sub> -- the efficiency with which electrons and holes are transported through, and trapped in, the semiconductor
- η<sub>int</sub> -- the efficiency with which electrons and holes recombine radiatively to create monochromatic photons
- η<sub>ext</sub> -- the efficiency with which the monochromatic photons are extracted from the semiconductor chip
- η<sub>conv</sub> -- the efficiency with which the monochromatic photons are converted (or mixed) to produce broadband white light
- η<sub>illum</sub> -- the efficiency with which the light illuminates the environment and, ultimately, the

<sup>&</sup>lt;sup>22</sup> John Carrano, "Semiconductor Ultraviolet Optical Sources (SUVOS)," http://www.darpa.mil/mto/suvos/ (2002).

human eye

In principle, these efficiencies, and that of the overall life cycle, may be nearly perfect. In practice, there are numerous opportunities for inefficiencies, and numerous challenges associated with reducing these inefficiencies.

# 0.3.1 Delivering electrons from the power grid

The first step is delivering electrical current to the SSL-LED light fixture.

Because the forward bias on a semiconductor LED is typically a few volts, the electrons must be delivered in the 2-5V range. Because a useful output optical power for illumination is of the order 10W per fixture, and electrical-to-optical conversion efficiencies will be of the order 10-50%, the delivered currents must be of the order (10W/4V)/0.25, or 10A. And, because the semiconductor is an asymmetric p-n junction, the voltage must be DC rather than AC. These voltages and currents are very different from those associated with traditional 110V and 220V AC power systems.

Hence, a general challenge will be the development of efficient power distribution or transformation systems for high (>10A) DC currents and low (<5V) DC voltages.

# 0.3.2 Injecting electrons and holes into the semiconductor

The second step is injecting electrons and holes from metal contacts into the n- and p-sides of the semiconductor.

Because of the high currents and low voltages associated with SSL-LEDs, the metal-semiconductor contact must have a very low resistance. However, low-resistance contacts usually require high doping densities in the semiconductor, and the wider the bandgap of the semiconductor, typically the more difficult to dope. For semiconductors with bandgaps corresponding to visible and UV light, this is a serious issue.

Hence, a general challenge will be the development of low resistance metal-semiconductor contacts with virtually no parasitic ohmic losses during electron or hole injection.

In addition, it is likely to be necessary to inject high densities of electrons and holes, to produce the highest number of lumens per unit chip area, and hence to reduce the lumens cost per unit chip area. However, a balance will need to be struck between higher injection densities, which will enable lower cost but at the expense of high operating temperatures and possibly lower performance; and lower injection densities, which will enable lower operating temperatures and possibly higher performance at the expense of higher cost.

<u>Decision</u>: Will the SSL-LED chip "engine" be driven at low input power densities with low cost/cm<sup>2</sup> and  $T_{oper}$ , or will it be driven at high input power densities at high cost/cm<sup>2</sup> and  $T_{oper}$ ?

# 0.3.3 Transporting and trapping the electrons and holes

The third step is transporting electrons and holes through the body of the semiconductor material, and then trapping them in regions where they can recombine and emit light.

Because transport and trapping require very different kinds of semiconductor materials properties, devices are generally constructed from sequences of epitaxial layers, each of which performs different functions. And, because radiative recombination is faster the more the electrons and holes overlap in space, the epitaxial layers used for trapping will often be bandgap nanostructures of low dimensionality (quantum wells, wires and dots).

Hence, a general challenge will be the development of uniform, precise epitaxial bandgap nanoengineering that enables efficient vertical and lateral electron and hole transport without ohmic loss, as well as efficient trapping of those electrons and holes.

#### **0.3.4 Creating photons**

The fourth step is recombining of the electrons and holes to produce photons.

However, electrons and holes may also recombine in ways that do not lead to photons, particularly in materials with structural defects, such as impurities, dislocations, or grain boundaries. Some defects (e.g., dopant impurities), are deliberately introduced to enhance other properties; others are caused by imperfections in the starting substrates, in the epilayers, or in mismatches between the substrate and the epilayers.

Hence, a general challenge will be the development of near-perfect semiconductor substrates, buffers and epimaterials, or imperfect epi-materials with artificial nanostructures, for which radiative recombination dominates nonradiative recombination (by at least 10x).

		C C C C C C C C C C C C C C C C C C C
A. The wavelength conversion approach, in which white light is created by using a single UV LED to excite a tri-color phosphor.	B. The color mixing approach, in which white light is created by mixing primary light from three LEDs (red, green, blue).	C. A hybrid approach, in which white light is created by mixing primary light from a blue and/or red LED with light created by using the blue LED to excite a mono- or duo- color phosphor.

#### 0.3.5 Extracting photons from the chip

The fifth step is extracting photons from the semiconductor material.

In an LED with a planar, unstructured top surface, much of the light that is emitted randomly in all directions from inside the semiconductor is totally internally reflected and never escapes. Practical high-brightness LEDs are therefore either non-planar, where the chip and its surfaces have been shaped or textured, or engineered so that light is not emitted randomly from inside the semiconductor.

Even then, it is difficult to extract all of the light. Indeed, for one material (AlGaInP) in the deep red, even though the process of creating photons is essentially 100% efficient, the overall power conversion efficiency from the best chip-shaped devices is still only 50%, due primarily to the remaining inefficiency in the process of extracting the light.

Hence, a general challenge will be the development of optimized light emission pattern and overall chip shape for high (>95%) efficiency photon extraction from the chip.

# 0.3.6 Transforming monochromatic into white light

The sixth step is transforming the narrowband emission that results from radiative recombination in the semiconductor into broadband white light.

Such white light can be generated by three general approaches, illustrated in Figure 11. The first is the wavelength-conversion approach; the second is the color-

mixing approach; and the third is a hybrid between the two. It is yet to be determined which approach will ultimately provide the best cost/performance tradeoff – at present, they each have strengths and weaknesses, and they each face different challenges.

Figure 11. The three possible approaches to white-light production. Courtesy of S. Nakamura (UCSB) and Paul Martin (LumiLeds).

Because the choice of approach is so fundamental, we will refer to them throughout this Roadmap. We attach to every Challenge discussed the abbreviation "WC" if it pertains to the wavelength-conversion approach, "CM" if it pertains to the color-mixing approach, or "Hy" if it pertains to the Hybrid approach. As technology progresses, one approach may "win," and the Challenges associated with the other approaches will disappear. However, it is also possible that different approaches will be preferred for different applications, and that all the Challenges will persist.

Decision: Will SSL-LED white light production be through a wavelength conversion, color mixing, or a hybrid approach?

Related to the question of which approach to white light production is the question of how many colors, and in what wavelength ranges, are best suited to SSL-LED technology. This is a complex issue, determined by a balance between three constraints: creating pure white (with a wide latitude for color temperature tuning), a high color rendering ability, and a high luminous efficacy.

Decision: How many colors (and in what wavelength ranges) will best balance the three constraints of pure white, high color rendering and high luminous efficacy?

6A Wavelength Conversion Approach. The first approach for transforming narrowband emission into broadband white light involves using UV LEDs to excite that emit light at down-converted phosphors wavelengths.<sup>23</sup> In general, this approach is likely to be the lowest cost, because of its low system complexity (only a single LED chip, and since the colors are created already blended, lamp-level optical and color engineering is minimized). It is also likely to be the least efficient, because of the power-conversion loss associated with the wavelength down-conversion; and the least flexible, since the colors are "preset" at the factory.

<sup>&</sup>lt;sup>23</sup> Thomas Justel, Hans Nikol, and Cees Ronda, U.S. Philips Corporation, "White light emitting diode," Patent Number US 6084250 (Jul 4, 2000).

Hence, a general challenge will be the development of UV (340-380nm) LEDs with high (>70%) external powerconversion efficiency and input power density, and multicolor phosphor blends with high (>85%) quantum efficiency.

<u>6B Color Mixing Approach</u>. The second approach for transforming narrowband emission into broadband white light is to combine light from multiple LEDs of different colors.<sup>24</sup> In general, this approach is likely to be the most efficient, as there are no power-conversion losses associated with wavelength down-conversion. It is also likely to be the most flexible, since the hue of the light can be controlled by varying the mix of primary colors, either in the lamp, or in the luminaire. However, it is also likely to be the most expensive, because of its high system complexity (multiple LED chips, mixing of light from separate sources, and drive electronics that must accommodate differences in voltage, luminous output, element life and thermal characteristics among the individual LEDs).

Hence, a general challenge will be the development of red, green and blue LEDs with high (>50%) external power-conversion efficiencies and input power density, and low-cost optics and control strategies for spatially uniform, programmable color-mixing either in the lamp or in the luminaire.

6C Hybrid Approach. The third approach for transforming narrowband emission into broadband white light is a hybrid approach. The present generation of white LEDs, with luminous efficacies of 25 lm/W, is based on this approach. Primary light from a blue (460nm) InGaNbased LED is mixed with blue-LED-excited secondary light from a pale-yellow YAG:Ce3+-based inorganic phosphor. The secondary light is centered at about 580 nm with a full-width-at-half-maximum line width of 160 nm. The combination of partially transmitted blue and reemitted yellow light gives the appearance of white light at a color temperature of 8,000 K and a luminous efficacy of about 25 lm/W. This combination of colors is similar to that used in black-and-white television screens - for which a low-quality white intended for "direct" rather than "indirect" viewing - is acceptable.

Other variations of this approach are possible. The simplest extension would be to mix blue LED light with light from a blue-LED excited green and red duo-color phosphor blend<sup>25</sup> – this variation is likely to be give the best balance between efficiency, color quality, cost and system complexity. A more complex but perhaps more efficient extension of this approach would be to mix blue and red LED light with light from a blue-LED excited green phosphor.<sup>26</sup>

In general, this approach is intermediate amongst the three approaches in efficiency, complexity and cost. It is likely to be intermediate in efficiency, as power-conversion losses from wavelength down-conversion are less from the blue than from the UV, but still greater than no powerconversion losses. It is likely to be intermediate in cost and system complexity, as only one (or at most two) LEDs is used, but light from the LED must still be color-mixed with light from the phosphor.

Hence, a general challenge will be the development of blue LEDs with high (>60%) external power-conversion efficiencies and input power density, blue-excitable duo-color phosphor blends with high (>80%) quantum efficiency, and low-cost optics for spatially uniform colormixing in the lamp.

#### 0.3.7 Delivering light to the viewer

The seventh and final step is delivery of the white light that has been generated, first to that part of the environment that is to be illuminated, and then to the viewer.

SSL-LEDs have many advantages in this regard. Because they are point sources, they can deliver directed light more efficiently to small areas. Their compactness enables more flexibility in the design of unobtrusive and architecturally blended luminaires. Their ruggedness enables them to be mounted in high-stress positions. And, it may be possible to program their color and direction for optimal interaction with the human visual system. However, we are at a very early stage in understanding how to make use of these advantages.

Hence, a general challenge will be the development of luminaires and lighting systems that convert intense point sources to diffuse light suitable for large-area illumination, which blend into the human workplace, and which enhance human productivity and comfort.

<sup>&</sup>lt;sup>24</sup> M. Koike, N. Shibata, H. Kato, and Y. Takahashi,

<sup>&</sup>quot;Development of High Efficiency Gan-Based Multiquantum-Well Light-Emitting Diodes and Their Applications," IEEE Journal of Selected Topics in Quantum Electronics 8 (2002) 271-277.

<sup>&</sup>lt;sup>25</sup> Christopher H. Lowery, Gerd O. Mueller, and Regina B. Mueller-Mach, Lumileds Lighting U.S., LLC, "Phosphor and White Light LED Lamp Using the Phosphor," Patent Number EP1145282A2 (Oct 17, 2001).

<sup>&</sup>lt;sup>26</sup> Tetsushi Tamura, Hideo Nagai, Masanori Shimizu, Yoko Shimomura, and Nobuyuki Matsui, Matsushita Electric Industrial Co., Ltd., "LED Lamp," Patent Number EP1160883A2 (Dec 5, 2001).

## **0.4 Technology Building Blocks**

In Section 0.2, we discussed SSL-LED technology from the point of view of Function – the birth-death lifecycle of photons. In the remainder of this Roadmap, we will discuss SSL-LED technology from the point of view of Fabrication.

We break this Fabrication down into three overall building blocks:

- 1. Substrates, Buffers and Epitaxy
- 2. Physics, Processing and Devices
- 3. Lamps, Luminaires and Systems

These overall building blocks, in turn, are composed of many individual sub-building blocks. Each sub-building blocks can be thought of as a Challenge Area in which a significant technical challenge must be overcome in order to meet our SSL-LED targets.

We argued, in Sections 0.3 and 0.4, that our SSL-LED targets are physically reasonable and consistent with our

knowledge of fundamental physics and with other, more mature, semiconductor manufacturing technologies. Nevertheless, solid-state lighting is in its infancy, just as silicon integrated circuits were in their infancy two decades ago. Hence, there are many significant Challenge Areas associated with the various building blocks.

The Challenge Areas themselves are discussed in the remaining Chapters 1-3. For each Challenge Area, we give a brief background discussion, followed by a succinct and as-quantitative-as-possible description of the Challenge associated with the Challenge Area, finally followed by Possible Approaches to surmounting them.

For each Challenge, we specify which of the three approaches to white light production (wavelength conversion, color mixing, or hybrid) it will have impact on. We also indicate the High-Medium-Low risk and reward scores discussed above. Also, unless otherwise specified, whenever we refer to quantitative target in a Challenge, we refer to Year 2012 (10-year) targets.
## **1** SUBSTRATES, BUFFERS AND EPITAXY

Two semiconductor materials systems are the focus of most attention for solid-state lighting: AlGaInN (the column-III nitrides), and AlGaInP (the column-III phosphides). These are the only known semiconductor materials with the following combination of properties required for solid-state lighting:

- Their band-gaps span the range appropriate for visible and near-UV light emission, and perhaps most importantly are direct rather than indirect, and hence emit light efficiently. The AlGaInP materials span the range from the deep red to the yellow-green; the AlGaInN materials span the range from the yellow-green (and potentially the red) to the UV.
- They represent families of materials that can be composition tailored into nanostructures optimized for electron and hole injection, transport, and radiative recombination.
- They are robust enough to withstand semiconductor fabrication processes as well as operation under high-current-density high-stress conditions.

Both of these materials systems are examples of so-called III-V compound semiconductors: combinations of elements from columns III and V in the periodic table. The phosphides are a relatively mature material, while the nitrides are a relatively immature material. Hence, particularly for the nitrides, there are many fundamental physics issues related to materials and nanostructures that are poorly understood.

The two semiconductor families enter into SSL-LED technology in different ways. The brightest and mostefficient light emitters in the red are fabricated from AlGaInP, while those in the green, blue and UV are fabricated from AlGaInN. It is possible that bright, efficient light emitters in the red will someday be fabricated from AlGaInN. If so, having a common materials platform for all three colors could greatly simplify the color-mixing approach to white-light production considerably.

In the absence of such a breakthrough, though, AlGaInP is important mainly for providing red in the color-mixing approach to white-light production, while AlGaInN is important in all approaches to white-light production. Hence, if the color-mixing approach to white-light production emerges as the winner, then AlGaInP is likely

to remain, along with AlGaInN, a critical semiconductor. If the wavelength-conversion approach to white-light production emerges as the winner, then only AlGaInN will remain a critical semiconductor.

#### <u>Decision</u>: Which semiconductor materials family will form the basis for the SSL-LED chip "engine" -- AlGaInN only, or a combination of AlGaInP and AlGaInN?

In this Chapter, we discuss the challenges associated with the "front-end" fabrication of these semiconductor materials: substrates, buffers and epitaxy.

For AlGaInP materials, this front-end fabrication is now reasonably mature. There exists a high-quality, relatively low cost (\$5/cm<sup>2</sup>), commercially available substrate, GaAs, to which they are well matched chemically, crystallographically and structurally. And, there exist production OMVPE tools for high-volume, high-precision, high-uniformity AlGaInP epitaxy at relatively low cost (\$15/cm<sup>2</sup>).

These front-end costs are low enough that there is no pressing need for further development of substrates and epitaxy. Even if substrate cost were to become an issue, even-lower-cost Ge substrates (roughly \$3/cm<sup>2</sup>) should be possible to use. And, the OMVPE tools are very similar to those used for mainstream GaAs and InP compound semiconductor epitaxy, hence epitaxy costs will continue to be driven down in response to demand for GaAs-based epitaxy.

For AlGaInN materials, this front-end fabrication is in its infancy. There does not yet exist a commercial technology for low-defect-density single-crystal substrates of GaN. If such a technology were to be developed, there is no doubt that it would provide the best substrate for subsequent AlGaInN device epitaxy.

In the absence of this technology, however, virtually all AlGaInN SSL-LEDs are currently grown on relatively poorly matched sapphire (Al2O3), silicon carbide (SiC) or silicon (Si) substrates. The extents of the mismatches are listed in Table 4. As a consequence, it has been necessary, in the interim, to develop "buffers." These buffers bridge the mismatches, with the final product being a surface whose crystallography and lattice constant match that of the device that will be grown on top, and which is as structurally perfect (and low cost) as possible.

Substrate	Lattice Mismatch	Thermal Expansion
		Mismatch
Sapphire	+16%	+39%
SiC	-3.5%	-3.2%
Si	+17%	-56%

Table 4. Lattice and thermal expansion mismatches betweenGaN and the most commonly used substrates.

Current buffers are relatively thin  $(1-5 \ \mu ms)$  and, though still highly defective (1e6-1e7 defects/cm<sup>2</sup>), have been adequate for moderate-efficiency light-emitting devices driven at moderate (<100W/cm<sup>2</sup>) input power densities. However, for high-efficiency light-emitting devices driven at high input power densities, it is believed that defect densities must be decreased by roughly two more orders of magnitude.

This may be possible with evolutionary advances in thinbuffer technology. However, it is more likely to require revolutionary advances in buffer technology – e.g., thick (20-200  $\mu$ ms) buffers subsequently removed from their original substrate.

There has been speculation in the past that with suitable engineering and nanostructuring of the device epitaxy (e.g., using quantum dots), this low structural quality could be "worked around." Indeed, there is some justification to this view, since the current generation of quantum-dotbased AlGaInN devices perform well despite being highly defective compared to common experience with AlGaInP



Figure 12. Schematic of dependence of luminescence efficiency of various compound semiconductor materials on dislocation density. After Shuji Nakamura, "Status of GaN LEDs and Lasers for Solid-State Lighting and Displays," OIDA Solid-State Lighting Workshop (Albuquerque, May 30, 2002), modified and augmented from S. D. Lester, F. A. Ponce, M. G. Craford, and D. A. Steigerwald, "High dislocation densities in high-efficiency GaN-based light-emitting diodes," Appl. Phys. Lett. 66 (1955) 1249.

or AlGaInAs devices.

Nevertheless, as illustrated in Figure 12, a growing body of work indicates that dislocations, nanopipes, and other mismatch-related structural defects do have ill Among these consequences: consequences. metal migration along the defects possibly leading to long term degradation; defect-mediated non-radiative recombination of electron-hole pairs; enhanced Coulomb scattering (and reduced mobility) of carriers due to charged dislocations. Hence, structural quality and low-defect-density buffer layers are now widely viewed as extremely important.

Moreover, if defects could be eliminated, it might not be necessary to rely on quantum-dot-like composition nonuniformities that in current devices localize electrons and holes away from the defects. Then, compositionally uniform structures could be used, with potential advantages such as enhanced carrier transport, narrower line widths and higher gain for stimulated emission devices.<sup>27</sup>

Hence, the common goal of the Challenges associated with Section 1.1 (Substrates) and 1.2 (Buffers) is to create a low-defect-density substrate or substrate+buffer combination that is lattice and thermal-expansion matched to AlGaInN epimaterials.

Decision: Which low-defect-density substrate or substrate+buffer combination will form the basis for epitaxial AlGaInN devices: Native GaN, Sapphire/SiC + Buffer, or Removable GaN?

Once a starting substrate or substrate+buffer combination has been created, the next step in the frontend fabrication sequence is epitaxy. All modern, highperformance light-emitting optoelectronic devices rely on bandgap-engineered epitaxially layered materials to control electrons, and holes, and photons. Indeed, the history of semiconductor optoelectronics can be viewed as the development of an understanding of how layered materials can be used to control electrons, holes and photons, and how epitaxy can be harnessed to create those layers.

Again, epitaxy of AlGaInP materials is relatively mature, while epitaxy of AlGaInN materials is relatively immature. In Section 1.3 we discuss epitaxy tools and processes, with a focus on AlGaInN materials.

<sup>&</sup>lt;sup>27</sup> S. Srinivasan, F. Bertram, A. Bell, F. A. Ponce, S. Tanaka, H. Omiya, and Y. Nakagawa, "Low Stokes shift in thick and homogeneous InGaN epilayers," Applied Physics Letters 80 (2002) 550-2.

## **1.1 Substrates**

In this Section we discuss the starting substrates. As discussed above, substrates for the AlGaInP materials system are relatively well-established. GaAs substrates are approximately \$5/cm<sup>2</sup>, only 5% of our target chip cost, and Ge substrates are even less expensive. Hence, we focus our attention on substrates for the AlGaInN materials system.

At this stage, there are three substrates being considered.

Challenge 1.1.1 discusses bulk GaN and AlN, which would be a perfect or nearly-perfect chemical, crystallographic, lattice-constant, and thermal-expansion match to AlGaInN.

Challenge 1.1.2 discusses sapphire, which is a substrate relatively "unmatched" to AlGaInN, but on which there has been considerable success at growing buffer layers on which epitaxial devices may be subsequently grown. This substrate is also relatively inexpensive, approximately \$10/cm<sup>2</sup>, or 10% of our target chip cost.

Challenge 1.1.3 discusses silicon carbide, which is a substrate better matched to AlGaInN than sapphire, but, at  $40/\text{cm}^2$ , is relatively expensive.

A final interesting substrate is silicon. This substrate is a much poorer match to AlGaInN materials than either sapphire or silicon carbide, by a substantial amount, so high-performance devices have not yet been demonstrated from material grown on Si. Nevertheless, as discussed in Section 1.2, many groups are pursuing this possibility, and there have been some successful demonstrations of GaN films and device structures on Si wafers having diameters as large as four inches. If successful, an AlGaInN on silicon substrate technology would be extremely exciting. It would take advantage of the maturity and low-cost of silicon substrate technology, as well as the possibility of integration with other advanced Si-based device technologies, such as MEMs and CMOS.

## 1.1.1 GaN and AIN

As noted above, perhaps the most defining feature of the AlGaInN materials system is the lack of commercially available GaN or AlN substrates that are chemically, crystallographically, lattice-constant, and thermal-expansion matched to the desired device materials. Indeed, it is surprising that AlGaInN materials have come so far so fast without such a matching substrate.

If such a substrate were available, spectacular results are likely. Defect densities in the range of  $10^3/\text{cm}^2$  would be expected, compared with typical defect densities in the range of  $10^9$  to  $10^{10}/\text{cm}^2$  for AlGaInN materials grown on

sapphire. Moreover, bulk GaN and AlN have higher thermal conductivities than sapphire substrates, and could improve thermal management of chips driven at high input power densities.

Unfortunately, the growth of bulk GaN or AlN substrates is in its infancy, with only preliminary results and limited success. It is impossible to employ well-known methods such as Bridgman or Czochralski for GaN bulk crystal growth on account of the extremely high melting temperatures (2800K) and nitrogen vapor pressures (over 45kbar) required. Hence, other approaches are, and will need to be, explored.

<u>Recommendation</u>: Develop technology for high (<1e4 defects/cm<sup>2</sup>) quality, moderate (<\$25/cm<sup>2</sup>) cost GaN or AlN substrates.

Impact=WC+CM+Hy; Risk=H; Reward=H.

#### Possible Approaches:

#### High-Pressure Solution Growth.

The most intensely explored approach to date is High-Pressure Solution Growth (HP-SG).<sup>28</sup> This technology is based on solution growth of GaN from molten gallium at temperatures in the range 1400-1500C, using nitrogen overpressures of typically 10 kbar. This growth technology has largely been developed at the High Pressure Research Center in Warsaw. This approach faces challenges related to growth rate, limited solubility of N in liquid Ga, crystal size, quality, and purity, but the most significant may be slow growth rates: on the order 0.01mm/hr, so that growing even small (1 cm diameter) crystals requires many days.

Low-Pressure Solution Growth.

A new approach, similar to the HP-SG method, is the Low-Pressure Solution-Growth (LP-SG) approach.<sup>29</sup> This method has not yet been disclosed in its entirety, but it involves growth of GaN ingots from a Ga-based metal solution in the temperature range of 800-1000C at less than 2 atmospheres ambient pressure. Preliminary studies of growth on graphite seeds gave growth rates of ~2 mm/hr, 10x faster than for the HP-SG approach, and boules about

<sup>&</sup>lt;sup>28</sup> S. Porowski, "Near Defect Free GaN Substrates," MRS Internet Journal of Nitride Semiconductor Research 4(S1) (1999) U32-U42.

<sup>&</sup>lt;sup>29</sup> V. A. Sukhoveyev, V. A. Ivantsov, I. P. Nikitina, A. I. Babanin, A. Y. Polyakov, A. V. Govorkov, N. B. Smirnov, M. G. Milvidskii, and V. A. Dmitriev, "GaN 20-Mm Diameter Ingots Grown From Melt-Solution by Seeded Technique," MRS Internet Journal of Nitride Semiconductor Research 5(S1) (2000) U376-U381.

20 mm in diameter and 15 mm long. However, the ingot was not single crystal, but polycrystalline with a [1011] preferred orientation. Hence, a significant challenge will be developing approaches that enable single-crystal growth from GaN seeds.

Other groups have demonstrated growth of GaN from different metal solutions. Small (~3 to 5 mm diameter) but high quality GaN platelets have been grown from Na solutions.<sup>30</sup> Recently, a 25-mm diameter platelet of GaN, grown with less than 10<sup>5</sup> dislocations/cm<sup>2</sup> at 1 GPa by Japan Energy and Yamaguchi University, has been reported.

## Pressure-Controlled Solution Growth.

Another variant of the solution growth approach is the so-called Pressure-Controlled Solution Growth (PC-SG) approach.<sup>31</sup> Whereas in the HP-SG method the driving force for crystal growth is a temperature differential, under the PC-SG method, the driving force is a pressure differential. A supersaturated state is obtained by holding the system at a constant temperature, followed by raising the pressure of the system. Continuous crystal growth is continuously supplied during crystal growth. GaN single crystals with diameters on the order of 20.6 mm have been demonstrated, along with defect densities below 10<sup>5</sup> cm<sup>-2</sup>.

## Vapor Transport Growth.

Growth of high quality bulk AlN crystals has been demonstrated via physical vapor transport (PVT) where high purity AIN is sublimed and recondensed on the growing crystal. This technique uses a growth temperature of approximately 2200°C at atmospheric pressure. Single crystal boules that are 15mm in diameter and several centimeters long have been demonstrated with this technique with growth rates exceeding 0.5mm/hr and dislocation densities below 103 cm<sup>-2</sup>. While larger diameter boules have also been demonstrated, there is currently a problem with cracking that needs to be solved before technologically useful, large diameter AlN substrates will be available. Other groups<sup>32</sup> have attempted similar processes using liquid Al as the source. PVT appears to be the preferred approach for growth of bulk AlN. The AlN substrate will be ideal for UV optical sources (which will require high Al concentration so that the growth of device layers will be almost homoepitaxial) but suffers from the disadvantage of being insulating and having a lattice parameter that is 2.4% smaller than pure GaN. Visible optoelectronic emitters will need In<sub>x</sub>Ga<sub>1-x</sub>N structures that have lattice parameters that are slightly larger than that of GaN. On the other hand, many of the current heteroepitaxial techniques use a buffer layer of AlN before they start GaN growth and is a better lattice match than SiC which is little smaller.

A similar approach<sup>33</sup> has been attempted for bulk growth of GaN using liquid Ga and N<sub>2</sub> at one atmosphere and ~1100°C. Close space sublimation methods (though one issue is cost of GaN powder); High rate sputter deposition at low pressures and temperatures;

Another approach currently being explored does not make use of liquid solutions at all, but rather uses lowpressure gas phase growth.<sup>34</sup> The key is to do this in a way that does not depend, as do OMVPE and HVPE, on expensive and environmentally harmful source materials. This technique is based on a pseudo-open tube design that uses subliming Ga and plasma-activated N<sub>2</sub> gases as the source materials. This approach is in its early stages of development, but growth rates of 1-6 mm/hr are anticipated based on theory.

## Ammonothermal Approach

Another approach<sup>35</sup> is ammonothermal growth under liquid ammonia. This could potentially produce very pure GaN single crystals in a low temperature process. While significant<sup>36</sup> transport has been demonstrated, only sub millimeter size crystals have been demonstrated. This technique is similar to the hydrothermal technique that is used commercially to produce quartz crystals.

## 1.1.2 Sapphire

Since the demonstration of reasonably-high-quality GaN and AlN buffer layers on sapphire, sapphire has become the dominant substrate for AlGaInN devices. Although

 $<sup>^{30}</sup>M.$  Aoki, "Growth of GaN crystals from a Na-Ga melt at 750C and 5 MPa of  $N_{\rm 2}$ ," Journal of Crystal Growth 218 (2000) 7.

<sup>&</sup>lt;sup>31</sup> T. Taguchi, "Light for the 21st Century Year 2000 Report of Results" (The Japan Research and Development Center of Metals, 2001).

<sup>&</sup>lt;sup>32</sup>R. Schlesser, R. Dalmau, and Z. Sitar, "Seeded growth of AlN bulk single crystals by sublimation," Journal of Crystal Growth 241 (2002) 416.

<sup>&</sup>lt;sup>33</sup> Robert F. Davis, "Alternative Substrates for III-Nitride LED Structures," OIDA Solid-State Lighting Workshop (Albuquerque, May 30, 2002).

<sup>&</sup>lt;sup>34</sup> T. Taguchi, "Light for the 21st Century Year 2000 Report of Results" (The Japan Research and Development Center of Metals, 2001).

<sup>&</sup>lt;sup>35</sup> Robert F. Davis, "Alternative Substrates for III-Nitride LED Structures," OIDA Solid-State Lighting Workshop (Albuquerque, May 30, 2002).

<sup>&</sup>lt;sup>36</sup>D. R. Ketchum and J. W. Kolis, "Crystal Growth of GaN in Supercritical Ammonia," Journal of Crystal Growth 222 (2001) 431.

similar buffer layers can now be grown on a few other substrates (e.g., SiC, as discussed in Challenge 1.1.3), these other substrates are quite expensive compared to sapphire.

Because of its many other uses, including "transparent armor," optical windows, and silicon-on-sapphire, the technology for manufacturing sapphire substrates is relatively mature. The current commercial process are the Czochralski (Union Carbide) and edge-defined film-fed (EFG) growth processes (Kyocera). Wafers are available at roughly \$5-10/cm<sup>2</sup>, which is already within the range required for our chip cost targets.

The major challenges are a desire to scale to somewhat larger wafer sizes (4" to 6"), to reduce impurities (e.g., Ti), and to improve the quality of the surface finish and polish.

<u>Recommendation</u>: Develop technology for manufacturing larger ( $\geq 6$ "), cheaper ( $\leq $5/cm^2$ ), better surface-finish (0001) sapphire substrates.

Impact=WC+CM+Hy; Risk=L; Reward=L.

#### Possible Approaches:

#### Scale-up of traditional growth processes.

The most likely approach will be simple scale-up of conventional Czochralski or edge-defined ribbon growth processes.

#### Heat-exchanger method

Another approach is the so-called heat-exchanger method (HEM), in which heat extraction during crystal growth is carefully controlled, independent of the heat input.<sup>37</sup> Using this process, sapphire crystals as large as 34 cm in diameter, in 65 kg boules, have been grown, and efforts are now underway to produce 50-cm-diameter boules. In this approach, purity may be an issue, as impurities such as titanium are used to facilitate growth and to strengthen the boules; and it is not clear what their impact on device performance will be. Also, in this approach, boules are at present mainly grown in the 1010 or 1120 orientations (for optical windows) or in the 1102orientation (for silicon-on-sapphire). For the wurtzite crystallography of the AlGaInN materials system, it is necessary to have substrates within 0.15° of the (0001) orientation. This orientation is more difficult to grow with high quality, possibly due to the weakening action of the main glide system [25], and because it is the close packed direction. Instead, this orientation is created by cutting non-(0001)-grown boules orthogonal to their growth axis, which adds to the cost.

## 1.1.3 SiC

Just as with sapphire, it is possible to grow reasonablyhigh-quality buffer layers of GaN or AlN on SiC substrates. These buffers are slightly better in quality than those on sapphire, because of the smaller lattice mismatch. And, because SiC substrates may be electrically conducting, they enable bottom-of-substrate electrical contact, which simplifies device design and is consistent with the industry standard vertical chip single wire bond structure, quicker LED assembly, reduced manufacturing costs and improved Also, SiC has somewhat better thermal reliability. conductivity than GaN or AlN (350W/m-K for typical conducting SiC vs. 230 W/m-K for GaN and 320 W/m-K for AIN), so this substrate is even better for sinking heat. But, SiC is also absorbing at wavelengths shorter than 380nm in the UV, so for the wavelength conversion approach something would need to be done to avoid this absorption.

The current state-of-the-art manufacturing technology involves physical vapor transport (PVT) via seeded sublimation.<sup>38</sup> At growth temperatures of 2200–2500°C a temperature gradient is established across the growth cell, which is in an inert gas ambient (e.g. Ar, He or N2). The gradient acts as a driving force for the sublimation of the SiC source material, the transport of the SiC species through the vapor phase and the crystallization on a SiC seed.

Continuous improvements of this technique have led to the industrial production of 50–75-mm diameter 6H and 4H wafers and the demonstration of high quality 100-mm wafers.

The main limitations are:

- Cost. Sublimation-grown substrates are currently quite expensive (\$2000 for a 2" diameter wafer, or 100\$/cm<sup>2</sup>). Costs need to come down by nearly an order of magnitude, to \$10-20/cm<sup>2</sup>!)
- Defects. Defects are perhaps the most significant issue, and among these defects, so-called micro pipes are the most harmful. These micro pipes are associated with dislocations, hence depend strongly on temperature gradients and thermal

<sup>&</sup>lt;sup>37</sup> Chandra P. Khattak and Frederick Schmid, "Growth of the world's largest sapphire crystals," Journal of Crystal Growth 225 (2001) 572-579.

<sup>&</sup>lt;sup>38</sup> St. G. Muller, R. C. Glass, H. M. Hobgood, V. F. Tsvetkov, M. Brady, D. Henshall, D. Malta, R. Singh, J. Palmour, and C. H. Jr. Carter, "Progress in the industrial production of SiC substrates for semiconductor devices," Materials Science and Engineering B80 (2001) 327-331.

1.2 Buffers

stresses during growth. The density of these micro pipes has steadily decreased over the past several years, down to densities as low as 1.1/cm<sup>2</sup> for an entire 50-mm wafer, and it may be possible to totally eliminate micro pipes in the next few years. However, eliminating dislocations will be much more challenging – these are still at the 1e3/cm<sup>2</sup> level.

Impact=WC+CM+Hy; Risk=M; Reward=L.

Possible Approaches:

Close-spaced sublimation growth.

The most likely approach will be continuing improvement and evolution of the close-spaced sublimation growth method.

## **1.2 Buffers**

In this Section we discuss the second stage in the substrate engineering process: growth of a buffer layer on an imperfectly-matched starting substrate. For the dominant current AlGaInN device technology, which relies on growth of GaN layers grown on c-plane sapphire, this buffer may well be the most important step in the realization of device quality GaN material.

The purpose of this buffer layer is to transition from the lattice constant or crystallography of the starting substrate so that it is compatible with the AlGaInN wurtzite alloys used for device epitaxy.

The primary issue is misfit dislocations, which must be present to accommodate the lattice mismatch between substrate and layer. These misfit dislocations, when extending into the layers above, form threading dislocations that affect electronic and optical properties. A secondary issue is micro cracking, which results from high residual strains upon cooling to room temperature due to a difference in thermal expansion coefficients between substrate and over layer.

There are a number of competing technologies for growing buffers, and each faces different Challenges.

Challenge 1.2.1 discusses technologies for growth of simple thin buffers, for which no wafer patterning or special processing are performed prior to buffer growth. These are the least expensive buffers, but the dislocation density remains substantial.

Challenge 1.2.2 discusses growth of "complex" buffers, for which patterning or special processing is performed prior to buffer growth. These buffers employ a combination of vertical and lateral growth of GaN-based films through and over patterned oxide or nitride films deposited on a GaN film previously grown on sapphire, SiC or Si.. These techniques are variously referred to as epitaxial lateral overgrowth (ELO or ELOG) or lateral epitaxial overgrowth (LEO). These complex buffers result in a substantial reduction in the density of dislocations; however, they require one or two insertions into the thin film growth sequence that increases the cost.

Challenge 1.2.3 discusses technologies for growth of thick buffers, followed by special processing performed afterwards to transfer the buffer to another substrate, or to create a free-standing buffer through substrate removal.

## **1.2.1 Thin GaN Buffers**

AlGaInN device technology is currently based on GaN or AlN buffers first grown by OMVPE on sapphire or silicon carbide, followed by epitaxy of AlGaInN device layers. Indeed, the demonstration by Amano and Akasaki in the late 1980's that reasonably high quality buffer layers were possible on sapphire is arguably one of the two pivotal breakthroughs (in addition to p-type doping) that triggered subsequent progress in device and SSL-LED technologies.

Both GaN and AlN buffers have been demonstrated, although GaN buffer layers appear to be somewhat superior, at the expense of somewhat greater process sensitivity related to the lower temperature (450–600C) necessary for the GaN buffer growth, and its tendency to partially desorb as the temperature is raised to the final growth temperature.

Buffers have been demonstrated on sapphire, silicon carbide and silicon.

The current state-of-the-art in buffer layer formation on sapphire consists of a so-called two-step epitaxy.<sup>39</sup> A low-temperature GaN nucleation layer (NL) is deposited first, followed by a high temperature (HT) GaN overgrowth. The NL consists of faceted crystalline islands that exhibit a spread in rotation about the (0001) axis. The lateral growth during HT deposition of GaN occurs preferentially in certain "growth patches", which grow vertically and

<sup>&</sup>lt;sup>39</sup> V. Narayanan, K. Lorenz, Wook Kim, and S. Mahajan,

<sup>&</sup>quot;Gallium nitride epitaxy on (0001) sapphire," Philosophical Magazine A 82 (2002) 885-912.

laterally over the underlying sub grains. The coalescence of these patches produces a continuous GaN layer. The best threading dislocation densities are still rather high  $(1e9/cm^2)$ , though this is surprisingly low given the significant mismatch between GaN and sapphire.

The scenario for silicon carbide is thought to be similar. The main difference is that the lattice mismatch is significantly less. Hence, coalescence of GaN islands (followed by layer-by-layer growth) occurs within the first several hundred angstroms of growth, as opposed to the first several thousand angstroms of deposition in the case of sapphire. And, buffer layers on SiC substrates also have somewhat lower defect densities than those on sapphire, and this result combined with the added benefit of an electrically conducting substrate has led to a significant use of this buffer layer technology for commercial devices on SiC. Unlike in the case of sapphire, though, the buffer layers on SiC must be electrically conducting, in order to take best advantage of the conductivity of the SiC itself. This typically requires high-temperature rather than lowtemperature buffers.

The scenario for silicon is much less favorable. This is not just because the lattice-constant mismatch is greater than it is for sapphire. It is also because the thermal expansion coefficient mismatch is significant, and in such a direction that tensile strain, which promotes cracking, is produced.

The limitations for thin-film buffers on all substrates are the high residual defect density, which compromises device performance significantly.

<u>Recommendation</u>: Develop buffer layers on sapphire, SiC or silicon, with decreased (1e7/cm<sup>2</sup> by 2007 and 1e5/cm<sup>2</sup> by 2012) defect density, increased reproducibility, and with variable lattice constants to enable flexibility in strain-engineering of epitaxial devices.

Impact=WC+CM+Hy; Risk=H; Reward=M.

## Possible Approaches:

It is possible that buffer layer technology is already as mature as it will ever be. However, there are many individual aspects of buffer layer technology that have potential for improvement. These include:

Relationship between surface conditions and buffer quality.

There is a need for more systematic studies of the relationship between surface cleanliness, morphology, orientation and flatness of sapphire and especially SiC substrates on buffer layer quality.

# <u>Mechanisms</u> for nanostructure evolution during buffer formation.

There is also a need for more systematic studies of the mechanisms and controlling factors for nanostructures evolution during buffer formation, particularly the transition between 3D and 2D growth modes. Indeed, studies indicate that the relationship between buffer layer evolution and final quality is sometimes counterintuitive: in order to achieve larger nuclei size and lower nuclei density, it may be necessary for films to become rougher first before they get smoother and less defective. There may also be compromises between low dislocation density and high mosaic structure in the films, and between electrical and optical quality.

## Increased use of in situ monitoring.

Buffer formation is complex. Even with the same temperature, pressure and gas flows it is sometimes hard to control and reproduce. Reactor design and cleanliness may both play important roles, exacerbated by the buffer layer being grown close to the kinetic (rather than the boundary level diffusion) limit. Hence, a more-widespread use of in situ optical monitoring may be beneficial.

#### Strain engineering.

The use of strain engineering (e.g., AlN/GaN superlattices) may help minimize strain and crack formation.

## <u>MBE</u> studies.

To elucidate fundamental nanostructures evolution mechanisms under controlled surface conditions, it may be useful to use MBE growth. Thus far, MBE has not proven itself to be capable of growing high-quality buffers, or highquality optoelectronic devices, in the AlGaInN materials system (though it has had some success in growing highquality electronic devices). If it does prove itself able to compete with OMVPE in optoelectronic device quality, this would be a major breakthrough. However, in the absence of such a breakthrough, MBE may still be a useful tool for unraveling the fundamental mechanisms of buffer layer formation, with its greater range of growth conditions that may be explored, and the more sophisticated surfacescience probes available. This understanding could then be used to improve OMVPE buffer layer growth.

## **1.2.2 ELO GaN Buffers**

In the previous Challenge, we discussed the technologies for growth of "simple" buffers. These are buffers where no patterning or special processing is performed prior to buffer growth. The best that these buffers have been able to achieve, on any substrate (including sapphire and SiC) has been dislocation densities in the range 1e8-1e9/cm<sup>2</sup>. This is a very high number by semiconductor device standards, and it is now clear that device performance is degraded as a consequence. In addition, stress and wafer bowing are issues with simple buffers.

Hence, there has been great interest in developing buffers that, though involving more complex processing, can decrease the dislocation density further, to the range of 1e6- $1e7/cm^2$ . In this Section, we discuss the technologies for growth of "complex" buffers. These are buffers where patterning or special processing is performed prior to buffer growth.

There are three overall approaches to complex buffers. These are, in order of increasing conceptual complexity: epitaxial lateral overgrowth (ELO), pendeo epitaxial lateral overgrowth (pendeo-ELO), and cantilever epitaxial lateral overgrowth (cantilever ELO).

ELO. Epitaxial lateral overgrowth is the epitaxial growth of thin films on substrates that have been masked and patterned in such a way that growth occurs selectively in only certain areas of the substrate. Under the proper conditions, GaN will grow selectively on the GaN buffer, but not on the inert mask. Initially, the growth is upward, but later the growth becomes both upward and laterally outward. Eventually, neighboring growths coalesce over the stripe, creating a continuous film of GaN. Because dislocation replication depends both on the dislocation direction and crystallography, as well as on the direction of (and facet associated with) growth, it is possible to engineer a significant reduction in dislocation density in various regions of the GaN overgrown film. ELO is now routinely used for devices, such as lasers, that are especially sensitive to defects. The operating life and output power of GaN based lasers has now been extended to 10,000 hours, and dislocation densities have been decreased to the range 1e6/cm<sup>2</sup>, an approximate 250x reduction from those of simple buffers.

<u>Pendeo-ELO.</u> In order to gain the fullest advantage of ELO, it is possible to perform multiple ELOs, with a reduction in dislocation density each cycle. However, this requires costly multiple process and regrowth steps, along with lithographic alignment across steps. A possible approach that effectively enables a double-ELO in a single step is called pendeo-ELO.<sup>40</sup> In this method, growth does





not initiate through open windows but begins on sidewalls etched into a GaN seed layer, as shown in Figure 13. As the lateral growth from the sidewalls continues, vertical GaN growth begins from the newly forming (0001) face of the continually extending lateral growth front. Subsequently, once the vertical growth reaches the top of the seed mask, lateral growth over the masked top of the seed begins. The final result is coalescence over and between each seed form, producing a continuous layer of GaN. This is all accomplished in one regrowth step and eliminates the need to align devices or masks for a second LEO laver over particular areas of the GaN surface.

<u>Cantilever ELO.</u> In pendeo-ELO, it is still necessary to grow an initial GaN seed layer, before carrying out the operations of mask-forming and ELO growth. Therefore, growth has to be carried out twice, which is expensive. To avoid this cost, a variant of pendeo-ELO, called cantilever ELO<sup>41</sup> in the U.S. and LEPS (lateral epitaxy on patterned substrates) in Japan, has been developed. In this technique, ELO is performed on a substrate that has been processed to impart it with a groove-and-ridge topography and to create preferential conditions for lateral growth from the ridges. In this way, the technique becomes a single mask one-step growth directly on the starting substrate, rather than a two-step growth that relies first on growth of a buffer layer. Promising results have been reported,<sup>42</sup> including external quantum efficiency of LEPS-grown UV

<sup>&</sup>lt;sup>40</sup> R. F. Davis, T. Gehrke, K. J. Linthicum, P. Rajagopal, A. M. Roskowski, T. Zheleva, E. A. Preble, C. A. Zorman, M. Mehregany, U. Schwarz, J. Schuck, and R. Grober, "Review of pendeo-epitaxial growth and characterization of thin films of GaN and AlGaN alloys on 6H-SiC(0001) and Si(111) substrates," MRS Internet Journal of Nitride Semiconductor Research 6 (2001) 1-16.

<sup>&</sup>lt;sup>41</sup> C. I. H. Ashby, C. C. Mitchell, J. Han, N. A. Missert, P. P. Provencio, D. M. Follstaedt, G. M. Peake, and L. Griego, "Low-Dislocation-Density GaN From a Single Growth on a Textured Substrate," Applied Physics Letters 77 (2000) 3233-3235.

<sup>&</sup>lt;sup>42</sup> K. Tadatomo, H. Okagawa, Y. Ohuchi, T. Tsunekawa, T. Jyouichi, Y. Imada, M. Kato, H. Kudo, and T. Taguchi, "High output power InGaN ultraviolet light-emitting diodes fabricated on patterned substrates using metalorganic vapor phase epitaxy.," Physica Status Solidi A 188 (2001) 121-5.

LEDs at 20 mA of 24% and dislocation densities of 1.5  $\times$  108/cm².

There are several issues that prevent ELO and its variants from being used in LEDs.

- The first is cost and area. Since ELO requires a simple buffer, followed by a process patterning step, followed by an ELO buffer, it roughly doubles the cost of the epitaxy. This is exacerbated because only narrow strips of ELO material are high quality, separated by coalescence boundaries with much higher dislocation densities. Hence, increasing the available area associated with the low defect regions will be important.
- The second is the residual dislocation density even in the "good" areas; these should be decreased still further, to the 1e5-1e6/cm<sup>2</sup> range.
- The third is strain and tilting of the ELO material, which causes wafer bowing, wing tilt accompanied by extended defects at coalescence boundaries, and device performance modifications through strain-induced piezoelectric fields.
- ELO does not work (is not selective) for AlGaN, making it difficult to create variable-composition and variable-lattice-constant buffer layers.

<u>Recommendation</u>: Develop ELO technologies that enable large (1mm<sup>2</sup>) area devices to be fabricated on low ( $\leq 1e6/cm^2$  by 2007) defect density areas, at moderate ( $\leq 20/cm^2$ ) cost per cm<sup>2</sup> of "good" material.

Impact=WC+CM+Hy; Risk=M; Reward=M.

## Possible Approaches:

Extensions of ELO.

There may be simple extensions of ELO, such as multiple ELO, that would enable larger "good" areas for devices.

ELO on cheap substrates.

Although ELO is inherently expensive, if combined with inexpensive substrates such as Si, it may be possible to meet the cost targets.

#### Thin, super-anisotropic ELO.

Because of the first upward, then simultaneously upward and outward growth, ELO films end up being relatively thick. This causes wafer bowing, due to thermal expansion coefficient differences between the original substrate and the ELO film. It may be possible to engineer superanisotropic ELO through orientation-dependent growth rates, and thereby create much thinner films and much reduced wafer bowing.

Alternative mask materials with no auto doping.

Auto doping of ELO GaN from common mask materials such as Si and O from SiO2, can enhance nonradiative recombination. The use of alternative mask materials, such as W, may be useful.

#### Time-engineering of facet orientation evolution

Because of the strong dependence of dislocation replication on the orientation of the facets that are growing, engineering this orientation during the overall ELO growth sequence can be beneficial. This can be done by relying on the dependence of facet growth rates and overall crystal growth shapes on the growth conditions (temperature, V/III ratio, etc). One example of this is the so-called "facet-controlled ELO", or "FACELO", technique developed in Japan, which has demonstrated dislocation densities in the range 10<sup>6</sup> cm<sup>-2</sup>~10<sup>4</sup> cm<sup>-2</sup> through successive FACELO growths.<sup>43</sup> These results may be the best quality GaN/sapphire to date.

## Self-assembled ELO.

Predeposition of very thin, discontinuous SiN layers on sapphire can lead to nanometer-sized holes, through which ELO growth may occur.<sup>44</sup> This eliminates a lithography step, enables ELO on nanometer length scales, and may lead to lower dislocation densities.

## Variable-composition ELO.

ELO of variable-composition ternary and quaternary AlGaInN materials would enable the creation of new lattice constant surfaces, on which epitaxy of heterostructures with different compositions and strain states can be grown.<sup>45</sup>

## **1.2.3 Thick, Removable GaN Buffers**

It is possible that thin planar or ELO-based buffer layer technologies will be successful in reducing dislocation densities. However, these technologies generally lead to a bi-material substrate+buffer structure with mismatched

<sup>&</sup>lt;sup>43</sup> H. Miyake, M. Narukawa, K. Hiramatsu, H. Naoi, Y. Iyechika, and T. Maeda, "Fabrication and optical characterization of facet-controlled ELO (FACELO) GaN by LP-MOVPE.," Physica Status Solidi A 188 (2001) 725-8.
<sup>44</sup> T. Wang, Y. Morishima, N. Naoi, and S. Sakai, "A New Method for a Great Reduction of Dislocation Density in a GaN Layer Grown on a Sapphire Substrate," Journal of Crystal Growth 213 (2000) 188-192.
<sup>45</sup> Michael A. Kneissl, David P. Bour, and Linda T. Romano, Xerox Corporation, "AlGaInN ELOG LED and Laser Diode Structures for Pure Blue or Green Emission," Patent Number US6345063 (Feb 5, 2002)



Figure 14. Schematic of laser removal of GaN thick film from substrate. After Robert F. Davis, "Alternative Substrates for III-Nitride LED Structures," OIDA Solid-State Lighting Workshop (Albuquerque, May 30, 2002).

thermal expansion coefficients, and difficult-to-control post-buffer and post-epi room-temperature strain states.

If the buffers are thick enough, however, it is possible to remove the original substrate, leaving a free-standing buffer that essentially becomes a new single-material substrate. An example is shown in Figure 14. Very thick buffers also have the advantage that dislocation densities tend to decrease with increasing thickness.

Freestanding GaN buffers have already been demonstrated on a variety of removable substrates, including sapphire, silicon carbide, gallium arsenide, and lithium gallate.

- Sapphire: The current largest freestanding GaN buffer was obtained by growing a thick GaN layer on a sapphire substrate using HVPE and separating the grown layer from the sapphire substrate. However, it is not very easy to separate the GaN layer from the sapphire substrate because sapphire is very hard and is not etched by any etchant.
- SiC: Freestanding GaN buffers have also been demonstrated on SiC, again using HVPE of thick GaN (at growth rates of 1 µm/min) followed by silicon carbide substrate removal (by RIE in a SF<sub>6</sub> containing gas mixture).
- GaAs: Freestanding GaN buffers are also

possible on GaAs,<sup>46</sup> since GaAs substrates can easily be removed by aqua regia, and relatively large substrates of high quality are readily available.

 LGO: Freestanding GaN buffers have demonstrated on Lithium Gallate (LGO), which has the advantage of having the best known lattice match to GaN, 0.19% in the a-axis, of any heteroepitaxial bulk substrate. And, entire LGO wafers can be easily removed from the III-nitride films in a matter of minutes through selective etching.

We note that even if thick, removable GaN buffers end up not being economical, if they are high enough quality, they will enable fundamental materials physics properties to be less ambiguously measured (science), so that an assessment can be made of the importance of eliminating defects, and eventually of going to GaN bulk substrates (technology).

<u>Recommendation</u>: Develop ultra-high-quality (<1e5 defects/cm<sup>2</sup>) thick, variable-lattice-constant, removable buffers to be used either stand-alone or with subsequent single or multiple film transfers to other substrates, with final overall substrate+buffer cost  $\leq$ 25/cm<sup>2</sup>).

Impact=WC+CM+Hy; Risk=M; Reward=M.

#### Possible Approaches.

#### Hydride vapor phase epitaxy (HVPE).

HVPE is a technology that enables very fast, highquality, low-cost vapor phase growth of GaN.<sup>47</sup> The typical HVPE process involves the transport of GaCl, synthesized by reacting HCl gas with liquid Ga metal, in a stream of hydrogen, to the substrate where it is reacted with a separately injected flow of NH<sub>3</sub>, typically at 1000– 1100C, to form GaN. There are many variants of the technique, including the use of other carrier gases, such as He (Ilegems 1972), use of "presynthesized" GaCl, and the use of horizontal or vertical flow geometries.

 <sup>&</sup>lt;sup>46</sup> K. Motoki, T. Okahisa, N. Matsumoto, M. Matsushima, H. Kimura, H. Kasai, K. Takemoto, K. Uematsu, T. Hirano, M. Nakayama, S. Nakahata, M. Ueno, D. Hara, Y. Kumagai, A. Koukitu, and H. Seki, "Preparation of large freestanding GaN substrates by Hydride Vapor Phase Epitaxy using GaAs as a starting substrate," Jpn. J. Appl. Phys. 40 (2001) L140-L143.
 <sup>47</sup> R. J. Molnar, W. Gotz, L. T. Romano, and N. M. Johnson, "Growth of Gallium Nitride by Hydride Vapor-Phase Epitaxy," Journal of Crystal Growth 178 (1997) 147-156.

Growth rates are very high (on the order of 1-3  $\mu$ m/min), the precursors are relatively inexpensive (no expensive organometallics as in OMVPE), and the temperatures are high (hence purity is easier to maintain). For all of these reasons the VPE process is much more economical than either OMVPE or MBE. It cannot be used for device epitaxy, because it lacks the flexibility and control for growing complex epitaxial device structures. (e.g., Al-containing alloys are difficult to grow using HVPE). However, it can be used as a "brute force" method for growing high-quality, relatively inexpensive thick buffers. Recently, e.g., ATMI has demonstrated 1e6/cm<sup>2</sup> dislocations in thick HVPE material.

#### Defect evolution during thick buffer formation.

The dislocation reduction mechanism for very thick layers is still not well understood. The reduction depends on the kinds and densities of dislocations in the population created by the initial growth on the starting sapphire and SiC substrates. It also depends on the evolution and annihilation of these populations during subsequent thick growth. These mechanisms must be better understood and controlled in order to minimize the final dislocation population, as well as eliminate cracking.

#### Variable composition buffers.

Especially powerful would be the creation of variable composition AlGaInN buffers, with variable lattice constants. This would enable device epitaxy to be performed on substrates with lattice constants tailored for the particular device. Note that both GaN and AlN HVPE have been demonstrated; however there may be issues with parasitic gas-phase reactions for AlN and AlGaN.

## Multiple layer transfer.

There are also a number of substrates which are relatively well matched to AlGaInN, but are either rare, or are difficult to grow in boule form at high quality and at low cost. These include: ZnO, MgO, MgAl2O4, NdGaO, YSZ (yttria stabilized zirconia), ZrB2.

For example, the II-VI material ZnO has a wurtzite structure with lattice constants of (a = 3.32 Å, c = 5.213 Å) and thus offers a good structural match to the equilibrium wurtzite nitride. Also, 3C-SiC and MgO are cubic zincblende structures having better structural and thermal match to the nitrides than does sapphire. The cubic lattice constants of 3C-SiC and MgO are respectively a = 4.36 Å and a = 4.22 Å. But ZnO decomposes in H2 at typical HVPE and OMVPE temperatures, and Zn tends to auto dope and diffuse through GaN at under OMVPE conditions. OMVPE.

Though expensive, because these substrates are wellmatched to AlGaInN, and because presumably very high quality buffers could be grown on them, it may be possible to use them in approaches where they are "reused."

One approach would be analogous to one of the methods used to produce silicon-on-insulator wafers. In this method, the so-called "Smart-Cut" process (ion implantation, wafer bonding, annealing) is used to transfer thin layers of crystalline material from one substrate to another. Here, one might grow a thick, very high-quality AlGaInN buffer on an expensive but well-matched substrate such as ZnO. Then, multiple AlGaInN layers could be transferred to a less expensive substrate. And, finally, when enough layers had been removed, the expensive but well-matched substrate could be reused for growth of another thick AlGaInN buffer.

The constraints on the substrate are: it must match with AlGaInN, it must be capable of being grown at large (6" or greater) diameters, with very high structural quality, but with a much relaxed constraint on cost.

Close-spaced sublimation.

In addition to HVPE, alternative high-growth-rate, inexpensive deposition technologies should also be explored.

## **1.3 Epitaxy Tools**

Epitaxy is a key and demanding "front-end" step in fabrication of the light-emitting device engine. It's science and technology has advanced considerably this past decade.

For AlGaInP materials, in particular, epitaxy tools are highly advanced, with organometallic vapor-phase epitaxy (OMVPE) emerging as the most important of these tools. Production OMVPE tools with automated cassette wafer loading are now capable of growing five 6" or thirty-five 2" wafers at a time. These tools have driven the cost of AlGaInP LEDs down considerably over the last ten years.

For AlGaInN materials, however, epitaxy tools are still relatively immature. AlGaInN materials, though still compound semiconductors, behave quite differently from conventional AlGaInP and AlGaInAs materials. Indeed, epitaxy tools used to grow more mature compound semiconductor materials such as AlGaInAs cannot be used to grow AlGaInN because of the unusual growth conditions required for the nitride systems. Commercial manufactures of nitride devices currently use a combination of commercial and customized reactor designs, and there is no clear consensus on how to design nitride CVD reactors either for optimal single-wafer results or for multi-wafer high-volume production.

In this Section, we discuss the advanced tools necessary for high reproducibility, uniformity and control of epitaxy, as well as fundamental understanding of mechanisms that can enable improved tools and processes. There are two dominant kinds of tools that are used for device epitaxy.

Challenge 1.3.1 discusses the first: Molecular Beam Epitaxy (MBE). MBE is a simpler technique (evaporation of atoms in ultra-high vacuum), and the engineering technology, though sophisticated, is reasonably well understood. However, this approach has not been as heavily emphasized in the past. MBE has not yet demonstrated high quality in situ buffers, and hence its use is limited to device epitaxy, and, even then, only in conjunction with a substrate whose buffer has been created by another method (e.g., OMVPE or HVPE). Nevertheless, for many device structures, MBE has advantages, and further development of MBE tools and processes could be important.

Challenges 1.3.2-1.3.4 discuss the second: organometallic vapor-phase epitaxy (OMVPE), which involves chemically reacting fluid flows. This approach is both currently dominant, and is likely to be dominant in the future. Because of its complexity, we divide the Challenges into three. Challenge 1.3.2 involves unraveling the chemistry underlying OMVPE. Challenge 1.3.3 involves reactive fluid flow models, and the design of OMVPE tools that optimize this reactive fluid flow. Challenge 1.3.4 involves in situ diagnostics, both for understanding OMVPE processes in greater detail, as well as for controlling these processes during epi manufacturing.

## **1.3.1 MBE Tools and Mechanisms**

OMVPE is the dominant current epitaxial technique for epitaxial growth of both AlGaInP and AlGaInN alloys. MBE is an alternative technique.

For AlGaInN materials, however, it is necessary to augment the usual solid sources – Al, Ga, In, Mg, Si – with gas sources, as there is no solid source available for providing the N beam, and with activating the N, since molecular nitrogen is almost totally inert. The three broad approaches for doing so are: RF plasma activation of N<sub>2</sub>; microwave cyclotron resonance excitation of N<sub>2</sub> (the socalled ECR source); and thermal cracking of ammonia directly on the substrate.

For AlGaInN devices, MBE has not yet demonstrated very high quality buffers or very high quality optoelectronic devices.<sup>48</sup> However, when used to grow devices on top of

buffers grown by other methods (OMVPE or HVPE), the quality of the devices has been gradually improving. For example, photoluminescence from GaInN/GaN multiquantum-well structures grown by MBE have spectral halfwidths of the order of 20nm, centered at 420 nm, indicating reasonably high quality, although light emission intensity is still lower by 1 to 2 orders of magnitude than that of layers grown by OMVPE.

There is no reason to believe that, as with other compound semiconductor devices, MBE will not eventually be able to match OMVPE in terms of device quality and performance. In fact, the MBE technique enables some features that are not yet possible with OMVPE, and that may enable it to surpass OMVPE in some ways. If it does so, it is possible that MBE could be scaled to the high-volume production necessary for solidstate lighting. If it does not do so, MBE still represents an important alternative technology for helping unravel the science of AlGaInN materials and heterostructures.

<u>Recommendation</u>: Develop MBE tools and processes that enable epitaxy of ultra-high-efficiency (>70%) visible light-emitting devices.

Impact=WC+CM+Hy; Risk=H; Reward=M.

## Possible Approaches:

## P-doping.

Higher p-doping (1×10<sup>18</sup> cm<sup>-3</sup>) may be possible by MBE than by OMVPE, due to the ability to grow in a hydrogenfree environment, and to eliminate hydrogen-related dopant passivation. Also, growth of superlattice structures may be more controlled compared to OMVPE, and may enable superior p-type superlattice doping.

## <u>Ultra-sharp interfaces and extreme composition control.</u>

More reproducible control of alloy composition may be possible with MBE, since films are normally grown at lower temperatures and under group-V-rich conditions, for which growth rates are column-III-arrival-rate limited, and III-III composition is determined simply by the relative III-III arrival rates. In practice, at higher growth temperatures, there may be preferential loss of the group III element with the higher vapor pressure above the alloy, In in the case of GaInN, Ga in the case of AlGaN (Joyce *et al* 1994). Also, Al may be difficult to incorporate in MBE.

## Materials with cubic crystallography.

Metastable cubic structures on substrates with cubic symmetry (e.g., 3C-SiC) are also more readily achieved by MBE.

<sup>&</sup>lt;sup>48</sup> G. Pozina, J. P. Bergman, B. Monemar, B. Heying, and J. S. Speck, "Radiative and nonradiative exciton lifetimes in GaN grown by molecular beam epitaxy.," Physica Status Solidi B 228 (2001) 485-8.

## Surfactant-controlled growth.

Surfactants are readily added to the "growth mix" in MBE, and can be helpful in modifying adatom migration on the surface, modifying growth modes, and engineering strain and defect evolution.

## Novel alloys.

The exploration of novel alloys, such as GaNAs, may be more readily done by MBE, due to lower growth temperatures.

## Different polarity growth modes.

Engineering the polarity of the GaN epilayer is more readily achieved by MBE. For example, GaN films grown on sapphire by MOCVD or HVPE usually exhibit Ga-face polarity. GaN films grown by MBE, however, can have their polarity flipped through introduction of a thin AlN buffer layer. Such polarity control may be used to tailor various properties of epitaxial films and electronic devices. The Ga and N-face samples differ in their electronic properties -- different Schottky barrier heights are observed for both polarities, the position and detailed spontaneously formed two-dimensional properties of electron gases vary with polarity, and the adsorption of gases and ions also show an influence of the two different surfaces. A particular interesting possibility is the growth of lateral polarity heterostructures with predetermined macroscopic domains of different polarity separated by inversion domain boundaries. These structures make use of the crystal polarity as a new degree of freedom for the investigation of electronic properties of III-nitrides and for novel devices.

## **1.3.2 OMVPE Chemistry**

The OMVPE process is fundamentally a chemical one, in which gaseous precursors are injected from a precision gasmixing manifold into a cold-wall reactor, where they react on, or enroute to, the substrate.

The two key aspects of OMVPE are the chemistry, and the fluid flow. These two aspects are linked, but each is a complex and challenging area of its own. This is particularly the case for AlGaInN, which is much less mature than AlGaInP, and which involves more extreme growth conditions (temperature, pressure), and more unwanted side-reactions. In this Challenge we discuss chemistry and precursors; in the next Challenge we discuss fluid flow (including some aspects of chemistry), and the ramifications on tool design.

The most common precursors for the growth of AlGaInN are the simple Column III metal alkyls (TMAl, TMGa, TMIn) and the Column V hydride (NH3). From these precursors, reasonably high quality AlGaInN

materials may be grown. However, despite considerable empirical knowledge accumulated by many research groups, clear understanding of the relative role of different physical mechanisms governing the chemistry is not yet been reached. This may be related to both complex gasphase as well as complex surface-phase chemistry:

- NH3 decomposition. Even something as basic as ammonia decomposition appears to be relatively poorly understood. Thermodynamic analysis of various nitrogen precursors show that ammonia should almost completely dissociate into inactive N2 and H2 at temperatures as low as  $\sim 400^{\circ}$  C. If this were the case, growth of GaN would not occur at all, due to the lack of a reactive nitrogen precursor. This means that the pure thermodynamic consideration is not applicable to analysis of the real growth situation. The N-H bond strength is 4.5 eV, similar to O-H and H-H. cracking may depend on catalytic NH3 dissociation, since the N-H bond breaking energy is so high.
- Precursor interactions. One area of concern in the MOCVD growth of III-N materials is the interaction of the organometallic sources with the high concentrations of NH3 used in this process. The organometallics are strong Lewis acids and will react in the gas phase with ammonia, a strong Lewis base, potentially leading to the production of stable adducts. The degree to which this is a problem is a function of nearly all aspects of the growth environment – pressure, temperature, flow rates, residence times in heated zones, etc.
- Purity. An extremely important consideration in the growth of high-quality epitaxial device structures is the purity of the sources. This is especially true for MOCVD growth of nitrides since the incorporation of Si and O are both of great concern for these materials, particularly for growing heavily p-type AlGaInN alloys. Recently, special high-purity sources of TEGa, TMGa, TMIn, and TMAl, have become available from several vendors, for which oxygen-containing precursors, such as residual alkoxide compounds, have been reduced.
- Particle formation. Recent work indicates that nanoparticle formation in the boundary layer can be a significant parasitic reaction path, both for GaN and AIN OMVPE.<sup>49</sup>

<sup>&</sup>lt;sup>49</sup> J. R. Creighton, W. G. Breiland, M. E. Coltrin, and R. P. Pawlowski, "Gas-phase nanoparticle formation during

<u>Recommendation</u>: Develop fundamental understanding of precursor chemistries that apply to actual OMVPE growth conditions and that enable design of new tools and processes for improved material quality and more efficient precursor usage.

Impact=WC+CM+Hy; Risk=L; Reward=H.

#### Possible Approaches:

#### Studies in conventional OMVPE reactors.

One approach is to look at growth rates and the quality of materials grown using various precursors under various temperature and flow conditions, and then to infer chemical mechanisms. This approach requires modeling the entire reactive fluid flow problem, taking into account detailed chemistries (such as sticking/evaporation coefficients of N2 and NH3). Hence, these experiments can be sometimes difficult to interpret. However, these same models are useful in that they make contact to experimental quantities of direct interest to devices, such as composition and growth rates.

Studies in special-purpose experimental set-ups.

The second approach is to study the chemistry separately, using special experimental set-ups tailored for chemistry studies rather than for growth. For example, chemisorption and reaction of deuterium and isotopically labeled ammonia on single-crystalline GaN films grown on sapphire substrates can be studied using temperature programmed desorption (TPD) and Auger electron spectroscopy (AES) studies.<sup>50</sup> These studies can be used to follow the surface reaction kinetics of species that are relevant to OMVPE of AlGaInN. Or, laser light scattering can be used to study gas-phase chemistry and particle formation. In this same class of approaches would also be the use of MBE to study chemistries, particularly NH3 chemistries, which are similar to those occurring in Conventional chemical reaction engineering OMVPE. techniques, such as the diagnostics and model development commonly carried out in the petrochemical industry, may also be helpful to investigate the gas phase chemistry of these systems.

#### Computational chemistry.

Theoretical calculations can greatly augment direct experimental studies, through step-wise testing of proposed

AlGaN metalorganic vapor phase epitaxy," Applied Physics Letters 2002) .

models of the growth chemistry. This is vital, because not all of the critical chemistry is expected to be accessible via experiment.

Novel Precursors and Carrier Gases.

Some recent success has been reported in the use of "novel" precursors for GaN growth. One ultimate goal of this research is to develop a class of sources that can be used to deposit III-N films at much lower temperatures than is required for the processes relying upon NH3. Some examples are listed here:

- Ga sources. Two possible alternate source compounds are dimethylgallium azide ((CH3)2GaN3)n and dimethylhydrizodimethylgallium ((CH3)2GaNH(N(CH3)2))2, for which the azide (N3) ligand is used because it is known that azides generally eliminate N2, which should leave a N atom bonded to Ga.
- Mg sources. Bis(cyclopentadienyl)magnesium (Cp2Mg) is a common source for p-type doping in GaN and AlInGaP materials. It is a white crystalline solid with very low vapor pressure, leading to transport problems similar to solid trimethyindium (TMI). Some of these problems can be alleviated by a newly developed sourcesolution magnesocene, Cp2Mg, dissolved in a solvent that is essentially nonvolatile.
- Carrier gas. The commonly used carrier gas for MOCVD is palladium-purified H2. For the growth of InGaN alloys, however, it has been found that the use of a N2 carrier gas results in a higher incorporation of In into the solid phase and also higher-quality films, as determined by PL measurements.

## **1.3.3 OMVPE Reactive Flow and Tools**

The OMVPE process is basically a chemically reacting fluid flow processes. These problems are complex, because they are sensitive to both the chemistry and the fluid flow. In the previous Challenge we discussed chemistry and precursors; in this Challenge we discuss overall chemically reacting fluid flow issues, and especially their ramifications on tool design.

Current OMVPE tools for the more-mature AlGaInAs and AlGaInP materials systems are very well developed. Current OMVPE tools for AlGaInN are much less mature, and there is no consensus on which, if any, is best. The tools take various forms (flows which are oriented horizontally or vertically), and the process conditions also vary (from atmospheric pressure to moderately low few-

<sup>&</sup>lt;sup>50</sup> R. Shekhar and K. F. Jensen, "Temperature Programmed Desorption Investigations of Hydrogen and Ammonia Reactions on Gan," Surface Science 381 (1997) L581-L588.

Torr pressures). And, both commercial and home-built reactors are used.

Simply borrowing from the experience of tools used for OMVPE of GaAs based devices is not sufficient, since much of that experience is contrary to the more complex growth mechanisms associated with AlGaInN.<sup>51</sup> The reasons are those listed above: more extreme growth conditions (high and low temperatures, pressure) and parasitic gas-phase pre-reactions.

The current generation of AlGaInN reactors suffer from: unacceptable composition nonuniformity (which leads to wavelength nonuniformity); inadequate throughput (larger reactors need to be developed in the near future in order to speed up the cost reduction cycle); and inadequate process reliability and reproducibility. This is a special issue for solid-state lighting, because the human eye is so sensitive to slight variations in color. The uniformity and reproducibility of wavelengths, e.g., needs to be within +/-1% in the green, +/- 0.8% in the blue. Currently, uniformity and reproducibility are about 10x worse for AlGaInN than for AlGaInP.

Fundamentally new reactor designs may be needed. Ideally, these new designs will be based on new knowledge of the chemistry developed in Challenge 1.3.2, and the unique requirements of AlGaInN epitaxy. Some of these requirements will be driven by the novel processes discussed in Challenge 1.4.2, such as those requiring rapid temperature, and gas-flow and pressure cycling.

<u>Recommendation</u>: Develop, through an understanding of chemistry mechanisms and fluid flow, a completely new generation of AlGaInN OMVPE tools with high compositional and growth rate uniformity, and ultra-high material quality.

Impact=WC+CM+Hy; Risk=L; Reward=H.

Possible Approaches.

Computational fluid dynamics studies.

In OMVPE, the chemically reacting fluid flow problem is formidable. Various types of stagnant volumes such as return-flows and boundary layers can occur, some of which may become spatially disconnected over various time scales; and convective instabilities associated with buoyancy and the hot substrate are particularly worrisome. Hence, it has been, and will continue to be, critical to use advanced Computational Fluid Dynamics (CFD) based reactor modeling combined with growth chemistry models.

The complexity of the growth chemistry models can be increased in a step-wise fashion: from simple unity sticking coefficient models to more advanced gas- and surfacephase reaction models. Likewise, the complexity of the fluid flow models can be increased in a step-wise fashion: from simple boundary-layer and convective instability models (that can give rules of thumb for efficient fluid mechanics design) to finite-difference fully numerical models.<sup>52</sup>

It will be especially interesting to develop models for particle nucleation, growth and transport. Understanding how to circumvent this parasitic reaction path could lead to reactors where epitaxial growth is much more efficient and predictable.

Relationship between material quality and growth conditions.

It will also be critical to continue to improve our understanding of the relationship between material quality and growth conditions.<sup>53</sup> For example, there is only a limited understanding of the relationship between overall pressure and material quality – though it appears that higher pressures are better. Through this understanding, it will be possible to target growth condition, and demands on tool development, more precisely.

Novel OMVPE tool designs.

There are three kinds of commercial multi-wafer platforms.

- Horizontal planetary reactors with a circular geometry and radial flow from the center outwards.
- Vertical rotating-disk reactors with a cylindrical geometry and vertical flow from a gas injection flange downwards.
- Vertical close-spaced reactor with a cylindrical geometry and vertical flow from an array of separate injection nozzles.

<sup>&</sup>lt;sup>51</sup> T. F. Kuech, "Issues in GaN Growth Chemistry and Reactor Design," OIDA Solid-State Lighting Workshop (Albuquerque, May 30, 2002).

<sup>&</sup>lt;sup>52</sup> R. P. Pawlowski, C. Theodoropoulos, A. G. Salinger, T. J. Mountziaris, H. K. Moffat, J. N. Shadid, and E. J. Thrush, "Fundamental Models of the Metalorganic Vapor-Phase Epitaxy of Gallium Nitride and Their Use in Reactor Design," Journal of Crystal Growth 221 (2000) 622-628.
<sup>53</sup> S. A. Safvi, N. R. Perkins, M. N. Horton, R. Matyi, and T. F. Kuech, "Effect of Reactor Geometry and Growth Parameters on the Uniformity and Material Properties of Gan/Sapphire Grown by Hydride Vapor-Phase Epitaxy," Journal of Crystal Growth 182 (1997) 233-240.

These commercial platforms have achieved great success for the traditional compound semiconductor materials, and all compete fiercely in the marketplace for OMVPE tools. However, they may not be appropriate for optimized AlGaInN OMVPE growth. Instead, it may be necessary to consider alternative designs:

- Single-wafer reactors
- Reactors that enable very rapid growth
- Upside-down reactors, in which the buoyancy and convective flows are aligned
- Split or two-flow reactors, in which the injection and subsequent flows of the column III and column V precursors are arranged to be as separate as possible, so as to avoid gas-phase prereactions (e.g., Nichia's vertical two-flow reactor, <sup>54</sup> though there remains considerable uncertainty on the exact geometry of this reactor).

Again, there is no consensus on what type of tool is best, and there probably will not be until more of the basic chemistry mechanisms have been unraveled. Only then can reactive flow models be used in a believable way to help design OMVPE tools.

## **1.3.4 OMVPE In Situ Diagnostics**

For OMVPE growth of traditional AlGaInAs and AlGaInP based compound semiconductors, in situ diagnostics, particularly those based on optical reflectance and optical pyrometry, have made a significant impact on the accuracy and reproducibility of growth. For example, VCSELs, which are among the most demanding device structures, can be grown with less than 0.5% wavelength variation from run to run.

For OMVPE growth of the more complex AlGaInN based compound semiconductors, in situ diagnostics have also shown themselves to be valuable, particularly during growth of buffers, whose microstructure evolves in a complex and sometimes-difficult-to-reproduce manner during growth. They could also be of great value during growth of device epilayers, where compositions and growth rates must be precisely controlled, but also vary nonlinearly with growth conditions (flows, temperatures, pressures).

However, in situ diagnostics for AlGaInN are relatively immature. Because device epitaxy is often grown on buffers which have undergone considerable microstructural evolution, and whose surfaces are not perfectly smooth, optical reflectance can be somewhat difficult to interpret.

Even the most basic quantity, temperature, which is usually measured through optical pyrometry, is difficult to measure due to blackbody radiation from the susceptor that is nearly completely transmitted through the sapphire substrates. Because of the nonlinear and steep dependences of both buffer layer evolution and device epitaxy growth rates and compositions on temperature, this is a major deficiency.

<u>Recommendation</u>: Develop in situ diagnostics for AlGaInN OMVPE tools, and implement strategies for calibrating and controlling growth parameters (e.g., temperature, partial pressures, rates) for both buffer layers and device heterostructures.

Impact=WC+CM+Hy; Risk=L; Reward=H.

## Possible Approaches:

#### Optical pyrometry.

In pyrometry, light emitted from the hot substrate is measured, and used to determine the temperature of the substrate. A variant of this, reflectance-corrected pyrometry, corrects for the emissivity changes that occur during growth of multilayer structures. This technique is extremely powerful, but there are difficulties with applying it to the AlGaInN/sapphire materials system: surfaces are not smooth hence light can be scattered rather than just specularly reflected; and blackbody radiation from the susceptor can leak through the transparent substrate.

## Normal-Incidence Reflectometry

In normal-incidence reflectometry, an external light source (laser or tungsten light bulb) is reflected off of the substrate. As layers of different refractive index are grown, the interference fringes that are observed in time can be used to deduce growth rates.<sup>55</sup> In addition, if absolute reflectance is measured, compositions and growth rates can be deduced simultaneously. This technique is also extremely powerful, and is being applied routinely to AlGaInAs growth in both commercial and home-made reactors worldwide. This technique presents some quantitative difficulties in its application to the

<sup>&</sup>lt;sup>54</sup> Shuji Nakamura, Nichia Kagaku Kogyo K.K., "Method of Vapour Growing a Semiconductor Crystal," Patent Number EP0482648B1 (Jan 30, 2002).

<sup>&</sup>lt;sup>55</sup> H. P. D. Schenk, P. de Mierry, P. Vennegues, O. Tottereau, M. Laugt, M. Vaille, E. Feltin, B. Beaumont, P. Gibart, S. Fernandez, and F. Calle, "In situ growth monitoring of distributed GaN-AlGaN Bragg reflectors by metalorganic vapor phase epitaxy.," Applied Physics Letters 80 (2002) 174-6.

AlGaInN/sapphire materials system, due to surface roughness. For device epilayers, this is a drawback. However, during buffer layer growth it is not a drawback, as it becomes useful as a tool for monitoring the nucleation and coalescence behavior associated with buffer layer evolution.

#### Spectroscopic Ellipsometry.

Non-normal-incidence optical monitoring techniques, such as spectroscopic ellipsometry, is an additional tool. This tool is much more surface sensitive than normalincidence reflectometry, and can be used to study the evolution of surface stoichiometry during growth. For example, the presence of N-rich and Ga-rich surfaces can be monitored, along with how they change as a consequence of variation of the growth environment (presence of absence of TMGa, NH3 partial pressure, etc).<sup>56</sup> And, how this surface stoichiometry, in turn, affects chemistries and decomposition rates (evidently, they decrease with increase in the N coverage on the GaN surface).

<u>New probes.</u>

There are also a number of probes, such as infrared absorption/transmission spectroscopy, reflection difference spectroscopy, and mass spectrometry, that would open new "windows" into fundamental understanding, but that have not yet been applied to AlGaInN epitaxy.

## **1.4 Epitaxy Processes**

In the previous Section, we discussed the development of new epitaxy tools based on an understanding of epitaxy mechanisms. In parallel with that, discussed in this Section, is the development of epitaxy processes based on existing tools. These processes will be different depending on the material to be grown.

AlGaInP, as discussed before, is the most mature, and is discussed in Challenge 1.4.1 AlGaInN is much less understood, and is discussed in Challenge 1.4.2. For both of these materials systems there are three common themes.

 The first common theme is strain. In some cases it will be desirable to have layers with large strains. In other cases it will be desirable to have layers with no strain. This can be done through use of quaternary AlGaInP and AlGaInN alloys, but it requires a very high degree of compositional control and is extremely demanding of the epitaxial growth tool and process.

- The second common theme is control of compositional modulation or nonuniformity, such as self-assembled quantum dots, which are nearlyuniversal phenomena in strained materials.
- The third common theme is that all these materials must be able to be tailored in two different ways. On the one hand, when used in active (radiating) parts of a device their radiative efficiency must be very high. This usually means undoped material that is grown as pure as possible. On the other hand, when used in the current transport part of a device their electron or hole conductivity must be very high. This usually means material grown as heavily doped as possible.

Because doping of AlGaInN materials is especially difficult, due to chemical passivation during growth, we discuss this issue in Challenge 1.4.3.

Finally, Challenge 1.4.4 discusses novel materials systems not included in either the AlGaInP or AlGaInN materials family.

## 1.4.1 Quaternary AlGaInP

Quaternary AlGaInP is the materials system that currently produces the brightest red luminescence, and hence is most likely to be used for the red LEDs in the color-mixed and hybrid approaches to white lighting.

This materials system can be considered mature. Devices made from the Ga-rich end of this materials system (deep red wavelengths of 650nm) have nearly 100% internal quantum efficiency, so the bulk material quality is very high. However, devices made from the Al-rich end of this materials system (mid-red wavelengths of 610nm) have much lower internal quantum efficiencies. Partly, this is due to fundamental materials physics -- the direct/indirect crossover occurs at roughly <sup>1</sup>/<sub>4</sub>:<sup>1</sup>/<sub>2</sub> Al:Ga:In content.

However, the mid-red wavelengths are those that are best-suited for tri-color white light, hence it would be highly desirable to push the AlGaInP materials system further into the mid-red.

<u>Recommendation</u>: Develop AlGaInP materials and heterostructures with high (>95%) internal radiative quantum efficiencies at wavelengths <620 nm.

Impact=CM; Risk=M; Reward=M.

## Possible Approaches.

<sup>&</sup>lt;sup>56</sup> Y. Taniyasu and A. Yoshikawa, "In-situ monitoring of surface stoichiometry and growth kinetics study of GaN (0001) in MOVPE by spectroscopic ellipsometry," Journal of Electronic Materials 30 (2001) 1402-1407.

## Suppression of ordering.

Ordering is a well-known phenomenon in this alloy system, and causes a bandgap narrowing. Hence, suppressing this ordering is critical. Growth conditions like temperature, V/III ratio and pressure all play a role. In addition, surfactants have recently been found to help suppress ordering, particularly the isoelectronic surfactants Sb and Bi. However, at high surfactant concentrations, other phenomena are observed, such as lateral composition modulation and surface roughness. Hence, there may only be a narrow window within which surfactants are effective.

## Higher-purity Al, Ga, In, P sources.

Small amounts of oxygen contamination may well decrease the quality of high-Al-content materials, including AlGaInP. This is especially true at the lower temperatures that suppress ordering.

## MBE.

If lower-temperature growth is key to decreasing ordering, and if high Al content is desirable, it may be useful to explore MBE techniques. We note that in the past few years, the compatibility of MBE with phosphides has been demonstrated.

#### Strain-engineered structures.

Structures with tensile (rather than compressive) strain may enable larger band offsets and tighter confinement of carriers in quantum wells. Growth on GaAs (111) orientations may enable strain-based piezo-electric fields that may also enable larger band offsets.

## **1.4.2 Quaternary AlGaInN**

Quaternary AlGaInN, typically grown by OMVPE,<sup>57</sup> is the dominant materials system used for the current generation of blue and green LEDs. Hence, it could be used for the blue and green components of a color-mixed approach to white lighting, or for a blue plus phosphordown-converted yellow or green/red approach to white lighting.

There are three "corners" to the "pseudo-ternary" triangle of this materials system.

• The Ga-rich corner is the most mature. This materials system is mostly GaN, with a small amount of InN for the light-emitting layers, and either pure GaN or GaN with a small amount of AlN for the confining layers. This corner of the triangle emits light in the blue and green.

- The Al-rich corner is less mature. This materials system contains significant amounts of Al. It is generally much lower in quality, and is much less used in devices. Significant opportunities would be opened up to the device designer if these alloys were opened up – particularly UV-emitting devices.
- The In-rich corner is the least mature. This corner would enable amber and red emitting devices, which would open up the possibility of integrating blue, green and red emitters on a single GaNbased substrate. However, when the In content becomes too high, radiative efficiency decreases strongly, and it has been difficult to achieve strong photoluminescence or cathodoluminescence much beyond 580nm.

For all three of these corners, and for quaternary AlGaInN materials generally, there are several common themes.

- Composition modulation. InGaN material tends to phase separate into a compositionally inhomogeneous "quantum-dot-like" microstructure. This tends to confine carriers to regions of lower bandgap, thereby avoiding nonradiative recombination at extended defects in the matrix. Indeed, some In content appears to be essential to the current generation of blue, green These materials are now and white LEDs. reasonably efficient, with internal radiative quantum efficiencies on the order of 50-75%. However, the inhomogeneity broadens spectral line widths, which may be disadvantageous for stimulated emission devices.
- <u>Defects</u>. Until higher-quality substrates and buffers are developed, extended defects such as dislocations will continue to be a significant problem. These defects may make necessary the composition modulation described above.
- <u>Doping</u>. n-type doping is relatively straightforward, as Si works quite well across the composition ranges Si has a moderate activation energy, and electrons have a relatively high mobility. p-type doping is not so straightforward. Mg is a tricky dopant to use, with a high activation energy, and with a strong propensity to be passivated with hydrogen. In addition, holes have a relatively low mobility.
- <u>In segregation.</u>
- <u>Growth temperature incompatibilities.</u> The ideal growth temperatures of the binary constituents are

<sup>&</sup>lt;sup>57</sup> S. P. Denbaars and S. Keller, "Metalorganic Chemical Vapor Deposition (MOCVD) of Group III Nitrides," Semiconductors and Semimetals 50 (1998) 11-37.

quite different – AlN requires high temperatures (1200-1300C), GaN medium temperatures (1000-1100C), and InN relatively low temperatures (700-800C). Hence, at growth temperatures optimal for InN, the material quality of AlN is poor, perhaps due to insufficient mobility of Al adatoms strongly bound to the AlN surface. At growth temperatures optimal for AlN or GaN, InN tends to desorb, due to the weak In-N bond.

- Interfaces. Segregation and growth temperature incompatibilities also lead to difficulties in creating sharp and well-defined interfaces in heterostructures. Each of these heterointerfaces represents an opportunity for roughness and interface non-abruptness, all of which can lead to non-radiative recombination, carrier scattering, etc.
- Strain. AlN, GaN and InN have very different lattice constants. Hence, the ternary and quaternary compositions are characterized by large microscopic bond strains, leading to microscopic composition modulation and phase separation. And, they are characterized by large macroscopic strains, due to mismatch of the overall alloy with the substrate. These macroscopic strains can lead to surface morphology issues (via growth mode) and cracking.

<u>Recommendation</u>: Develop epitaxy processes for highquality materials and nanostructures over the entire AlGaInN quaternary composition range, to achieve high (>95%) internal radiative quantum efficiencies throughout the UV and visible (370-630 nm), and very-high (>1e19/cm<sup>3</sup>) effective p-type doping levels.

Impact=WC+CM+Hy; Risk=H; Reward=H.

Possible Approaches.

#### Variable-pressure OMVPE.

The optimum temperatures and pressures for growth are not yet understood. Several research groups have reported improved material quality of GaN-based thin film growth by depositing at atmospheric pressures and higher. This of course places additional strains on the development of a scalable GaN reactor design. At these high pressures, buoyancy-driven convective instabilities become severe and difficult to control. These instabilities become more dominant as the reactor is scaled to larger dimensions. It is also possible that both low and high pressures are needed at various stages of the device epitaxy – e.g., depending on whether In is present or not in the layer. Tailoring the material nanostructures (e.g., quantum dot nucleation away from extended defects)

Phase separation into quantum-dot-like nanostructures is evidently a key ingredient to high internal radiative efficiency in the presence of extended defects. Hence, tailoring it further may be profitable: e.g., using surfactants or other methods to induce nucleation of quantum dots away from extended defects.

#### Modified OMVPE processes.

Novel OMVPE-based processes such as atomic layer epitaxy (ALE) may be useful. This process enables deposition at much lower temperatures than those required for conventional OMVPE. The low growth temperature leads to an efficient incorporation of indium and, as a result, to a dramatic improvement in emission properties of the material. Also, in ALE AlInGaN material, the optical emission properties do not degrade as quickly with increasing Al mole fraction.

#### <u>Quantum dots without In</u>

In the usual case of Ga-rich GaInN, GaInN quantum dots are embedded in a matrix of GaN. This has the beneficial aspect, mentioned above, of trapping carriers away from non-radiative recombination at extended defects. However, once Al is added, In becomes difficult to also incorporate, due to its high vapor pressure at AlGaN growth temperatures. Instead, it may interesting to explore either self-assembled or lithographically tailored growth of GaN or AlGaN quantum dots (QDs) embedded in AlGaN or AlN matrices.<sup>58</sup>

## Quantum dots with both In and Al

If growth temperatures can be low enough, adding In simultaneously with adding Al may be possible. Indeed, the most intense UV emission at room temperature thus far has been demonstrated in this manner, in the wavelength range of 315-370 nm from quaternary InxAlyGa1-x-yN alloys grown by OMVPE.<sup>59</sup>

## Control of parasitic pre-reactions.

In addition, the risk of parasitic reactions between NH<sub>3</sub> and TMAl, which is used as the Al source material, presents a problem in the commonly used normal-pressure MOCVD technique, which makes growth at high AlN

<sup>&</sup>lt;sup>58</sup> M. Miyamura, K. Tachibana, T. Someya, and Y. Arakawa, "Self-assembled growth of GaN quantum dots using lowpressure MOCVD," Physica Status Solidi B-Basic Research 228 (2001) 191-194.

<sup>&</sup>lt;sup>59</sup> H. Hirayama, A. Kinoshita, T. Yamabi, Y. Enomoto, A. Hirata, T. Araki, Y. Nanishi, and Y. Aoyagi, "Marked enhancement of 320-360 nm ultraviolet emission in quaternary In{sub x}Al{sub y}Ga{sub 1-x-y}N with Insegregation effect.," Applied Physics Letters 80 (2002) 207-9.

molar fractions difficult. To grow AlGaN, it is important to suppress the parasitic reactions. Hence, improved OMVPE tools that can suppress the parasitic reactions and enable growth of AlGaN with a high AlN molar fraction will be important.

## Molecular beam epitaxy.

MBE may have an advantage for growth of some ranges of AlGaInN composition, because of its lower growth temperatures, and the possibility of surfactants for higher Al surface mobilities.

## Widen OMVPE growth conditions.

If OMVPE is used, the overall growth temperature would most likely need to be lowered, to avoid InN desorption (at temperatures above 550C). Also, higher V/III ratios might be necessary, though this may lead to rough interfaces.

## Strain-engineered buffers.

Strain is also a major issue with high-In-content InGaN layers, since the usual buffers on sapphire are either GaN or AlN. This strain hinders the incorporation of In atoms in the InGaN lattice, and is the driving force for a compositional pulling effect in InGaN films. It may be possible to do some sort of strain engineering, either by growing InGaN buffers directly on sapphire, or by interspersing strain-balancing layers amongst the InGaN device layers.

## Composition engineering at interfaces.

Systematic studies of In incorporation as a function of time, including the effects of segregation, desorption, and various V/III surface conditions. Also, studies of how In and other elements can be used as surfactants. These studies will be especially useful for tailoring the transition from low-to-high temperature growth at some interfaces.

## Growth interruptions for smoother interfaces

Growth interruptions, just as is common practice with the more mature AlGaInAs and AlGaInP materials systems, may be helpful. However, growth interruptions may also lead to deleterious effects, for example, enhanced Indium clustering, enhanced impurity accumulation, etc. Indeed, thus far, the highest quality InGaN/GaN interfaces appear to be growth without growth interruptions at all.

## **1.4.3 Doping and Passivation**

OMVPE is characterized by having a large amount of hydrogen present, both from the H2 carrier gas as well as from the ammonia precursor that is present in great quantities. This hydrogen incorporates into the p-type GaN during MOCVD growth, producing highly stable passivation of the Mg acceptors. Hence, this hydrogen must first be released before the Mg-doped material can actually become p-type. The original observation that this could be accomplished through e-beam irradiation, and the later observation that this could be accomplished through thermal annealing, is perhaps one of the most significant advances that enabled high-brightness AlGaInN-based LEDs.

However, much is not understood about this passivation process – how it depends on both the Mg present as well as on other point and extended defects – and about the release process. In fact, there is evidence that complete acceptor activation by thermal H release requires temperatures that threaten material integrity, and may rarely occur in actual devices.

Note that even without passivation, doping of AlGaInN is difficult. In part, this is because it is a wide-gap semiconductor. The ionization energies of dopants goes as  $m^*/\epsilon^2$ , where  $m^*$  is the effective mass and  $\epsilon$  is the dielectric constant. In wide-gap semiconductors the effective mass tends to be large (especially for holes) and the dielectric constant tends to be low, so ionization energies tend to be large, and doping becomes relatively difficult. E.g., the depth of the Mg acceptor level is 250 meV, which leads to poor doping efficiency (typically no more than about 1% at room temperature). If shallower acceptors can be found, they would have considerable impact on device design.

A common theme in this Challenge is the importance of linking experiment with theory - both in studying the energetics, as well as the kinetics, of doping and passivation.

<u>Recommendation</u>: Develop very-high-doped (1e19/cm<sup>2</sup> equivalent) heterostructures for lateral and vertical hole transport, over the entire AlGaInN composition range.

Impact=WC+CM+Hy; Risk=H; Reward=H.

## Possible Approaches:

## p-doping life-cycle.

Heavy passivation of Mg doping by hydrogen is a major issue. Improved processes for hydrogen release, as well as improved control of how the hydrogen uptake occurs during the epitaxy process, are of interest. These improved processes will require a deeper understanding of the overall p-doping life cycle, during and after OMVPE. This is especially an issue in high-Al-content AlGaInN, which is much more difficult to dope p-type.

## H uptake and release.

One approach is to study the uptake and release process under carefully controlled surface and bulk conditions, and to develop detailed models for the dynamics of this process. For example, mathematical rate-equation models<sup>60</sup> have been developed recently that include diffusion and reaction of a wide range of hydrogen, Mg and intrinsic-defect species with different charge states, along with simultaneous solution of Poisson's equation to take into account space charge. This allows the behavior of H to be modeled in junction devices, under bias, at room temperature, and in real-time.<sup>61</sup> These studies need to be extended to Al-rich alloys.

#### Surface barrier engineering.

From the studies discussed above, it appears likely that surface barriers impede the release of hydrogen during activation annealing. Understanding the mechanism for this barrier, and then introducing chemical or metallurgical treatments to reduce it, will be very important.

#### Novel p-type dopants.

C in c-GaN may be shallower than Mg in h-GaN, and hence may be an interesting alternative p-type dopant.

#### Piezoelectric-field-induced artificial sheet charges

Another interesting possible approach has to do with the use of piezoelectric fields to create artificial sheet charges at heterointerfaces, which would be equivalent to heavy doping, at least for lateral current transport. These fields may be responsible for recent observations of enhanced hole transport in Mg-doped GaN/AlGaN superlattices.

#### MBE (with and without H)

Hydrogen-free MBE processes may be useful to explore.

Novel Processes, including laser activation. A pulsed KrF excimer laser irradiation can dramatically enhance the p-type conductivity of GaN:Mg by efficiently dissociating the Mg-H complexes.

#### Co-doping.

It may be possible to use co-doping schemes to enhance dopant solubilities.<sup>62</sup> Also, dopant complexes may have not only higher solubilities, but possibly reduced ionization energies of acceptors and donors (e.g., Si+2Mg).

Point defect structure.

In general, a detailed investigations of point defect structure as it pertains to doping, by experiment (detailed characterization) and theory (fundamental physics), is needed. In addition, an understanding will be needed of how this point defect structure varies with alloy composition.

## **1.4.4 Novel Epimaterials**

AlGaInP and AlGaInN are the current dominant materials systems. However, similar kinds of bandgap engineering can be done in principle with other materials.

One of the prime candidates is ZnO, in which p-type doping has recently been demonstrated. Note, though, that these results have not yet been widely reproduced, and they may have stability issues because of poor thermodynamic miscibility.

Two additional possibilities are GaNP and GaNAs.<sup>63</sup> These materials are expected to span a very wide band gap range, and may possibly emit red, green, and blue light by changing the ratio of mixed crystals. Thus far, however, there has been a strong tendency towards phase separation in these materials -- regions of hexagonal [0001] oriented GaN, cubic [111] oriented GaAs and hexagonal [0001] oriented GaN {sub 1-x}As{sub x}. Also, the growth mode and optimum V/III ratio is affected dramatically by the addition of As flux, suggesting that arsenic is acting as an isoelectronic surfactant during the growth of GaN films.

<u>Recommendation</u>: Explore novel nitride-replacement epimaterials for high internal-radiative-efficiency (>80%) in the wavelength ranges UV(370-410), R(590-630) G(520-560) and B(440-480).

Impact=WC+CM+Hy; Risk=H; Reward=H.

#### Possible Approaches:

#### <u>ZnO</u>.

This material has recently been found to exhibit p-type conductivity, and is considered a prime candidate for homoepitaxial growth, doping and optical properties of nitride-replacement materials.

GaNAs and GaNP.

<sup>&</sup>lt;sup>60</sup> S. M. Myers, A. F. Wright, G. A. Petersen, W. R. Wampler, C. H. Seager, M. H. Crawford, and J. Han, "Diffusion, release, and uptake of hydrogen in magnesium-doped gallium

nitride: Theory and experiment," Journal of Applied Physics 89 (2001) 3195-3202.

<sup>&</sup>lt;sup>61</sup> S. M. Myers and A. F. Wright, "Theoretical description of H behavior in GaN p-n junctions," Journal of Applied Physics 90 (2001) 5612-5622.

<sup>&</sup>lt;sup>62</sup> H. Katayama-Yoshida, T. Nishimatsu, T. Yamamoto, and N. Orita, "Codoping method for the fabrication of lowresistivity wide band-gap semiconductors in p-type GaN, ptype AlN and n-type diamond: prediction versus experiment," Journal of Physics-Condensed Matter 13 (2001) 8901-8914.

<sup>&</sup>lt;sup>63</sup> S. V. Novikov, T. Li, A. J. Winser, C. T. Foxon, R. P. Campion, C. R. Staddon, C. S. Davis, I. Harrison, A. P. Kovarsky, and B. J. Ber, "The influence of arsenic incorporation on the optical properties of As-doped GaN films grown by molecular beam epitaxy using arsenic tetramers.," Physica Status Solidi B 228 (2001) 227-9.

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These materials are in their infancy. Because of the strong differences in binding energies and ideal growth temperatures between GaN and GaAs, and between GaN and GaP, they are not easy to synthesize. Also, there has been relatively more work on GaNAs than on GaNP.

The behavior of substitutional charged impurities in GaP has been well studied. The electronegativity of N is quite large at 3.0 compared to 1.64 for P. For this reason, an N atom strongly traps nearby electrons and the potential of these trapped electrons attracts positive holes to form excitons. Such impurities appear electrically neutral except

in their immediate vicinity, and therefore at short distances their potential operates to create deep levels. Likewise with GaN, differences in the electronegativity between P or As atoms and the N atoms of the mother crystal result in trapped positive holes, causing electrons to be drawn by Coulomb potential in the same fashion.

Much more work is necessary to establish the growth conditions as well as the optoelectronic properties of these materials.

## **2 PHYSICS, PROCESSING AND DEVICES**

At the heart of SSL-LED technology is the light "engine" chip. The "front-end" fabrication of this chip involves the substrate, buffer, and epitaxy technologies discussed in Chapter 1. The "back-end" fabrication of this chip involves the processing or shaping of the epiwafers into light-emitting devices, and is discussed in this Chapter.

As was the case for the front-end fabrication, the backend fabrication of the AlGaInP devices used for red light emitters is more mature than that of the AlGaInN devices used for green, blue and UV light emitters, though perhaps not by as much.

For AlGaInP devices, 50% chip power conversion efficiencies have already been demonstrated. However, these efficiencies are for deep red (650 nm) wavelengths, rather than for the mid-red (610 nm) wavelengths best suited for a tricolor white. And, these efficiencies decrease significantly at the high input-power densities necessary to meet our chip cost targets. Hence, there are still challenges associated with designing and fabricating band-gapengineered AlGaInP devices.

For AlGaInN devices, 20% chip power conversion efficiencies have been demonstrated. These efficiencies are still quite far from our targets; are at wavelengths that do not yet include the green and red ranges desired for the color-mixing approaches to white-light production; and also decrease significantly at the high input-power densities necessary to meet our chip cost targets. Hence, there are major challenges associated with designing and fabricating band-gap-engineered AlGaInN devices. Also, for AlGaInN, this band-gap engineering is complicated by unique electronic properties, such as strong piezoelectricity, as well as by the general immaturity of the materials.

In Section 2.1, we discuss the basic properties of AlGaInN materials and nanostructures, and the properties of electrons, holes and photons in these materials and nanostructures:

- How electrons and holes are created, how they move, and how they annihilate, either nonradiatively or radiatively.
- How photons are created from radiative recombination of electrons and holes, and how they can be manipulated to maximize escape from, rather than re-absorption by, the semiconductor.

In Section 2.2, we discuss post-epi device-level wafer processing. This Section is diverse, ranging from wafer

bonding and film transfer, to metallization, to etching, chip shaping and texturing for enhanced light extraction. Many of these processes are similar to, and borrow from, equivalent technologies for silicon integrated circuits. However, some, such as chip-shaping for efficient external light extraction, are unique to SSL-LEDs, and require overcoming special challenges. These are the processes that we focus attention on.

In Section 2.3, we discuss "simple" light-emitting diodes in which light is emitted spontaneously (and omnidirectionally) by the device. In Section 2.4, we discuss lasers or other devices in which light is emitted directionally. Both are possibilities for solid-state lighting, and both have advantages and disadvantages. Spontaneous emission devices are likely to be the least costly to fabricate, will be more linear with drive intensity and hence somewhat easier to control, and perhaps more sensitive to defects, but with less efficient extraction and directability of the light. Stimulated emission devices are likely to be more expensive to fabricate, will be less linear with drive intensity and hence somewhat more difficult to control, perhaps less sensitive to defects, but with more efficient extraction and directability of the light.

Decision: Will the SSL-LED light chip "engine" be based on spontaneous (LEDs) or stimulated (lasers) emission devices?

For both spontaneous and stimulated emission devices, an additional issue is the level of functionality will be integrated into the semiconductor chip. At one extreme, a single semiconductor chip provides only a single function: emission of monochromatic light at a particular wavelength. At the other extreme, a single semiconductor chip emits light at all the colors necessary for white light, and includes the electronics required to drive and control intensity, color, directionality and focus.

Decision: Will the SSL-LED light chip "engine" be a single-function generator of monochromatic light, or will it monolithically integrate other functions, such as white-light production and programmable drive electronics?

## **2.1 Semiconductor Physics**

In this Section we discuss the basic materials properties of AlGaInP and AlGaInN semiconductors. Particularly for the AlGaInN semiconductors, fundamental knowledge of these properties is substantially less well developed compared to conventional AlGaInAs- and GaInPAs-based compound semiconductor materials, and compared to silicon. The difficulties stem, in part, because the AlGaInN materials system itself comes in four "flavors":

- Crystallographically perfect bulk materials
- Crystallographically perfect materials fabricated into nanostructures for bandgap engineering purposes
- Crystallographically imperfect bulk materials
- Crystallographically imperfect materials fabricated into nanostructures for bandgap engineering purposes

The last two flavors are perhaps the most common, because of the lack of suitable substrates for epitaxial growth, which leads to epitaxial films with high defect densities. These defects produce electronic states in the band gap that can both modify the overall properties of the material, as well as cause difficulties in measuring those properties.

Also, 2D, 1D and 0D nanostructures fabricated from these materials have properties very different from those of bulk materials, and can be exploited for bandgap engineering purposes. In particular, semiconductor nanostructures will manifest three phenomena: modification and concentration of the electronic density of states; the possibility of materials with higher strain and a wider accessible range of materials compositions and bandgaps; and enhanced carrier confinement and trapping.

It is necessary to improve our understanding of, and ability to manipulate, the physical properties of materials with all four "flavors." Only then can we take full advantage of these materials for scientific design of efficient optoelectronics.

In Challenge 2.1.1, we discuss the basic properties of AlGaInN materials. In Challenge 2.1.2, we discuss highefficiency recombination of electrons and holes to create photons. In Challenge 2.1.3, we discuss the manipulation of photons through nanostructures engineering to control the directionality and extraction of photons from the device.

## 2.1.1 AlGaInN Material Properties

Most of the properties of AlGaInP semiconductors are well established. However, the properties of AlGaInN semiconductors are not yet well established. These properties range from even basic ones such as electronic band gap to more subtle ones such as polarization field constants. Some of these properties are listed here.

- AlGaInN Structure. For the common semiconductors InP), (Si, GaAs, one crystallographic structure (diamond cubic) is overwhelmingly favored. For AlGaInN semiconductors, this is not the case. Both hexagonal and cubic phases can be grown. Most devices are currently fabricated from the hexagonal phase; however, devices can also be fabricated from the cubic phase, and there is now a growing literature on the synthesis and properties of this material, particularly by MBE. Moreover, cubic AlGaInN has several properties that make it interesting for devices: it is easier to dope, cleave (especially useful for laser facets) and contact; and it may have higher electron and hole mobilities. Hence, it is of interest to understand the forces that control growth of one or the other of these phases.
- <u>AlGaInN Microstructure</u>. For the common semiconductors (Si, GaAs, InP), microstructure is usually featureless (very few extended defects or compositional nonuniformities). For AlGaInN, however, phase separation into compositionally modulated "quantum-dot-like" material is not only common, but perhaps essential to performance. The quantum-dot-like regions trap free carriers and prevent them from recombining nonradiatively at extended defects. Hence, it is of interest to understand the forces that drive microstructure development, and especially phase separation.
- AlGaInN Electronic Band Structure. The basic electronic band structure of a semiconductor determines how electrons and holes move and recombine in bulk materials and in heterostructures. Of primary importance are the main features of the band structure: band-gaps, band-offsets, and effective carrier (electron and hole) masses. Of secondary importance are the derived properties of the band structure, such as dielectric properties.

To maximize the device designer's ability to take advantage of the full range of AlGaInN alloys, it is important to establish these properties for all the quaternary compositions. In addition, since strain (both intentional and unintentional) and hightemperature operation are universal features of AlGaInN devices for solid-state lighting, these properties need to be established for a range of strains (+/- 5%) and temperatures (0-200C). Also, although almost all current devices are



Figure 15. Electron and hole wave-functions in quantum wells are spatially separated when oriented along polar vs. when oriented along non-polar directions. After P. Waltereit, O. Brandt, A. Trampert, H. T. Grahn, J. Menniger, M. Ramsteiner, M. Reiche, and K. H. Ploog, "Nitirde semiconductors free of electrostatic fields for efficient white light-emitting diodes," Nature 406 (2000) 865-868.

fabricated from hexagonal AlGaInN, there may be some benefit to the use of cubic AlGaInN, hence it will be helpful to establish these properties for both hexagonal and cubic<sup>64</sup> AlGaInN.

 <u>Polarization Fields</u>. A unique feature of AlGaInN materials is polarization fields, due to their noncubic symmetry. These fields are of two kinds: spontaneous polarization (SP) and piezoelectric polarization (PZ). Both fields are significant and are about an order of magnitude higher than those observed in the common narrower-bandgap zincblende III-V semiconductors.

The consequence of these polarization fields is significant. For example, in the presence of an interface the difference in the SP or PZ coefficients in the two materials gives rise to a net charge at the interface. In the common case of a quantum well (QW), i.e. a lower bandgap thin semiconductor layer sandwiched between two higher bandgap cladding layers, the two interfaces will have opposite charges, and a strong electric field will be produced across the QW. These fields modify the energy band levels as well as give rise to charge separation and Stark effects which, as illustrated in Figure 15, modify carrier recombination rates and energies. The equivalent sheet charge densities are on the order of 1e13/cm<sup>2</sup>, and the resulting electrostatic barriers for charge confinement are comparable in magnitude to those created by band offsets at typical heterojunctions.

Hence, a quantitative understanding of these polarization fields is necessary in order to understand how to best engineer device heterostructures for carrier transport, trapping and radiative recombination.

<u>Phonons.</u> At finite temperatures, and especially at the higher temperatures of operation afforded by AlGaInN materials, phonons will be present. Phonons are the dominant mechanism for carrier scattering through deformation potentials and piezoelectric fields at typical operating (0-200C) temperatures of SSL-LED devices. And, phonons may couple with photons to create polaritons with mixed optical properties, and may couple with electrons to create polarons with mixed electronic properties.

Phonon effects are especially strong in AlGaInN Because nitrogen is materials. more electronegative than the group V atoms in the narrower-bandgap III-V materials, the ionic component of the chemical bond in AlGaInN materials is also much stronger. This, in turn, results in higher optical phonon energies and greater polaron effects. Such fundamental quantities as the Frohlich coupling constant for electron/LO-phonon interactions need to be measured.

A central related question is whether, in p-doped high-Al-content AlGaN, polarons will form (i.e., self-trapping of holes by coupling to phonons – this is the DX-center analogy).

Moreover, because the bond strengths and elastic constants for AlN, GaN and InN are so different, the phonon frequencies and dispersion curves are very different in each these materials. Hence, not only are bulk phonons important, but phonons confined to heterointerfaces are also important,<sup>65</sup> as well as phonons confined in 0D structures such as quantum dots.

<sup>&</sup>lt;sup>64</sup> S. F. Chichibu, M. Sugiyama, T. Kuroda, A. Tackeuchi, T. Kitamura, H. Nakanishi, T. Sota, S. P. DenBaars, S. Nakamura, Y. Ishida, and H. Okumura, "Band gap bowing and exciton localization in strained cubic InxGa1-xN films grown on 3C-SiC (001) by rf molecular-beam epitaxy," Applied Physics Letters 79 (2001) 3600-3602.

<sup>&</sup>lt;sup>65</sup> E. F. Bezerra, A. G. Souza, V. N. Freire, J. Mendes, and V. Lemos, "Strong interface localization of phonons in nonabrupt InN/GaN superlattices," Physical Review B 6420 (2001) 1306.

Electron and hole transport. Transport of electrons and holes from the contacts to the active regions is an essential step enroute to radiative recombination within the active regions. The transport may be a complex convolution of perpendicular and parallel paths, particularly if significant lateral current spreading is required, as it is with the current generation of devices.

Hence, it is essential to understand the transport dynamics of electrons and holes, in order to understand how they can best be manipulated through alloy and heterostructure composition and design.

• <u>Defects</u>. Defects of many kinds are present in device heterostructures.

Of primary importance are point defects – including impurities useful for doping. These and other point defects determine the achievable doping levels and conductivities, and the ability to optimize vertical and lateral current transport in devices. If they lead to deep levels, they can also lead to nonradiative recombination that competes with the radiative recombination.

Of secondary importance are extended defects including dislocations. These defects are a universal presence in AlGaInN materials, as they are the vehicles for strain relaxation in buffer layers used for virtually all current AlGaInN-based They are of secondary importance devices. because it is now well-established that they are all (edge, screw and mixed, e.g.) detrimental to device performance - they are responsible for deep level traps, for nonradiative recombination paths, as well as for alternate, multi-stage and red-shifted radiative recombination paths. Hence, it is of the greatest importance to understand how to eliminate these defects. It is of lesser importance to understand their energetics and thermodynamics, except as this may assist in understanding how to eliminate or passivate them.

<u>Recommendation:</u> Firmly establish the physical constants of AlGaInN alloys – including mechanical properties, electron band-structure and transport, phonons and piezoelectric effects, and defects.

Impact=WC+CM+Hy; Risk=M; Reward=H.

Possible Approaches:

EXAFS.

Extended x-ray absorption fine-structure measurements of local bonding arrangements would be helpful in extracting miscibility parameters of AlGaN and InGaN ternary alloys.

Thermodynamics of AlGaInN Crystallography. Our current understanding is that the hexagonal phase is thermodynamically more stable than the cubic phase for all the AlGaInN alloys [ref Edgar 1994]. However, the degree of stability depends on alloy composition and temperature, and it is possible that for a range of compositions and at high growth temperatures, the cubic phase is either more stable or only marginally less stable. Careful thermodynamics studies, as well as the creation of metastable phases through kinetic factors would be helpful.

Thermodynamics of AlGaInN Microstructure. Our current understanding of the compositionally nonuniform microstructure of InGaN alloys is that it is related to an interplay between chemical forces and microscopic strain. All pseudobinary III-V compound semiconductors are characterized by significant microscopic strain due to size mismatches amongst the alloying atoms. This is especially the case for AlGaInN alloys, for which bond strengths are large (2.28 eV for AlN, 2.2 eV for GaN, 1.93 eV for InN) and deformations energetically costly. This microscopic strain causes a miscibility gap, and a tendency for phase separation. The magnitude of this gap has been estimated for the hexagonal AlGaInN alloys and for some of the cubic AlGaInN alloys -- there are some indications that the gap is greater in cubic GaN than in hexagonal GaN. However, we do not yet have a good understanding of how and why the quantum-dot-like microstructure forms for the various alloys and for various growth conditions.

Samples with controlled strains and electric fields.

Since strain-induced polarization fields are so pervasive, it has been difficult to unambiguously measure intrinsic electronic band structure properties (including bandoffsets). Hence, the preparation of high-quality materials with known or controlled strain will be helpful.

Also, the preparation and study of alloys with controlled (or no) compositional modulation could help unravel the effects of composition-modulation-induced polarization fields.

Finally, it may also be helpful to study samples under controlled external modification of stress (e.g., wafer flexing, hydrostatic pressure), or electric fields (e.g., modulation spectroscopies such as electroabsorption, electrotransmission, photoreflectance).

Ternary and quaternary electronic band structure.

For hexagonal GaN, which has been the easiest material to obtain in high quality, most of the overall electronic band structure properties have been established. This material is similar in structure to that of many well-studied II–VI compounds such as CdS, hence are similar in some properties. E.g., the lower-than-cubic symmetry very likely gives rise to three separate and anisotropic valence bands at the zone center, though this has not yet been confirmed by measurements.

Much less detail is available for AlN, InN, or for the ternary AlGaN, GaInN, AlInN and quaternary AlGaInN alloys. Even the bandgap of pure unstrained InN is not yet certain, with reports varying from 0.9 to 1.89eV. And, even less detail is available for the cubic variants of these alloys.

Band offsets are particularly poorly established. Due to the strong influence of strain on the band structure, and the different symmetry of the upper valence bands in e.g. GaN and AlN, offsets can only be defined if the strain field is known. For example, it has been predicted that for the AlN/GaN interface the valence band offset is 0.20 eV for AlN lattice matched to GaN, but 0.85 eV for GaN lattice matched to AlN [ref].

The band structure of heavily doped materials is also tricky. Relativistic calculations may be necessary, because of strong spin-orbit and electron-phonon coupling.

Taxonomy of point and point defect clusters.

It would be helpful to have systematic studies leading to a taxonomy of point and point defect clusters. These would include the energies and charge states of p-type impurities in the In-rich and Al-rich AlGaInN alloys; and interactions between point defects to form passivated or compensated complexes, and the resulting shallow or deep levels. Also, compensation at high doping levels.

Trapping and escape of hot carriers.

The final destination of electrons and holes are typically quantum wells within which they are trapped, but from which they can sometimes escape. Although wells can be fairly deep in the AlGaInN family of materials, when devices are driven very hard and at fairly high junction temperatures, escape can be a dominant non-radiative carrier leakage path.<sup>66</sup> Understanding this escape and how to control it will be important to achieving high-radiativeefficiency devices.

## Electron and hole scattering.

It will be helpful to have systematic studies of the basic mechanisms for electron and hole scattering. These mechanisms include:

- intrinsic scattering from acoustic and optical phonons (complicated by abnormally strong contributions from piezoelectric fields)
- extrinsic scattering from line defects such as dislocations (which may, depending on doping and Fermi level, be charged);
- extrinsic scattering from material microstructure, such as composition fluctuations.
- scattering at the high carrier densities characteristic of heterojunctions, and the influence of screening.
- relaxation and transport of hot electrons as they are injected into thin quantum wells.

## 2.1.2 High-Radiative-Efficiency Electron-Hole Recombination

One of the most central Challenges is the recombination of electrons and holes to create photons. In principle, this process can be very efficient, and in many materials and heterostructures does indeed approach 100%. It is in large part because of the high potential efficiency of this process, that Solid-State Lighting is viewed as ultimately more efficient than any of the traditional technologies.

In practice, however, electrons and holes may recombine in many ways that do not lead to photons. They may interact with defects and recombine non-radiatively. They may be injected into heterostructures, but then, particularly at higher injected currents or temperatures, may escape before recombining. Understanding the physics of how electrons and holes interact with each other, and with the heterostructures they are injected into, is essential to the engineering of ultra-high-efficiency electron-hole radiative recombination.<sup>67</sup> Among the issues are the following.

Heterostructures. Because of their charge, electrons and holes interact strongly with each other, and with the electric fields and potential barriers associated with heterostructures.68 These interactions modify electron and hole energy levels, thereby modifying recombination energies and wavelength. They also modify the spatial overlap of the electron and hole wave functions, thereby modifying recombination rates. Hence, an understanding of these effects is necessary for tailoring the light emission wavelengths of devices, and for optimizing the efficiency of radiative recombination.

<sup>&</sup>lt;sup>66</sup> P. Hurst, P. Dawson, S. A. Levetas, M. J. Godfrey, I. M. Watson, and G. Duggan, "Temperature dependent optical properties of InGaN/GaN quantum well structures," Physica Status Solidi B-Basic Research 228 (2001) 137-140.

<sup>&</sup>lt;sup>67</sup> Weng W. Chow, "Physics of Optical Response in Group-III Nitride Active Structures," OIDA Solid-State Lighting Workshop (Albuquerque, May 30, 2002).

<sup>&</sup>lt;sup>68</sup> B. Monemar and G. Pozina, "Group III-nitride based hetero and quantum structures," Progress in Quantum Electronics 24 (2000) 239-290.

Microstructure. In microstructurally perfect material (in the absence of defects), radiative recombination is generally an extremely efficient process in III-V semiconductors. In the presence of defects as numerous as those found in AlGaInN material, however, non-radiative recombination typically becomes a very efficient competing channel.69 Surprisingly, AlGaInN emits very efficiently (though with much room for improvement). There is a belief that localization effects are important, either through In-rich composition heterogeneities, or through polaron effects, but there are as yet no definite conclusions regarding the origin of the process. Indeed, figuring out ways to maintain high radiative recombination rates without localization would be significant, since localization may impede electron and hole transport. Comparative investigation of quantum well vs. quantum wire, vs. quantum dot active regions should be employed.

Excitons. The most basic electron-hole interaction is the formation of excitons, or electron-hole pairs bound together by Coulomb attraction. In most III-V semiconductors the binding energy is relatively weak, and excitons are observed mainly at lower temperatures. However, in AlGaInN semiconductors, the binding energy is much larger. The reason is their strong ionicity, which leads to less covalent electron density between the ion cores, and less screening of the Coulomb attraction between electron and hole. This is similar to the II-VI materials (e.g., CdS, CdSe, ZnO), for which excitonic effects have been unambiguously shown to enhance radiative recombination in II-VI semiconductor quantum wells.

Electric Fields. An additional important interaction is with electric fields in heterostructures. In an electric field, electrons and holes become spatially separated. In quantum wells with a non-zero polarization field, this leads to what is called the Quantum-Confined Stark Effect (QCSE). In the QCSE, the field within the quantum well separates the electron and hole wave functions, decreasing their radiative recombination rate, and red-shifting their recombination transition energies. For AlGaInN materials, characterized by significant spontaneous and piezoelectric polarization fields, the effect on radiative recombination rate and transition energies can be quite large.

Other potential effects are strong modifications of: the bandstructure; modification of exciton binding to defects; modification of interactions with phonons to form polarons.

<u>Recommendation</u>: Understand and control electron-hole interactions and exciton formation in heterostructures, so as to enable high internal-radiative-recombination efficiencies (Year 1 60% at 100C at 50A/cm<sup>2</sup>; Year 3 60% at 125C at 150A/cm<sup>2</sup>; Year 5 90% at 150C at 250A/cm<sup>2</sup>) over the full range of wavelengths (370-630 nm).

Impact=WC+CM+Hy; Risk=H; Reward=H.

## Possible Approaches.

#### Engineering of Imperfect Heterostructures.

There are open questions regarding how electrons and holes recombine in the presence of heterostructures with intrinsic imperfections (such as quantum wells with wellwidth fluctuations).

#### Time-resolved PL and PLE.

Time-resolved photoluminescence and photoluminescence excitation spectroscopies will be important in elucidating the dynamics of electron-hole recombination, and its nature.<sup>70</sup>

#### Controlled microstructures.

Systematic studies of special samples with very low defect densities, or defects of controlled types, could be important.

## Controlled heterostructures.

Systematic studies of recombination in special 3D, 2D (quantum well), 1D (quantum wire) and 0D (quantum dot) nanostructures, might also be important.

## Electric and polarization fields.

Since electric and polarization fields play such a strong role in modifying electron-hole interactions, engineering of these fields through screening by dopants, through external modulation, or band-gap engineering will also be useful.

## Spatially resolved luminescence.

An understanding of recombination from point or extended defects, will also be useful. For example, is the

<sup>&</sup>lt;sup>69</sup> A. Hierro, M. Hansen, J. J. Boeckl, L. Zhao, J. S. Speck, U. K. Mishra, S. P. DenBaars, and S. A. Ringel, "Carrier trapping and recombination at point defects and dislocations in MOCVD n-GaN.," Physica Status Solidi B 228 (2001) 937-46; T. Miyajima, T. Hino, S. Tomiya, K. Yanashima, H. Nakajima, T. Araki, Y. Nanishi, A. Satake, Y. Masumoto, K. Akimoto, T. Kobayashi, and M. Ikeda, "Threading dislocations and optical properties of GaN and GaInN.," Physica Status Solidi B 228 (2001) 395-402.

<sup>&</sup>lt;sup>70</sup> Shih-Wei Feng, Yung-Chen Cheng, Chi-Chih Liao, Yi-Yin Chung, Chih-Wen Liu, Chih-Chung Yang, Yen-Sheng Lin, Kung-Jeng Ma, and Jen-Inn Chyi, "Two-component photoluminescence decay in InGaN/GaN multiple quantum well structures.," Physica Status Solidi B 228 (2001) 121-4.



Figure 16. A 2D photonic crystal that surrounds a "defect" cavity from which a light emitter may be constructed. After A. Scherer, J. Vuckovic, and M. Loncar, "Efficient Light Emitter Geometries," OIDA Solid-State Lighting Workshop (Albuquerque, May 30, 2002).

famous yellow emission due to a combination of Ga vacancy-impurity complexes and dislocations, and what is the nature of donor-acceptor recombination? To understand these questions, it may be useful to explore further spatially resolved luminescence spectroscopies, such as CL (cathodoluminescence), EBIC (electron-beam-induced current) and NSOM (near-field scanning optical microscopy).

#### Transport and recombination models.

It may be useful to develop comprehensive, coupled models of electron-hole transport, trapping and recombination processes. These can take the form of simple rate equation as well as more-complex finiteelement simulations.

## **2.1.3 Photon Manipulation**

Once photons have been created in the semiconductor material, they must be extracted. The development of an understanding of how to guide, reflect, and manipulate the flow of photons will be critical to this.

One recent and particularly intriguing development is photonic band gap materials. These materials are the optical analog of semiconductors with an electronic band gap. Periodic variations in dielectric constant forbid certain photon energies within the photonic lattice. These kinds of structures have the potential to guide and reflect light in a spectrally controlled manner, and to create cavities in which optical modes and spontaneous emission patterns may be modified.

For example, preliminary theoretical and experimental results indicate that they may be used to enhance light output levels of LEDs through both inhibition of, and extraction of light from, in-plane guided modes.<sup>71</sup> An example of such a structure is illustrated in Figure 16.

The physics of these structures, their fabrication methods, and their insertion into devices are all in their infancy. Much more basic and fundamental work is necessary in order to understand how these structures may be used to manipulate light and enhance radiative efficiencies and especially extraction efficiencies.

<u>Recommendation:</u> Explore novel micro- and nanostructures for dispersive, guided-wave manipulation of photons for higher-external-efficiency (Year 1 30%, Year 3 50%, Year 5 70%) light-emitting devices.

Impact=WC+CM+Hy; Risk=H; Reward=H.

## Possible Approaches.

## Heterogeneous media.

Photonic crystals are only a small subset of heterogeneous media that could, and should, be investigated for enhanced spontaneous emission as well as beam directionality. Some of these alternative media may not require the very high degree of lithographic precision characteristic of photonic crystals. Instead, they may rely on molecular and mesoscale self-assembly, and hence be more practical to fabricate. The common thread is the possibility of materials in which the photon mean free path is short yet still low loss, and in which there is a high density of nanoscale light-emitting centers or clusters.

## Fabrication.

Because of the size scale of the wavelengths of visible and near-UV light, the size scale of photonics crystals are very small, and fabrication will be difficult. Novel techniques may be necessary, including self-assembled opal-like nanocomposites and MEMS-like fabrication techniques.

#### Surface plasmons.

At surfaces and interfaces, at which there is a strong index step, it is common for electromagnetic waves to form bound waves. When combined with periodic surface

<sup>&</sup>lt;sup>71</sup> H. Y. Ryu, J. K. Hwang, Y. J. Lee, and Y. H. Lee,

<sup>&</sup>quot;Enhancement of Light Extraction From Two-Dimensional Photonic Crystal Slab Structures," IEEE Journal of Selected Topics in Quantum Electronics 8 (2002) 231-237.

structures, it may be possible for these bound waves to outcouple light into radiation efficiently.

Photon-mode engineering.

Advanced solutions for the light extraction problem may rely on photon-mode engineering. In order to inhibit the generation of light in unfavorable directions, microcavities,<sup>9</sup> photonic crystals (i.e., structures with a periodic pattern of the refractive index) and emitters with surface-plasmon enhancement.

## **2.2 Device Processing**

Assuming a device has been designed, using the physicsbased understanding discussed above, and assuming the appropriate epilayers have been grown, the next step in fabrication of the light-emitting chip engine is device processing. These are the final processes that are done to the substrate and the epilayer, just before the wafer gets diced into chips and packaged.

Epitaxy and device processing are the wafer-level fabrication steps whose manufacturing economics scale with wafer size. It is to the advantage of any semiconductor technology to move as much processing to the wafer level as possible, to take advantage of these economics.

In this Section, we discuss this wafer-level processing -methods by which the epilayers are laterally patterned into chips with a complex arrangement of etched and deposited thin films and chip shapes. We discuss them roughly in the order of the flow from the "front-end" to the "back-end.

In Challenge 2.2.1 we discuss processes by which epilayers are bonded and transferred to other substrates. These epilayer transfer processes give device designers greater flexibility in mixing and matching materials that normally incompatible.

In Challenge 2.2.2 we discuss metallization – particularly the ohmic contacts through which high input current densities must flow into the device, and which must have very low resistances and be very robust.

In Challenge 2.2.3 we discuss etching, chip-shaping and texturing. These are the processes that are used to carve 3D shapes into the 2D epilayers, to engineer the transport of electrons, holes photons.

Note that processes that are in common use across the silicon and compound semiconductor industry we don't discuss, since they use tools and technologies that are already well-developed from these other technologies. Instead, we focus on those processes which are unique to SSL-LEDs, and which require overcoming special challenges.

## 2.2.1 Wafer Bonding and Film Transfer

It is often the case that one family of epitaxial semiconductor materials cannot satisfy all the materials properties necessary for the functionality of a particularly device. This is especially the case with multi-functional devices, such as MEMS (microelectromechanical systems), in which electronic and mechanical functions are combined, or optoelectronics, in which electronic and optical functions are combined. For these kinds of devices, methods are been developed for monolithically integrating materials to provide enhanced functionality. Wafer bonding and film transfer are two promising examples of such methods.

For example, AlGaInP LEDs are normally grown on GaAs substrates. However, the smaller band-gap GaAs substrate absorbs the light produced by the higher-energy AlGaInP active region, thereby limiting the brightness of the LEDs. One approach to circumventing this problem is to use wafer bonding to provide a transparent GaP substrate in place of the original GaAs growth substrate.

In this technique, the GaAs substrate is selectively removed after growth, and the GaP substrate is fused to the AlGaInP layers by elevated heat and pressure. The resulting bond is conductive and provides for a verticalconduction transparent substrate AlGaInP LED.

These transparent substrate AlGaInP LEDs are at least a factor of two more efficient than conventional absorbing substrate AlGaInP LEDs. For devices employing GaAs (absorbing) substrates, a maximum extraction efficiency of about 15% is achieved using thick transparent windows on top of the active region. For transparent substrate devices, extraction efficiencies as high as 50% have been determined for conventional-geometry devices in the red wavelength regime. At this point, transparent substrate AlGaInP materials have provided the platform for the world's most efficient visible-spectrum LEDs to date.

Wafer bonding and thin film transfer processes are not yet used in commercial AlGaInN devices, though they are beginning to be explored. Since sapphire is a transparent substrate, its removal is not as important as it is for GaAs in the AlGaInP/GaAs case.

However, substrate removal would enable additional flexibility in device design. For example, it would enable two-sided integration with optical elements, such as DBRs. Indeed, the first VCSEL (optically pumped) in AlGaInN was fabricated using laser lift-off and bonding.

And, if a sequential layer-transfer technique such as Smart-Cut could be developed for GaN, a reusable substrate technology could be very exciting. E.g., Thick GaN HVPE grown on lithium gallate followed by multiple smart-cut onto cheaper substrates (as discussed in the Buffers on Reusable Substrates Section).

Some of the issues in this area are:

- Scale-up of bonding and/or film transfer to 2" (Year 1), 3" (Year 3) and, ultimately, to 4" (Year 5) wafers. Related to this is the ability to do wafer bonding and film transfer without loss of operating or active semiconductor volume.
- Resistance of bonded interfaces, in cases where electrical current must pass through the interface. This may require better understanding and control of contamination (e.g., carbon) at the bonding interface, as well as of the in-plane rotational alignment between the two wafers.<sup>72</sup>

A particularly interesting avenue may be the monolithic integration of AlGaInP and AlGaInN through wafer bonding and film transfer. This would enable the integration of the brightest red-emitting material with the brightest blue- and green-emitting material.

<u>Recommendation</u>: Develop scaled-up (4") high-yield GaN wafer bonding and single or multiple film-transfer processes to enable economical removable-substrate technologies, as well as improved optical engineering and integration.

Impact=WC+CM+Hy; Risk=M; Reward=M.

Possible Approaches:

Laser lift-off

Smart-Cut (implantation-based layer removal)

Selective etching

<u>GaN/on</u> <u>Si liftoff</u>

Metal/film transfer

## **2.2.2 Metallization and Thin Films**

High-quality ohmic contacts are essential to high-power devices. If they do not have a low resistance they will dissipate some electrically injected power, leading to parasitic ohmic losses and excess device heating.

Typical ohmic contact technologies used in GaN-based devices are:

- n-type: Ti/Al with 600C annealing.
- p-type: Ni/Au with 400C annealing.

The limitations, however, which are much more severe for AlGaInN materials than they are for AlGaInP or AlGaInAs materials. Most of the limitations are on the ptype contact side, and stem from the inability to create heavily p-doped GaN material. And, if the Mg doping does become very heavy, it can diffuse into the active region during subsequent processing, quenching luminescence

In addition, since the metallization generally covers at least one side of the LED (unless good current spreading layers can be developed), metallizations that have secondary properties (in addition to high electrical conductivity) such as high optical reflectance or transmission, have also become important.

Finally, the metallizations must be reliable to 100,000 hrs, and must withstand high operating (150C) and soldering (>300C) temperatures associated with die-attach or flipchip bonding of the LED chip to the lamp package.

<u>Recommendation</u>: Develop metallization processes for n and especially p type AlGaInN materials with low (Year 1 1e-3 ohms-cm<sup>2</sup> at 100C and 50A/cm<sup>2</sup>, Year 3 1e-4 ohmcm<sup>2</sup> at 125C and 150A/cm<sup>2</sup>, Year 5 1e-5 ohm-cm<sup>2</sup> at 150C and 200A/cm<sup>2</sup> lead-free) electrical contact resistance, and desirable optical properties such as high (>90%) reflectance or transmission.

Impact=WC+CM+Hy; Risk=M; Reward=M.

## Possible Approaches:

## Polarization-field enhanced contacts

Because of their wurtzite symmetry, and because of strain that is often present, AlGaInN materials have strong piezoelectric and polarization fields associated with them. These fields can be used to create sheet charges that can decrease contact resistances significantly. For example, utilizing a thin n-type Al{sub x}Ga{sub 1-x}N layer on top of n-type GaN, a metal-semiconductor contact resistance

<sup>&</sup>lt;sup>72</sup> J. J. O'Shea, M. D. Camras, D. Wynne, and G. E. Hofler, "Evidence for voltage drops at misaligned wafer-bonded interfaces of AlGaInP light-emitting diodes by electrostatic force microscopy," Journal of Applied Physics 90 (2001) 4791-4795.

of 8.5\*10{sup -5} Omega cm{sup 2} has been demonstrated without high temperature annealing, based on polarization fields in the thin Al{sub x}Ga{sub 1-x}N layer.<sup>73</sup>

#### <u>Bi-metal contacts for high reflectance and low contact</u> resistance

Most metals (particularly those which "stick" well and hence aren't free-electron metals) are poor reflectors. Hence, it is unlikely that contact metallizations will ever have extremely high reflectance. However, by optimizing the thickness of bimetal combinations, it may be possible to increase reflectance somewhat. For example, 70% reflectivity and 2x10-5 ohm-cm<sup>2</sup> contact resistivity in ntype electrodes have been demonstrated by optimizing the conditions for Ti/Al contact formation. Alternative materials, such as ZnO/Ni/Ag for n-type electrodes, and Pt/Ag for p-type electrodes, are also being explored. Over 90% has also been demonstrated!

Metal oxides (e.g., ITO) for optically transparent contacts

Most metals are also opaque. Hence, it is unlikely that contact metallizations will ever have extremely good transparency. Some metal oxides, however, have reasonable conductivities and reasonable transparencies. For example, Ni/indium tin oxide (ITO) ohmic contacts to p-type GaN (~2\*10{sup 17} cm{sup -3}) have been demonstrated with specific contact resistivity of 8.6\*10{sup -4} Omega cm{sup 2} and high transparency (above 80% for 450-550 nm) upon annealed at 600 degrees C in air.<sup>74</sup>

Improved processing of conventional Ti-based n and Nibased p contacts

For both conventional Ti-based n contacts, and Ni-based p contacts, there is much that is not understood about the effects of surface treatments before metallization, of interfacial reactions between the metal and the semiconductor after metallization and subsequent annealing. E.g., oxygen plasma treatments, (NH4)(2)S-x solution treatments, Be prediffusion, etc., all have a significant but poorly understood effect on the quality of the ohmic contact, possibly due to interfacial conducting gallium oxides or oxynitrides created at the surface. These effects are compounded by effects due to the overlayer metal (e.g., Au, Pd or Pt in the case of p contacts), which in some cases one also would like to be either highly reflecting or highly transparent.

## 2.2.3 Etching, Chip-Shaping, Texturing

In many of device configurations, there is a common need for fabricating optically engineered structures for reflecting or refracting light. These structures require processes that etch or shape the material. This is the case for both AlGaInP and AlGaInN materials, though AlGaInN, being refractory and relatively chemically inert, has special challenges.

For example, edge-emitting laser devices require facets. These facets can be created by cleaving in the AlGaInP/GaAs system, but not easily in the AlGaInN/sapphire system, because of the symmetry of the sapphire substrate. Hence, it would be helpful to develop etched, rather than cleaved facets. In fact, even for AlGaInP/GaAs lasers, it may be helpful to develop etched facet technology, in order to facilitate on-wafer test, maximize usable substrate area, and lower cost.

Chip shaping and texturing are perhaps even more critical. Light extraction depends strongly on the shape of the chip that surrounds the active light-emitting area, and on the texture of the surfaces through which light is being emitted.

Photons may escape only at incident angles smaller than the critical angle of the total internal reflection, as illustrated in Figure 17. The solution widely used at present is to clad the light emitting layer with thick, transparent window layers.

Hence, the difference between a conventional and a highbrightness LED. In a conventional LED, light generated at a certain point in the active layer may only escape upward through a narrow cone. Almost all of the light emitted in other directions is totally reflected and absorbed in the substrate and/or in the active layer. Ideally, the best performance would be achieved in a spherical LED. In practical planar high-brightness LEDs, thick window layers allow the light to escape through six cones. The thick window layers allow the light generated at the center of the chip to escape through the lateral conical paths. Most commercial high-brightness LEDs exhibit light-extraction efficiencies somewhat below 30%.

In order to improve the light-extraction efficiency further, the LED design can employ nonrectangular geometries, textured surfaces,<sup>75</sup> and encapsulants with a

<sup>&</sup>lt;sup>73</sup> Yun-Li Li, J. W. Graff, E. L. Waldron, T. Gessmann, and E. F. Schubert, "Novel polarization enhanced ohmic contacts to n-type GaN.," Physica Status Solidi A 188 (2001) 359-62.
<sup>74</sup> Ray-Hua Horng, Dong-Sing Wu, Yi-Chung Lien Lien, and W.-H. Lan, "Low-resistance and high-transparency Ni/indium tin oxide ohmic contacts to p-type GaN.," Applied Physics Letters 79 (2001) 2925-7.

<sup>&</sup>lt;sup>75</sup> R. Windisch, C. Rooman, B. Dutta, A. Knobloch, G. Borghs, G. H. Dohler, and P. Heremans, "Light-Extraction Mechanisms in High-Efficiency Surface-Textured Light-Emitting Diodes," IEEE Journal of Selected Topics in Quantum Electronics 8 (2002) 248-255.



Figure 17. Schematic of light transmitted through, or total internal reflected from, a planar semiconductor surface; and the resulting angular escape cone. After Arturas Zukauskas, Michael S. Shur, and Remis Caska, Introduction to Solid-State Lighting (John Wiley and Sons, Inc., New York, 2002).

higher refractive index (at present, epoxy resins with  $n_{e}$  1.6 are used).

The highest performances of AlGaInP/ GaP LEDs are achieved using chips that deviate from a conventional rectangular shape.<sup>76</sup> A truncated inverted pyramid (TIP) shape, which is achieved by dicing a chip with a beveled blade to yield side-wall angles of 35° with respect to the vertical,<sup>7</sup> greatly improves light-extraction. Such a shape totally redirects internally the reflected photons at small incidence angles that fit the escape cones. As of this writing, the AlGaInP TIP LED holds the performance record for an electroluminescent visible-light source. In the orange region (610 nm), it exhibits the highest reported luminous efficiency, exceeding 100 lm/W (close to that of sodium lamps) with a peak luminous flux of 60 lm. In the red region (650 nm), external quantum efficiencies of as high as 55% have been achieved.

Although it may be difficult to separately target internal conversion efficiency and external extraction efficiency, if our chip conversion efficiency goals are 30% in Year 1, 40% in Year 3 and 60% in Year 5, it is expected that external extraction efficiencies will ultimately need to target 90%.

<u>Recommendation</u>: Develop economical (<10\$/cm<sup>2</sup>) designs and processes for etching, shaping and texturing devices and chips for >90% external extraction efficiencies, while minimizing surface damage and active-area (<10%) loss.

Impact=WC+CM+Hy; Risk=M; Reward=H.

#### Possible Approaches.

#### Dry etching.

Key issues here are rates, anisotropy, selectivity, and damage<sup>77</sup> (subsurface vacancy complexes which can enhance surface conductivity).

#### Ray tracing and waveguide modeling.

The development of first principles modeling for light extraction and the identification of new methods for light extraction is a particularly rewarding area.

#### Photoenhanced electrochemical etching.

Has the potential for dopant type and bandgap selectivity.<sup>78</sup>

#### Laser ablation for etching and polishing.

Etching of GaN by ablation using KrF excimer or F{sub 2} laser has been demonstrated, as well as simultaneous irradiation of F{sub 2} laser with KrF excimer laser to GaN has been explored. The GaN etching process consisted of the following sequential procedures; laser ablation, and an acid chemical treatment for residue

<sup>&</sup>lt;sup>76</sup> Tun S Tan, Michael R Krames, and Fred A Jr. Kish,

Lumileds Lighting U.S., LLC, "Forming LED Having Angled Sides for Increased Side Light Extraction," Patent Number US6323063 (Nov 27, 2001).

<sup>&</sup>lt;sup>77</sup> S. J. Chua, H. W. Choi, J. Zhang, and P. Li, "Vacancy effects on plasma-induced damage to n-type GaN," Physical Review B 6420 (2001) 5302.

<sup>&</sup>lt;sup>78</sup> J. W. Seo, C. S. Oh, J. W. Yang, G. M. Yang, K. Y. Lim, C. J. Yoon, and H. J. Lee, "Allowable substrate bias for the etching of n-GaN in photo-enhanced electrochemical etching.," Physica Status Solidi A 188 (2001) 403-6.

removal. Complete removal of 700 nm-GaN is accomplished by 10 pulses with a laser intensity of  $\sim$ 40 \* 10{sup 6} W/cm{sup 2}, besides, very sharp etching sidewall and extremely flat sapphire surface axe obtained.

## Novel shapes.

The development of alternative, novel shapes for optimizing light extraction may also be useful. For example, the truncated-inverted-pyramid structure, first demonstrated by Hewlett-Packard, is the current state-ofthe-art. Other possible structures include (Japan work) end-face etching to produce inclined facets. In this case, light is directed, which would otherwise be absorbed internally, through the substrate for extraction. These inclined facets were formed by the dry etching method.

Mechanical shaping methods.

## **2.3 LEDs and Integrated LEDs**

The simplest light-emitting device is the light-emitting diode. These are basically p-n junctions within which electrons and holes are injected into an active region, recombine and emit light. There are two overall LED configurations:

- Vertical-Injection LED. The simplest configuration is the vertical-injection configuration. In this configuration, holes are provided from a ring contact into a p-type semiconductor layer. The holes spread radially inwards within the highly conducting p-type layer, and then inject into the active layer(s). At the same time, electrons are provided from a contact on an n-type substrate, transport through the substrate, and are then injected into the same active layer(s). The electrons and holes are trapped within the active layer(s), and eventually recombine to emit light.
- <u>Lateral-Injection LED.</u> If the substrate (e.g., sapphire) is not conductive, then, in the lateralinjection configuration scheme, the electrons are also injected from a ring contact. They are injected into a highly n-doped layer through which they spread laterally inward, before eventually moving upwards into the active layer(s) to recombine.

All LED structures are variants of these two basic LED configurations. The major functions that the structure must perform are: Ohmic contact; current spreading and transport to the active region; injection of carriers in the active region; spontaneous recombination of carriers; and,

finally, light extraction.

The epilayer and wafer processing building blocks that are used to perform these major functions depend on the alloy compositions available at the wavelength of interest. At any particular wavelength, the available alloy compositions may allow some properties but not others, and compromises must be made. The art of device design is to take advantage of the properties that are available at the wavelength of interest, while compensating for the properties that are unavailable.

At all wavelengths (red, green/blue and UV), the common goal is to achieve very high power conversion efficiencies at high input current densities and high operating temperatures.

In Challenge 2.3.1 we discuss red LEDs fabricated from AlGaInP materials. In Challenge 2.3.2 we discuss green, blue and UV LEDs fabricated from AlGaInN materials. In Challenge 2.3.3 we discuss monolithically integrated LEDs in which multiple colors are emitted to create white directly at the chip level.

## 2.3.1 Red LEDs

Red LEDs would be used in a white lighting system as one of several colors mixed together to create the appearance of white light. Thus far, however, only the AlGaInP materials system has demonstrated efficient red luminescence, hence we focus our attention on AlGaInPbased red LEDs.<sup>79</sup>

The current state-of-the-art in AlGaInP red LEDs is represented by multiple-well, substrate-removed and bonded, chip-shaped structures emitting at 650nm. The structural quality of the active layers, the achievable doping levels, and the active layer design are such that carrier injection, trapping and radiative recombination are all nearly 100% efficient. And, the transparency of the substrate combined with truncated-inverted-pyramid chip shape enables a 60% external extraction efficiency. All together, this LED has an external quantum efficiency approaching 60% at room-temperature, the highest external quantum efficiency of all visible-spectrum LEDs. Taking the electrical series resistance into account, the power conversion ("wall-plug") efficiency of this device approaches 50%.

The major limitations are:

• Cost. This is a relatively expensive device, as it

<sup>&</sup>lt;sup>79</sup> K. Streubel, N. Linder, R. Wirth, and A. Jaeger, "High Brightness Algainp Light-Emitting Diodes," IEEE Journal of Selected Topics in Quantum Electronics 8 (2002) 321-332.

involves removal (and disposal) of a GaAs substrate, combined with thick GaP epitaxy, and chip shaping.

- Wavelength. As the wavelength shortens from 650nm, the internal quantum efficiency for radiative recombination decreases rapidly. This is a significant limitation for red LEDs that are to be color-mixed with other LEDs to create white light. The optimum wavelength for such a red LED is actually closer to 610 nm, as eye sensitivity drops off rapidly towards the red. This is known to be because, for larger aluminum compositions, carrier leakage due to smaller band offsets and increased population of indirect L and X minima reduce internal quantum efficiency considerably. Also, non-radiative centers associated with Al are believed to play a role in decreasing the internal efficiency of shorter-wavelength quantum AlGaInP devices.
- High Power. For the same reasons as those given above, at high input power densities, and at high temperatures, carrier leakage over relatively low confining barriers compromises device efficiency.

<u>Recommendation:</u> Provide red LED with wavelengths of <620nm and increase input power density to 600 W/cm<sup>2</sup> while maintaining high (>40%) power-conversion efficiency and reasonable (<70\$/cm<sup>2</sup>) cost.

Impact=CM Risk=M; Reward=M.

## Possible Approaches.

## Alternative High-Extraction Structures.

It would be desirable to avoid the costly thick epi structures used in current state-of-the-art transparentsubstrate red LEDs. One possibility may be to bond to a mirrored substrate. Alternatively, an epi-ready transparent substrate could be employed to avoid the wafer bonding step.

Enhance barrier heights through strain engineering.

For example, use strain to modify the band-gap energy in these materials to drive the direct to indirect energy-band cross-over far enough away that the emission efficiency would improve dramatically. A new substrate (i.e., different lattice constant than GaAs) may be required to implement this concept effectively.

## <u>Quantum dots.</u>

Because of the large band-gap energy modifications resulting from enhanced quantum confinement and strain,

self- assembled quantum dots can be used to obtain light emission at wavelengths unattainable even using highly strained quantum wells, as evidenced by InAs/GaAs based quantum dot lasers emitting at 1.3  $\mu$ m which is an increase in the band-gap energy by almost a factor of three!

## InN-rich Alloys.

Because color mixing would be easiest if done at the chip level, it would be beneficial to fabricate red LEDs, like blue and green LEDs, from AlGaInN materials.

## Degradation mechanisms.

For high brightness solid-state lighting high operating current densities (and thus high junction temperatures) are required. Reliability of AlGaInP LEDs to date shows a dependence on both current density and junction temperature, with more light-output degradation observed as either of these parameters is increased. Typical degradation curves for AlGaInP LEDs in 5-mm lamp packages are shown in Fig. 5.7. These degradation mechanisms must be studied in detail to understand their root nature and cause to discover methods to eliminate them or render them harmless.

## 2.3.2 Green, Blue and UV LEDs

Green and blue LEDs could be used in a color-mixing approach to white lighting as two of several colors mixed together to create the appearance of white light. Blue LEDs could also be used in the hybrid approach to white lighting in conjunction with wavelength conversion materials. UV LEDs could be used in the wavelengthconversion approach to white lighting.

All current (and likely future) high-performance green, blue and UV<sup>80</sup> LEDs are fabricated from the AlGaInN materials system. The state-of-the-art in these LEDs is represented by multiple-quantum-well structures grown on sapphire. Because these LEDs are grown on buffers on sapphire, the structural quality of the active layers is not very high. But, due to clustering into In-rich InGaN "quantum-dot" like regions, which trap most of the carriers, the radiative recombination efficiency can still be relatively high (nearly 30-40%). Also, the transparency of the sapphire substrate enables a 30% external extraction efficiency. All together, these LEDs have power conversion efficiency of about 20-30%.<sup>81</sup>

<sup>&</sup>lt;sup>80</sup> J. Han and A. V. Nurmikko, "Advances in Algainn Blue and Ultraviolet Light Emitters," IEEE Journal of Selected Topics in Quantum Electronics 8 (2002) 289-297.

<sup>&</sup>lt;sup>81</sup> A. Y. Kim, W. Gotz, D. A. Steigerwald, J. J. Wierer, N. F. Gardner, J. Sun, S. A. Stockman, P. S. Martin, M. R. Krames, R. S. Kern, and F. M. Steranka, "Performance of High-Power

The major limitations are:

- Cost. These are relatively expensive devices (150 \$/cm<sup>2</sup>), mostly because of low yield for the process of buffer layer growth on sapphire.
- Wavelength. Although their wavelength in the blue is relatively optimal for either color-mixed or blue+yellow phosphor approaches to white lighting, their wavelength in the green is not. The optimum wavelength for such a green LED is 540 nm, which matches the peak of the eye sensitivity. However, as the wavelength lengthens from 520nm, the internal quantum efficiency for radiative recombination decreases rapidly.
- Power Conversion Efficiency. Both their internal radiative efficiency and their external extraction efficiencies are low, hence their overall power conversion efficiencies are low.
- Power Density. Current injection uniformity is poor, due to difficulties in lateral current spreading. As a consequence, the input power density can be limited by "hot" spots at the points of carrier injection.

<u>Recommendation</u>: Reduce UV (370-410nm) blue (440-480nm) and green (520-560nm) LED wafer manufacturing cost to 70\$/cm<sup>2</sup>, increase power conversion efficiency (Year 1 25-35%, Year 3 35-45%, Year 5 50-60%, Year 10 60-70%), and increase power density to 600 W/cm<sup>2</sup>.

Impact=CM+Hy; Risk=M; Reward=H.

#### Possible Approaches:

#### Epimaterial improvement.

The efficiency loss at shorter wavelengths may be due to a number of effects: (a) increasing "macroscopic" strain (hence poorer material quality) of InGaN devices grown on GaN/sapphire buffers; (b) materials physics issues associated with high In content. The major approach to increasing internal efficiency is hence probably related to improved buffer layer quality and epitaxy processes.

#### Optical engineering.

Optical engineering (reflective metals, DBRs, waveguides, etc) for increased external extraction efficiency. For example, the use of distributed Bragg reflector (DBR) mirrors between the active region and the substrate, to reflect downward-emitted light away from the substrate and towards the top of the device.

#### Improved current spreading.

Novel methods for increasing current spreading for injection uniformity and higher current densities (e.g., tunnel junctions).<sup>82</sup>

## 2.3.3 Monolithic White LEDs

All current commercial devices are "discrete" devices emitting monochromatic light in a narrow band around one wavelength. For signaling applications, which dominate current markets for visible light emitters, this focus on discrete devices is reasonable.

However, there are strong cost motivations for integrating LEDs with one another, or with electronic devices, together onto one chip. First, there are significant costs associated with the white light production process at the package level. This is especially true for the color mixing approach, but also for the wavelength conversion approach. Second, there are significant costs associated with white lighting fixtures, including electronic control circuitry and optical elements for focusing and directing light.

Both of these costs are incurred during chip packaging and fixturing, rather than during chip fabrication. However, chip fabrication is done at the wafer-level, which experience from other semiconductor technologies has shown is always much less expensive than packaging, since it is done in parallel over the entire wafer at once, rather than in series, die by die (or package by package). Hence, shifting functionality from the die or package to the wafer or chip can be an important means for reducing overall system cost.

In addition, monolithic integration at the wafer level would enable the fabrication of compact microsystems with higher functionality as well as enhanced yield and reliability.

<u>Recommendation</u>: Explore schemes to create monolithic white LEDs, in which package and fixture level functionality (such as color mixing, wavelength conversion, optical focusing and directing, and control circuitry) have been integrated into the chip, while maintaining high luminous efficacies (Year 1 40lm/W, Year 3 50lml/W, Year 5 75lm/W).

Alingan Light Emitting Diodes," Physica Status Solidi a-Applied Research 188 (2001) 15-21.

<sup>&</sup>lt;sup>82</sup> S. R. Jeon, Y. H. Song, H. J. Jang, K. S. Kim, G. M. Yang, S. W. Hwang, and S. J. Son, "Buried tunnel contact junctions in GaN-based light-emitting diodes.," Physica Status Solidi A 188 (2001) 167-70.
Impact=WC+CM+Hy; Risk=H; Reward=H.

#### Possible Approaches

Thin film wavelength converters.

Wavelength conversion is currently done at the package level, through the addition of "thick-film" phosphors. This function might be moved to the chip level through the development of thin-film wavelength converters. The integration of such wavelength converters might involve thin film deposition or wafer bonding. The key ingredient is that they must be strong absorbers and efficient emitters.

Examples of such thin-film wavelength conversion materials are:

- Photon-recycling semiconductor LEDs (PRS-LEDs). For example, as discussed by researchers at Boston University, a blue InGaN LED can be wafer bonded or otherwise joined to an AlGaInP top layer generating two complimentary colors and hence, white light. To date, researchers have demonstrated PRS-LEDs that produce about 10 lm/W of white light.
- Quantum-dot semiconductor materials. In these materials, free electrons and holes are created, move freely in the material, and then recombine. Because they involve semiconductor materials, the absorption can be fairly strong. Because they are nanocrystalline, they can be applied in thin film form, rather than epitaxially. The biggest drawback to these kinds of materials is that electrons and holes can move freely to free surfaces, where non-radiative recombination is probable. Hence, free surfaces must be either eliminated or passivated through careful choice of the host material that the quantum dots are contained in, or of the composition of the interfaces between the host material and the quantum dots. Another drawback is their likely small Stokes shift, which means that the absorption and emission bands are not very well separated, so that some of the band-edge emission can get reabsorbed, thereby diminishing efficiency.

Selective-growth multiple wavelength chips

Further advances in white multichip LEDs might be achieved by heterointegration of semiconductor LEDs into a single epitaxial structure, for instance, by selective-area MOCVD.

Integration with MEMS

The AlGaInN materials system is not just useful for light emission, it may also be a useful material for MEMS structures. It is exceptionally strong, with a Young's modulus of 345 GPa for AlN, compared to 165 GPa for silicon, a standard MEMS material. This offers advantages in terms of reliability and wear. Also, nitrides have a high piezoelectric coefficient, which can be extremely useful for piezoelectrically based sensing applications. And the chemical stability of these materials should enable successful regrowth technologies, necessary for more complex mechanical structures. All of this suggests the possibility that MEMS structures, which would enable moving optical elements for focusing and directing light, can be integrate with AlGaInN-based light emitters.

Multi-quantum well emitting layers (RGB).

Multiple quantum wells in which the thickness and compositions of the wells are varied to enable different wavelength emission.<sup>83</sup> The difficulty here is that to create a wide spectrum of colors requires such a wide range of compositions that it may be difficult to integrate epitaxially on one chip without lattice mismatch and strain problems. Also, the close proximity of layers with different bandgaps means that light emitted from the layers of wider bandgap can easily be absorbed by the lower bandgap layers.

# **2.4 Directional Emitters**

The light-emitting diode discussed in Section 2.3 is the simplest light emitter. It requires only that electrons and holes recombine radiatively. However, without any special attention paid to the optics of the LED, the light emission is random and omnidirectional.

As a consequence, in a planar chip, as discussed in Section 2.2, most of the light is totally internally reflected and never escapes from the semiconductor. Then, the chip must be shaped in special ways to maximize the amount of light that escapes.

An alternative to chip shaping is to alter the way in which the light is emitted, so that it isn't random, but directional. Then, light extraction can be much more efficient, without going to the trouble of shaping the chip. These kinds of devices are more complex and perhaps more costly, but are potentially more efficient. In this Section, we discuss these kinds of directional light emitting devices. In Challenge 2.4.1, we discuss resonant-cavity and super-luminescent LEDs. In Challenge 2.4.2 we discuss edge-emitting lasers.

<sup>&</sup>lt;sup>83</sup> I. Ozden, E. Makarona, A. V. Nurmikko, T. Takeuchi, and M. Krames, "A dual-wavelength indium gallium nitride quantum well light emitting diode.," Applied Physics Letters 79 (2001) 2532-4.

In Challenge 2.4.3 we discuss vertical-cavity surfaceemitting lasers.

stimulated emission Because enhances radiative affect recombination, but doesn't non-radiative recombination, stimulated emission devices, if driven sufficiently hard, can be less sensitive to defects than spontaneous emission devices. However, stimulated emission devices are more sensitive to material heterogeneities, since these tend to inhomogeneously broadened the gain spectrum, so that much of the material cannot contribute emission into the narrow lasing line.

A common theme to all of these devices is the importance of optoelectronic device simulation tools that can be used to optimize device design and performance.

# 2.4.1 Resonant-Cavity and Super-Luminescent LEDs

Resonant-cavity  $^{84}\,$  and super-luminescent LEDs differ from ordinary LEDs in that light is not emitted equally into all optical modes.

In the case of resonant-cavity LEDs the active region has been placed inside an optical cavity, or resonator. The resonator modifies the spectral density of optical modes in the direction parallel to the cavity axis -- enhancing it at wavelengths corresponding to cavity resonances, and suppressing it at wavelengths away from the resonances. Hence, the spontaneous emission rate, which is proportional both to the square of the carrier density, and to the optical mode density at the carrier recombination wavelength, is enhanced.

In the case of super-luminescent LEDs the active region is placed inside a guided-wave structure. The guided waves cause stimulated emission into, and enhanced intensity in, the guided wave modes.

These enhancements have two beneficial consequences. First, they enable radiative carrier recombination to compete better against non-radiative carrier recombination, thereby increasing the internal radiative efficiency. Second, since the enhancement is only in those optical modes whose light propagation direction is along a particular axis, the overall light emission pattern is no longer omnidirectional, but enhanced along that axis. This both enables more compact subsequent collection and focusing optics, and enhances the light extraction efficiency. Typically, the enhancement factor can be as large as 4x, and for a planar transparent-substrate device, extraction efficiencies can be improved from 2.5% to 10%.

In addition, the cost of resonant-cavity and superluminescent LEDs is not expected to be much greater than that of ordinary LEDs, since they are only "modestly" engineered structures. Hence, the incremental benefit per incremental cost may be quite high.

<u>Recommendation</u>: Develop cost-effective RC- and SL-LEDs with high power-conversion efficiency and low output FWHM angular spreads (Year 1 35°, Year 3 25°, Year 5 20°).

Impact=WC+CM+Hy; Risk=M; Reward=H.

# Possible Approaches:

#### Novel resonant cavities.

Fabrication of cavities around the active LED device is quite difficult in both the AlGaInP and AlGaInN materials. In AlGaInP the reason is the lack of index contrast in the available epimaterials, requiring thick, expensive, and difficult to control epigrowths. In AlGaInN the reason is the large strain associated with the easier-to-grow ternary alloys, and difficulties in growing the less-strained quaternary alloys. Hence, it may be interesting to explore novel approaches to resonant cavities – e.g., based on chip shaping, photonic crystals or wafer bonding and film transfer.

#### Dielectric DBRs.

The most common approach to creating optical cavities in the vertical direction is through the use of distributed Bragg reflectors (DBRs). Whether these DBRs are fabricated from epitaxial semiconductor or dielectric materials, high vertical resistances can be a major issue. Hence, it may be useful to combine such DBRs with methods for lateral current injection, as illustrated in Figure 18.

<sup>&</sup>lt;sup>84</sup> D. Delbeke, R. Bockstaele, P. Bienstman, R. Baets, and H. Benisty, "High-Efficiency Semiconductor Resonant-Cavity Light-Emitting Diodes: a Review," IEEE Journal of Selected Topics in Quantum Electronics 8 (2002) 189-206.



Figure 18. Schematic of RCLED with dielectric mirrors and lateral current spreading enhanced through a tunnel-junction. After A. V. Nurmikko, "Make the Photon -- Then Get It Out: Strategies for III-Nitride Emitters," OIDA Solid-State Lighting Workshop (Albuquerque, May 30, 2002).

#### Side-emitting LEDs.

Guided wave structures are easiest to fabricate when the waves are guided horizontally. Hence, side-emitting superluminescent LEDs may be interesting to explore. Also, side-emitting LEDs may be easier to integrate with certain kinds of lamp packaging. For LCD backlights, e.g., sideemitting LEDs improve the optical efficiency of the light guide by eliminating the energy-wasting bends required by conventional top-firing LEDs.

# 2.4.2 Edge-Emitting Lasers

Semiconductor lasers go one step further than resonant cavity devices. In simple resonant cavity devices, the optical mode density is modified, but the cavity is relatively leaky (low Q), the optical field strength of the modes is relatively low, and spontaneous emission still dominates.

In lasers, the cavity is not leaky (high Q), the optical field strength of the modes becomes very high, and stimulated emission dominates. In this situation, the same two beneficial effects as for RCLEDs occur, except much more so. First, this enhancement enables radiative carrier recombination to compete much better against nonradiative carrier recombination, thereby increasing the internal radiative efficiency. Second, since the stimulated emission is only in those optical modes whose light propagation direction is parallel to the cavity axis, the overall light emission pattern is completely unidirectional along that axis. The light extraction efficiency becomes 100%.

In addition, lasers are essentially exact point sources of light, rather than approximate point sources of light as are LEDs. Hence, the package- and fixture-level optical engineering associated with color mixing, wavelength conversion, light directing and focusing would be potentially easier with lasers than with LEDs. It is even possible to imagine white lighting systems where the laser is located remotely from phosphors that it excites: phosphors could be painted on a wall and activated by a remote UV laser to produce unusual lighting effects without any power connections in the wall. Unlike an LED, a laser beam could be easily directed with near 100% efficiency to such a remote phosphor.

The current state-of-the-art in high-power semiconductor lasers is edge emitters in the AlGaInAs materials system. The main application of these lasers is optical pumping of solid-state lasers such as Nd:YAG. In that sense, these lasers are used in a similar way to the way lasers might be used in white lighting: as a source of cheap, directable, monochromatic light for input into an optical wavelength and mode converter.

These lasers are moderately mature. In array form, as illustrated in Figure 19, output powers can be as high as 2-3kW. Typically, output powers at 810nm are in the 100W per package range, with retail prices of approximately \$40/Watt and wholesale prices of approximately \$4/Watt, with power conversion efficiencies in the 50-60% range.

Indeed, if equivalent optical powers could be created at visible wavelengths, then, using an "average" human eye sensitivity of 400 lm/W, these performance figures would correspond to:

• A luminous efficacy of roughly 200 lm/W, which is exactly the year 2020 target



Figure 19. A 2D array of laser diode bars capable of 2.56kW average optical output power. If such powers were available in the three primary colors, the result would be roughly 1Mlm of white light. After D. F. Welch, "A Brief History of High-Power Semiconductor Lasers," IEEE Journal of Selected Topics in Quantum Electronics 6 (2000) 1470-1477.

- A luminous flux per package of 40 klm, which is 25x higher than the year 2020 target
- A purchase cost of 10 \$/klm, which is higher (but only by about 5x) than the Year 2020 target.

And, it should be noted, that these lasers are currently manufactured in modest volumes compared to the potential volumes for white lighting, so presumably there is significant room for additional performance improvement and cost reduction.

The major (and huge) limitation, however, is that these kinds of efficiencies and powers have yet to be demonstrated at the visible and near-UV wavelengths that would be interesting for white lighting.

- State-of-the-art red edge emitting lasers in the AlGaInP materials system now have efficiencies in the 40% range, and power outputs in the 1-3W range, at wavelengths in the 630-670nm wavelength range.<sup>85</sup>
- State-of-the-art violet edge emitting lasers in the AlGaInN materials system, now have power outputs of 5mW and lifetimes of 10,000 hrs at wavelengths in the 405nm range. The most intense current interest is for applications in optical data storage (digital versatile disks), so less attention has been paid to raw power. However, much higher powers should be possible. For example, lasers transferred using laser lift-off to copper substrates for improved thermal management have recently demonstrated cw powers as high as 100W.<sup>86</sup>

<u>Recommendation</u>: Develop economical (<90\$/cm<sup>2</sup>), high input power density (500W/cm<sup>2</sup> averaged over entire chip), high-power-conversion efficiency (Year 1 20%, Year 3 40%, Year 5 60%, Year 10 70%) edge-emitting semiconductor lasers in the four wavelength ranges UV(370-410nm), R(590-630nm), G(520-560nm), B(440-480nm).

Impact=WC+CM+Hy; Risk=H; Reward=M.

# Possible Approaches.

#### Improved AlGaInN materials.

Just as with AlGaInN LEDs, the most important improvement will be in the quality of the AlGaInN substrate and epimaterial quality. Perhaps most important is the need for line widths to be homogeneous, not inhomogeneous, hence for them not to be dominated by effects such as QW interface roughness, statistical distributions of QD sizes, etc.

#### Improved heterostructure designs.

Thus far, the issue has been mostly a materials one – getting sufficient internal radiative efficiency in the UV from AlGaInN materials. However, there may be heterostructure design approaches which can compensate for this reduced internal radiative efficiency.

#### Buried Heterostructures

Although transverse-mode control may not be a significant issue in lasers for solid-state lighting, there may be some advantages to using selective-area epitaxy for some parts of the device structures, particularly to avoid facet damage described below, but also to spread and confine current in various ways. Also, one can learn from this technology as it is developed for DVD laser diodes, for which transverse mode control will be critical.

# Wafer-scale facet creation.

One of the major limitations to edge emitting laser technology is the lack of economical processes for waferscale, non-cleaved, low-damage facet creation. Because a huge light flux is concentrated on a small facet area, there is a great potential for optically induced facet damage. Much effort has been expended to reduce this potential in AlGaInAs and GaInPAs based lasers, including engineering the facet so that its optical absorption is as low as possible (through coatings or band-gap modification). Indeed, in very high reliability laser applications, this is perhaps the major reason for interest in VCSEL technologies.

# Novel designs for lower thermal resistance

Because AlGaInN-based lasers are at present very inefficient, they must be pumped very hard, and heating becomes a severe issue. In the long run, even if efficiencies increase, the ability to pump hard will be important. Hence, ways to decrease the thermal resistance of the device will be important, through, e.g., transferring the device to super-high-thermal-conductivity substrates such as Cu, diamond-like C, or flip-chip mounting on Cu bars. In this area, one can borrow from AlGaInAs-based highpower laser technology.

#### Strain tailoring

<sup>&</sup>lt;sup>85</sup> Wu LZ and Zhang YS, "Selenium doping effects and lowthreshold high-power GaInP-AlGaInP single-quantum-well lasers grown by MOVPE," IEEE Photonics Technology Letters 12 (2000) 248-250.

<sup>&</sup>lt;sup>86</sup> M. Kneissl, W. S. Wong, D. W. Treat, M. Teepe, N. Miyashita, and N. M. Johnson, "CW InGaN multiplequantum-well laser diodes on copper substrates.," Physica Status Solidi A 188 (2001) 23-9.

This is used routinely in other similar material systems such as AlGaAs and InGaAsP and can be turned to advantage in laser design where it is desirable to engineer the light hole valence band to be uppermost. Similar concepts may be applied to the nitrides, though it should not be forgotten that in hexagonal films the valence band degeneracy is already lifted by the axial component of the crystal field. On the other hand, it may well be possible to design perfectly lattice-matched structures, using quaternary alloys as outlined above.

# **2.4.3 VCSELs**

Vertical-cavity surface-emitting lasers (VCSELs) are a second kind of laser. They differ from edge emitters in that the output direction of the light is out of the plane, rather than in the plane, of the substrate material. This is potentially a more convenient output direction, enabling packaging and optical engineering approaches that borrow heavily from those of conventional LEDs. And they are potentially less expensive than edge-emitting lasers, since they can be processed and tested in wafer form.

Moreover, they have most of the same potential for power conversion efficiencies as edge emitting lasers. Their directionality makes extraction of light near-100% efficient. And their even higher optical circulating power density enables stimulated emission and radiative recombination to compete even more favorably against non-radiative recombination. Indeed, like edge emitters, AlGaInAsbased VCSELs at 850nm with power conversion efficiencies of over 50% have also been demonstrated.

For solid-state lighting, it will be necessary to develop VCSELs that are just as efficient in the UV or visible. AlGaInP-based red VCSELs have been demonstrated. Their power-conversion efficiency (now at 14%) and temperature performance continues to improve,<sup>87</sup> but are still far from our targets.

AlGaInN-based VCSELs in the UV, blue and green are even less mature, but perhaps even more important to emphasize. Recently, an optically pumped InGaN/GaN VCSEL operating at the near-UV wavelength of 384 nm has been demonstrated. This VCSEL made use of distributed Bragg reflectors (DBRs) made of MOCVDgrown GaN/AlGaN and dielectric multilayers. Nevertheless, this kind of device is extremely challenging to fabricate – the vertical electrical resistance of the DBRs is high, and may require horizontal current injection approaches.

And perhaps the biggest challenge will be high power. In the infrared, where there is now a lot of experience with both edge emitters and VCSELs, VCSELs have only been able to compete in low-power, high-modulation-speed applications, such as in data communications. In highpower applications, edge emitting lasers are dominant.

<u>Recommendation</u>: Develop economical (<75\$/cm<sup>2</sup>), high input power density (600W/cm<sup>2</sup> averaged over entire chip), high-power-conversion efficiency (Year 1 pulsed, Year 3 cw 20%, Year 5 cw 50%, Year 10 cw 70%) VCSELs in the four wavelength ranges UV(370-410nm), R(590-630nm), G(520-560nm), and B(440-480nm).

Impact=WC+CM+Hy; Risk=H; Reward=H.

#### Possible Approaches:

#### Novel strain-engineered DBRs.

In situ grown AlN/GaN DBRs are tricky, because of strain. Dielectric DBRs may be used, but these are also tricky, especially in the UV, as the available transparent materials, and the available index contrast, are limited, requiring many periods.

Novel concepts for lateral current injection.

For virtually any bottom or top DBR stack, vertical resistance is likely to be very high. Hence, novel approaches to lateral current injection will need to be pursued. This is especially a problem on the p-side, with the poor mobility of holes, so techniques for type conversion, such as tunnel junctions, may also be necessary.

Novel concepts for heat sinking.

# **2.4.4 Optoelectronic Simulation Tools**

The application of numerical simulations to the design of photonic devices can have a dramatic affect on performance optimization, limiting iteration cycles, reducing development costs and accelerating time to market. Simulation areas of maximum impact include, but are not limited to, the design of LEDs with enhanced light extraction efficiency, resonant cavity LEDs (RCLED) and VCSELs design, optimum phosphor composition, semiconductor bandgap engineering and material gain optimization. In addition, material growth stands to benefit from simulations of epitaxial deposition and defect propagation.

<sup>&</sup>lt;sup>87</sup> Knigge A, Zorn M, Wenzel H, Weyers M, and Trankle G, "High efficiency AlGaInP-based 650 nm vertical-cavity surface-emitting lasers," Electronics Letters 37 (2001) 1222-1223.

Numerical simulation of RCLEDs and VCSELs must cope with the multilayer structural complexity of the cavities with etched features and open boundaries, and the richness of physical interactions between carriers and photons, including nonlinear effects and multiple spatial/temporal scales. Direct integration of the full set of Maxwell-Bloch equations using finite difference time domain (FDTD) codes resorts to a full resolution of the finer space and time scales involved, using a finite mesh of points in space and time. While in principle the most accurate approach, FDTD and its variants using the paraxial wave equation, the beam propagation method (BPM), lead to complex, time-consuming numerical simulations. It is perhaps no accident that only one such code is commercially available, while a number of similar numerical tools have been developed and used independently by research groups and universities.

Numerical studies for the optimum placement of the oxide aperture in VCSELs offer one indication of the numerical Recommendation: detailed simulations so far tend to yield opposite conclusions from experiments regarding the node vs. antinode placement of the aperture, due to an underestimating of the scattering losses. An "infinite" number of the unguided continuum part of the waveguide spectrum must be included to capture diffraction and scattering losses.

Regarding the simulation of light extraction, the majority of simulation tools involve "ray tracing" codes. The accuracy of this approach is limited when the typical device size is comparable to the radiation wavelength. Time consuming full wave simulations must be used to address the coherent wave interference in photonic band-gap structures. Although codes for infinite 3-D structures are publicly available, additional complexities due to symmetry breaking must be addressed for 2-D photonic membranes, and thin epi-layers used for enhanced extraction. Finally, no simulation tools are currently available for optimization of light extraction from randomly textured surfaces, an easy and inexpensive-to-apply manufacturing method that has yielded record extraction efficiencies.

Simulation tools for bandgap engineering are in a more mature stage, due to work at Sandia and elsewhere. Still, more work is required to address the challenges of straininduced piezo-electric fields and composition nonuniformity ("dopant islands") occurring in GaN alloys.

Last, but not least, to our knowledge the simulation of epitaxial growth, defect percolation and defect propagation is still in its infancy. Further development of such tools will have a considerable impact in the areas of substrate growth and material doping, which are high priority areas. <u>Recommendation</u>: Develop commercial software tools for simulation of high-efficiency high-power optoelectronic devices (Year 1 RCLED capability with prototypes, Year 2 Textured surfaces capability, Year 3 VCSELs with beta availability, Year 5 Photonic Crystals with commercial availability).

Impact=WC+CM+Hy; Risk=M; Reward=L.

#### Possible Approaches.

#### Materials properties.

All simulation tools will depend on knowledge of fundamental materials properties, such as bandgaps, complex refractive indexes, etc., as a function of temperature, carrier concentration and quaternary alloy compositions. Systematic studies leading to parameterized models for these properties will be necessary input to these simulation tools.

#### Novel, Fast Approaches in Device Simulation Tools.

Long execution times, complexity of input/output and long "user learning curves" are impeding the use of detailed simulation codes, requiring "dedicated to simulation" personnel. Introduction of new simulation algorithms, capable of capturing the essential physics on a much coarser description level, without resorting to detailed spatial grids, is highly desirable. A successful example has been given in VCSEL cavity simulations.88 There, the optimum representation of cavity eigenmodes by paraxial modes of waist determined by an algebraic variational principle allows the decomposition of the rate equations into modes of known spatial structure. An orders-ofmagnitude reduction in execution time results, both in deriving the cavity eigenmodes, and in dynamic multimode simulations that replace finite differencing in space by a set of coupled ODEs. The approach handles diffraction, scattering and self-interference losses and has been validated be comparisons with experiments. A similar approach is directly applicable to RCLEDs, and it may be extrapolated to wide stripe edge emitters. Eigenmode expansions are also possible in cases when a parabolicprofile refraction index arises.

#### Light Extraction Algorithms.

First-approximation solutions are given by existing raytracing codes. Novel models are required to cope with

<sup>&</sup>lt;sup>88</sup> Riyopoulos SA, Dialetis D, Liu J, and Riely B, "Generic representation of active cavity VCSEL eigenmodes by optimized waist Gauss-Laguerre modes," IEEE Journal of Selected Topics in Quantum Electronics 7 (2001) 312-327.

textured surfaces used for enhanced extraction, since the typical surface feature compares with the wavelength. In the case of randomly textured surfaces it is possible to derive extraction algorithms without a detailed feature resolution, taking advantage of the statistical correlation properties of the random texturing. Semi-analytic theoretical background already exists for 1-D incidence to

an infinite rough surface. That could form the kernel of a light extraction tool for finite size cavities.

#### Finite Differencing Approaches.

Despite their complexity and computational intensity, longer user "learning curve", large CPU and memory size and long execution time, fully discretized grid codes may still be required for the most complex devices. FDTD codes have a wider usefulness in a complementary role: once the design parameter space for a given device is narrowed down by the use of the faster, coarser description tools, FDTD codes can be employed for parameter fine tuning and increased accuracy. Benchmark tests are required for validation, such as, for example, the successful simulation of effects of oxide aperture location in VCSELs.

# Simulation of Material Layers Growth.

Different variants of the diffusion-limited aggregation equations governing layer deposition and interface formation can be codified to model the physics of deposition and obtain estimates for defect density and dislocation propagation from microscopic molecular parameters. (The modeling of the reactor physical chemistry including reactant flows, temperature distributions and "parasitic" chemical reactions was addressed in Section 1.3).

# **3 LAMPS, LUMINAIRES AND SYSTEMS**

In Chapters 1 and 2 we discussed the light-engine chip that is at the heart of solid-state lighting. This chip must ultimately be packaged into a lamp, along with phosphors or chips of other wavelengths. The lamp, in turn, must ultimately be inserted into a luminaire, or fixture, which directs the light from the lamp onto a workspace.

The overall combination of lamp, luminaire, workspace and human viewer, can be thought of as a lighting environment with a wide range of permutations and design possibilities. The importance of this entire lighting environment is clear from the economics of traditional lighting. Of this \$40B market, about 1/3 is the lamp, while the remaining 2/3 is the luminaires, the drive electronics, and lighting-specific architectural features.

In Section 3.1, we discuss the most critical materials used in chip packaging: the phosphors which down-convert either UV or blue primary light, and the encapsulants which protect the entire LED and phosphor combination from the external environment.

In Sections 3.2 and 3.3, we discuss the lamp package itself, and the luminaires and fixtures into which the lamp will be inserted. Lamps and luminaires will have an enormous impact on the efficiency, life and cost of SSL-LED technology through their thermal management of high input power density to the light-engine chip, and through their optical engineering for efficient white light production and directing.

It is likely that, particularly in the early years of SSL-LED technology, there will be a diversity of approaches to lamps and luminaires. These approaches will reflect the different approaches to white light production itself – whether by color mixing, by wavelength conversion, or by a hybrid combination. For example, a lamp based on color mixing will likely need to accommodate multi-chip mounting, and perhaps more sophisticated optics. A lamp based on wavelength conversion from the UV will need to accommodate UV-resistant materials and perhaps more heat-generation for the same lumen production because of lower luminous efficacies.

It is also likely that, in the early years of SSL-LED technology, there will be some overlap in the functions performed by the lamp and the luminaire. One expects in the early years for the luminaire, which is easier to customize, to provide more of the functionality, but in the later years for the lamp, which is easier to make complex at low cost, to provide more of the functionality.

One example is color mixing. There already exist commercial luminaires in which multiple lamps of different colors are mixed into programmable shades of colored and white light. And, for the highest-performance lighting, e.g., for theatres and stages, color-mixing at the luminaire level may forever be the best approach. However, for mainstream white lighting, for which cost is expected to a major factor, we expect white light production, whether through color mixing, wavelength conversion, or a hybrid approach, to occur at the lamp level. Hence, for the purpose of this Roadmap, we assume that white-light production and color-mixing are lamp, rather than luminaire, functions.

Finally, in Section 3.4, we discuss the challenges associated with solid-state lighting systems. Just as the emergence of incandescent lighting technology created radically new ways of thinking, this new era of SSL-LED technology will create a new lighting culture through new applications and new ways of lighting. The result will be an exciting new interplay between the lamp, the luminaire, lighting and interior design, and the human visual system

Decision: Will SSL-LED white lighting compete with conventional lighting by emphasizing traditional attributes such as low cost-of-ownership, high efficiency and environmental friendliness, or will it compete by emphasizing new attributes such as programmability and improved interplay with building architectures and the human visual system?

# 3.1 Phosphors and Encapsulants

In this Section, we discuss challenges associated with two of the fundamental materials used in lamp packaging: the luminescent materials used in the wavelength conversion and hybrid approaches to white light production; and the encapsulant materials used to protect the chip and phosphor from the external environment.

Throughout these challenges, there are three common themes.

The first is high efficiency. For the phosphor this means strong absorption in the blue or near-UV and high quantum efficiency for re-emission in the red, green or blue. For the phosphor+host+encapsulant materials



Figure 20. Examples of commercial phosphor powders used in fluorescent lamps and displays, under white light illumination (top) and under UV (254nm) illumination (bottom). The abbreviations are:

SPE	$Sr_2P_2O_7:Eu^{2+}$
BAM	BaMgAl <sub>10</sub> O <sub>17</sub> :Eu <sup>2+</sup>
BAM-Mn	BaMgAl <sub>10</sub> O <sub>17</sub> :Eu <sup>2+</sup> , Mn <sup>2+</sup>
CBT	$(Ce^{3+}, Gd^{3+}, Tb^{3+})MgB_5O_{10}$
YAG	$Y_3Al_5O_{12}:Ce^{3+}$
YOX	Y <sub>2</sub> O <sub>3</sub> :Eu <sup>3+</sup>
MGM	$Mg_4GeO_{5.5}F:Mn^{2+}$
•T Instel H 1	Nikol and C Ronda "Development

After T. Justel, H. Nikol, and C. Ronda, "Developments in the field of luminescent materials for Lighting and Displays," Angew. Chem. Int. Ed. 37 (1998) 3084-3103.

combination this means low parasitic absorption and optical scatter of the down-converted secondary light.

The second is high-temperature operation. Phosphor quantum efficiencies and encapsulant integrity must be sustained even at the high input power densities and temperatures associated with the light-engine chip. The resulting phosphor temperatures may be somewhat lower than the junction temperature in the chip itself, but are nevertheless expected to be in the 150C range.

The third is lumens maintenance. The high quantum efficiency and low parasitic absorption of the phosphor+host+encapsulant materials combination must be maintained over our target operating lifetimes of >100,000 hours.

# **3.1.1 Phosphor Materials**

The function of the luminescent, or phosphor, materials is to absorb the primary near-UV or blue light emitted by the LED chip, and then to re-emit at longer wavelengths such as blue, green or red.

In principle, this wavelength conversion can occur in thin-film materials deposited during chip fabrication. As discussed in Section 2.3, though, efficient luminescent materials with high enough optical absorption to be compatible with ( $<5-\mu$ m-thick) thin-film technologies have not yet been found. Additionally if luminescent thin films were developed, ways must be found to extract the light from the film and avoid light piping. Hence, the current

generation of luminescent materials are integrated at the package, or lamp, level, after the LED chip has been fabricated.

In the early stages of solid-state lighting, it is likely that these luminescent materials will borrow from technologies developed for other applications, such as fluorescent lamps, cathode-ray-tube displays, and scintillators.<sup>89</sup> There is a huge variety of such phosphors – a few examples are shown in Figure 20.

Similar to fluorescent lamp phosphors, the phosphors for SSL-LED are required to have high photoluminescent efficiency with desired chromaticity. These can be achieved by inorganic phosphors doped with rare earth, divalent or trivalent, and transition metal ions. Due to their feature of narrow band (a few nm) emission, trivalent rare-earth activated phosphors are widely used in current lighting and display technology, giving both high conversion efficiency and color flexibility. The current generation of commercial white LEDs, based on the approach first used by Nichia) is based on such a phosphor: YAG activated with trivalent cerium (YAG:Ce<sup>3+</sup>), which converts the blue LED radiation into a very broad band yellow emission.

In the middle-to-later stages of solid-state lighting, luminescent materials for solid-state lighting will probably diverge considerably from those used for fluorescent lamps, due to their different requirements.

On the one hand, some of the different requirements will make finding SSL-LED phosphors easier:

- Fluorescent lamp phosphors must be in contact (typically) with a mercury-containing gas discharge, hence must be compatible both with a reactive plasma environment, as well as reactive mercury itself. Hence, sulfide-based phosphors, which react strongly with mercury (as well as under exposure to UV light and moisture), cannot be used.
- Fluorescent lamp phosphors must absorb well both at 254 nm, where 85% of the primary excitation is, and at 185 nm, where an additional 12% of the primary excitation is. The situation is even worse for high-pressure discharge fluorescent lamps, which have much broader primary excitation wavelengths. LED phosphors only need to absorb well at one primary excitation wavelength.
- The high-energy excitation by the primary light (wavelength: 254 and 185 nm) in fluorescent

<sup>&</sup>lt;sup>89</sup> G. Blasse and B. C. Grabmaier, Luminescent Materials (Springer-Verlag, Berlin, 1994).

lamps leads to band-to-band electron transitions of the host materials, causing them to be reactive to the mercury plasma and to degrade. LED phosphors, in contrast, are excited with relatively low energy (380 to 470 nm). This excitation usually results in intra-band transitions, and would not result in materials degradation.

• The high-energy excitation by the primary light in fluorescent lamps also leads to a larger Stokes shift, hence a lower wall-plug efficiency. In principle, an LED phosphor does not then need to be as quantum efficient as a fluorescent lamp phosphor, in order to achieve the same overall luminous efficacy. In practice, if it is as quantum efficient, then the reduced Stokes shift will lead to a higher wall-plug efficiency.

On the other hand, some of the different requirements will make finding SSL-LED phosphors more difficult.

- Generally speaking, the further into the UV one goes, the better most materials absorb. Since for SSL-LED technology we are looking for high absorption in the blue or near-UV, there will be fewer materials to choose from. This is especially an issue for phosphors that must absorb blue light. If rare earth phosphors, which absorb blue only weakly, are used, then they must be very thick. Increased thickness translates to increased cost, as well as higher optical scattering which, as discussed below, can trap light and reduce light extraction from the LED package
- Low optical scattering of phosphor-converted secondary light by the phosphors themselves is not a consideration for fluorescent lamps, since absorption by other components of the lamp is small, and scattered light will still eventually escape. However, for solid-state lamps phosphor transparency is important, since there are likely to be many packaging materials (e.g., die attach solders) that will absorb scattered light.
- Phosphor performance must be sustained even at temperatures of 150C. This is somewhat higher than the temperatures that need to be sustained by typical fluorescent lamp phosphors (though highpressure mercury lamp phosphors can experience temperatures as high as 300C).
- Because SSL-LED lamp life is expected to be much longer than fluorescent lamp life (100,000 hours rather than 10,000 hours), SSL-LED phosphors must also be much longer lived than fluorescent-lamp phosphors. The so-called

"lumens maintenance" issue is a major one for SSL-LED phosphors, whose emission bands shift and whose quantum efficiency decreases with age. Coloration can result, in the case of inorganic phosphors (e.g., CdZnS), from precipitation of the metal elements and, in the case of organic materials, from breakage of bonds in the molecule.

 SSL-LEDs may encounter more severe environments (moisture, light and heat) than fluorescent lamps, leading to accelerated phosphor degradation. Some environmental factors may be unique to SSL-LEDs, such as electric fields in the vicinity of the chip, leading to electrophoresisinduced emission-wavelength shifts.

The phosphors that need to be developed can be divided into the three principle emission wavelength ranges: red (590-630nm), green (520-560nm) and blue (440-480nm).

Red-emitting phosphors are the most challenging. The main reason is that the red emitter must not only be centered near 610nm, but, because of the sharp decrease in human eye sensitivity at longer wavelengths, it must have a narrow line width. The combination of high absorption in the blue or near-UV, and narrow emission line width, is difficult to achieve.

For example, SrS:Eu2+ absorbs strongly in the blue and near-UV and emits in the red, but with a broadband emission. Or, for example,  $Y_2O_3$ :Eu<sup>3+</sup> has a narrowband red emission and a quantum efficiency for 254 nm excitation close to 100% (the highest of all known lighting phosphors), but absorbs poorly at wavelengths longer than 380nm, even with sensitization.

The situation for green emitting phosphors is slightly more relaxed -- since the human eye is sensitive to a broad range of green light, narrowness of spectral emission is not a dominant concern. The relaxation of this selection criteria allows for a wider range of possible candidates. For example, the broad-band emission of divalent europium ion (Eu<sup>2+</sup>), which is due to 4f<sup>6</sup> 5d -> 4f<sup>7</sup> optical transitions, is extensively tunable with emission wavelengths extending from the UV to red wavelength spectral regions. Moreover, the absorption by 4f<sup>7</sup> -> 4f<sup>6</sup> 5d optical transitions usually extend throughout the ultraviolet and for some materials into the blue. For example, SrGa2S4:Eu2+ absorbs strongly in the blue wavelength range 450-475nm and emits in the green.

Nevertheless, optimizing these and other phosphors for quantum efficiencies of >80-85% at >150C temperatures over 100,000hr lifetimes will be a significant challenge. Avenues for the optimization include, but are not limited to, development of non-stoichiometric formulations, protective coatings, optimal doping level, fluxing, and new combinations of activator and sensitizers.

The situation for blue-emitting phosphors is in between that of red and green. Human eye sensitivity cuts off on the purple, but not on the green, side of blue. Hence, there can be an emission tail in the green without a significant decrease in either overall luminous efficacy or color quality.

While many Eu<sup>2+</sup>-activated phosphors are green emitters, several of them have been identified to be good blue emitters. For example, (Sr,Ba,Ca)<sub>5</sub>(PO<sub>4</sub>)<sub>3</sub>Cl:Eu<sup>2+</sup> and BaMg<sub>2</sub>Al<sub>16</sub>O<sub>27</sub>:Eu<sup>2+</sup> show strong absorption throughout the UV and almost into the visible, and emit blue light. They were developed originally as fluorescent lamp phosphors and recently have been adopted as SSL-LED phosphors. Since these phosphors were designed and optimized for 254nm and 185nm absorption, their efficacy with LED excitation (370-410 nm) is still mediocre. To improve the efficacy, the absorption in the 370-410 nm region needs to be increased. However, these oxide-based phosphors generally offer good chemical stability under exposure to near-UV light and moisture.

Again, optimizing these and other phosphors for quantum efficiencies of >85% (for near-UV-absorbing phosphors) at >155C operating temperatures will be a significant challenge.

<u>Recommendation</u>: Develop UV (370-410nm) and blue (440-480 nm) absorbing phosphor materials with >80-85% quantum efficiency in the red (590-630 nm), green (520-560 nm) and blue (440-480 nm), >1000/cm optical absorption coefficient, low degradation over 100,000hrs, and low-variation in efficiency and absorption at high (175C) operating temperatures.

Impact=WC+Hy; Risk=M; Reward=H.

# Possible Approaches.

# Multiple wavelength conversions.

If red-emitting phosphors that absorb primary blue or near-UV light prove difficult to find, cascaded wavelength conversion (or cascade luminescence) may be a good alternative. This approach uses a phosphor that first emits in the green, accompanied by another phosphor that selectively absorbs the green and re-emits red. However, this approach introduces a second wavelength conversion process with its own efficiency issues.

# High-vibrational-frequency phosphors.

Phosphors are normally quite sensitive to temperature, a phenomena exploited by optical-fiber thermometers,

through the variation in the Stokes shift with temperature. Most of this shift is due to the temperature-dependent occupation of various vibrational levels within an electronic state. Hence, these shifts are expected to be smaller in phosphors whose vibrational frequencies are so high that only the ground vibrational state can be occupied.

Phosphors with activators occupying interstitial sites in the host lattice have shown less sensitivity to temperature than phosphors with substitutional activators. Substitutional centers are more strongly coupled to the host crystal, whereas interstitial centers are more weakly coupled. Interstitial centers can experience decreasing perturbation with increasing temperature as a result of lattice expansion. For the phosphor, this translates to a higher thermal quenching temperature.

#### Novel sensitizers.

Many phosphors depend on "sensitizer" ions for absorption, followed by energy transfer to "activator" ions for emission. Through a deeper understanding of these processes, and a wider exploration of sensitizer-activator combinations, it may be possible to engineer phosphors with the required absorption and emission wavelength combinations.

# Nanocrystalline Semiconductors

The optical properties (absorption and luminescence spectra, and scattering cross section) of nano-scale semiconductors can be tuned through quantum size effects. This property can be used to develop custom red, green, and blue emitters for solid-state lighting that are not restricted to atomic transitions. In addition, such luminescence conversion materials would exhibit much lower scattering optical scattering due to the small size.

Organic coordination-compound phosphors.

Wavelength conversion based on organic materials, such as organic dyes and conjugated polymers, have shown promising conversion efficiencies and white light demonstrations. For example, Eu3+ and Tb3+ ions coordinated to light-absorbing organic ligands can be designed to absorb efficiently at 370-400nm, and to emit with high quantum efficiency. These organic phosphors are soluble in polar organic solvents and can be tested in solution before being transferred to the solid state. And, they are compatible with polymeric carriers which, unlike traditional particle phosphors, have no optical scattering. However, degradation and lumens maintenance is expected to be a bigger issue with these materials than with inorganic materials. And, mutual compatibility with these inorganic materials, if blends are to be used, could be an issue.

# Combinatorial discovery.

Because of the huge diversity of potential phosphor materials, new approaches to synthesizing and evaluating may be needed. Combinatorial discovery, in which tens of thousands of combinations of materials are synthesized and evaluated in parallel, are one such approach. This approach may be valuable both for developing new families of phosphor materials, as well as for fine-tuning the composition of already-developed families of phosphor materials. To guarantee successful implementation, combinatorial discovery platforms should be compatible with eventual scale-up of the synthesis process to production volumes.

#### Improved evaluation techniques.

It may also be necessary to develop new approaches to rapid, accurate evaluation of the optical properties of phosphors – including absorption, internal and external quantum efficiency, and scattering. These measurements are seldom done rigorously, are tricky, and there is often considerable disagreement between measurements in different laboratories.

#### Charge-state engineering.

Phosphor behavior is highly dependent on charge state. Hence, it may be necessary to charge-compensate certain activators if they reside in host lattice sites of a different oxidation number. For example, a Ce<sup>3+</sup> luminescent center may be located on a +2 oxidation state host lattice site, in which case it may be necessary to incorporate a -1 ion, such as F<sup>-</sup> or Cl, in order to charge-compensate the phosphor.

# 3.1.2 Phosphor Synthesis and Application

Assuming that a set of phosphor materials have the necessary optical properties, the materials must still be synthesized into powders and then applied to the SSL-LED chip or lamp.

Traditionally, the synthesis of an inorganic phosphor follows the following procedure:<sup>90</sup>

- 1. grinding and mixing of the ingredient solid materials
- 2. firing in a furnace to induce high temperature solid-state reactions that result in a sintered, microcrystalline "cake"
- 3. mechanical milling of the as-fired product into particles whose sizes are approximately those of the microcrystals in the cake itself
- 4. washing to remove the unreacted ingredients
- 5. sieving the product to narrow the typically broad grain size distribution



Figure 21. Schematic cross-section of phosphors slurry-deposited on a conventionally-attached LED die and conformally-deposited on a flipped-and-submount-attached LED die. Courtesy of D.A. Steigerwald (LumiLeds).

Recent development on the preparation techniques include: the use of wet chemistry treatments before the high temperature reaction; the use of fluxing materials for better crystal growth; and the use of reducing atmospheres, such as hydrogen, for phosphors whose oxidation state must be carefully controlled, such as those based on Eu<sup>2+</sup>.

The resulting phosphor powder can then be mixed with other phosphor powders of different colors, and dispersed in a slurry containing an organic or water-based solvent into which low concentrations of a binding agent and an adhesive have been added. The choice of the solvent depends on the properties of the binders, the adhesive and the phosphors. The viscosity required for the slurry also determines the choice of the solvent. Typical solvents used for lamp phosphor slurry are butyl acetate and xylol. Filmforming binder and adhesive are added to the slurry, the former links the phosphor grains to the film whereas the latter functions as film body. Nitrocellulose and ethylcellulose had been used as the binders, and several phthalates as the adhesives.

Finally, as illustrated in Figure 21, the slurry is applied to the LED chip which has presumably already been mounted in the lamp package.

<sup>&</sup>lt;sup>90</sup> Shigeo Shionoya and William M. Yen, Editors, Phosphor Handbook, CRC Press, Boca Raton, 1999).

<u>Recommendation:</u> Develop phosphor synthesis and application methods that are environmentally friendly, maintain high phosphor quantum efficiency, cause no dissipative optical absorption or scattering, are compatible with a variety of lamp packaging techniques, and maintain lumen performance over lifetimes >100,000 hours.

#### Impact=WC+Hy; Risk=H; Reward=H.

#### Possible Approaches:

#### New synthesis techniques.

It may be possible to develop new scalable synthesis techniques such as spray pyrolysis. These techniques would produce much finer particles without the need for grinding, along with improved control over particle composition, morphology, and size distribution. By eliminating the need for milling and other post-processing steps, processing-induced surface defects, impurities, and compositional changes can also be reduced.

#### Ink "printing".

As control over particle sizes and distributions improves, it may be possible to dramatically increase the packing density of the particles. For example, this would be the case for bimodal and trimodal size distributions of submicron, spherical particles. This would enable dispersion in vehicles that enable innovative printing by methods such as ink-jet printing that have not previously been accessible. These novel ink formulations and printing approaches will allow the deposition of much thinner films than currently possible with thick film approaches. Also, the use of phosphor nanoparticles will reduce sintering and melting temperatures. This will allow sintering of the deposited layer into dense layers at much lower temperatures.

#### Phosphor slurries.

Unlike the slurries used for fluorescent lamp phosphors, the slurries used for SSL-LEDs must: (1) reduce or fill the gap between phosphor grains when dried, (2) be composed of binders and adhesive which match the phosphor refractive index and which minimize optical absorption and scattering, and (3) be chemically compatible with the phosphors and the encapsulants. These can be achieved by formulating the slurry with novel binders and adhesives. Possible candidates are film-forming acrylic polymerizates and block polymers containing film-forming backbones and binding groups. In addition, viscosity adjustability and compatibility with the application techniques are important factors.

Coated phosphors.

Some phosphor materials may have all desired optical properties, but may be incompatible with the most appropriate solvent for dispersing and applying the phosphor to the SSL-LED chip. Then, it may be necessary to develop techniques for coating, by chemical vapor deposition (CVD) or other thin-film techniques, the phosphor microcrystals with wide-bandgap, water-resistant coatings such as refractory oxides (Al2O3, Y2O3, La2O3). These coatings may have the additional benefit of passivating the surfaces of the individual phosphor grains and improving overall quantum efficiency.

#### Nanocrystalline phosphors.

To minimize optical scattering, it may be beneficial to develop very small phosphor particles. The key size scale is the wavelength of light, below which Mie scattering decreases significantly. This may require new synthesis techniques, both for wet chemical processes and for high temperature solid-state processes. In wet chemical processes, such as colloidal, reverse micelle and spray drying techniques, the particles are precipitated or synthesized from solution, and their sizes and the size distribution can be controlled by nucleation kinetics and passivation of the surfaces. In a solid-state process, the particle sizes are governed by the time-temperaturetransformation sequence associated with the firing process.

Integration with encapsulants.

It may be possible to mix phosphors directly into the epoxy resins (or other transparent thermosetting plastic resins) or sol gels used to create the package dome. If the encapsulant is index-matched to the phosphor, then optical scatter will be low. In addition, the phosphor can then be set apart from the chip, reducing its temperature, and the light source can be less point-like, and more distributed (a possible safety advantage).

# **3.1.3 Encapsulants**

The encapsulant is the clear material that lies between the light emitting die/phosphor and the external environment. Typical encapsulants include acrylics, epoxies and silicones. The encapsulant serves both as a key component in the optical design of the LED and as the final seal between the die/phosphor and the external environment. As an optical element of the LED the encapsulant should have high index of refraction and good stability in presence of high intensity light, humidity and high temperature. As a final "seal" between the chip+phosphor combination, and the external environment the encapsulant must protect the chip and phosphor from the mechanical handling and possibly other environmental conditions. Diffusion of water is a particular issue unless higher-cost hermetic packages are used.

The wall-plug efficiency for the LED is very sensitive to the index of refraction of the encapsulant. The nearer the index of refraction of the encapsulant is to that of the LED substrate material the higher the WPE for the LED. This can be best understood by noting that the LED die by necessity has some self-absorption. The largest contributors to this absorption are absorption in the doped semiconductor, absorption of the metal contacts and absorption in the active region. For LEDs grown on sapphire the encapsulant should be as near to the ~1.7 index of sapphire as possible. For LEDs grown on SiC encapsulant index must be even higher to match the ~2.2 index of SiC.

For LEDs that use near UV ( $\sim$ 370nm) light to pump phosphors this light can be damaging to the human eye. For this reason then, the encapsulant may have the additional optical requirement that the near UV light be absorbed in the encapsulant and not escape into environment. If the phosphor is integrated with the encapsulant, then there will be the opposite optical requirement that near UV light not be absorbed in the encapsulant.

Clarity of the encapsulant is critical and should be maintained at >80% through a  $\sim$ 5mm thick section under the extremes of operating temperature, humidity and blue/near-UV light intensity.

The whole area of encapsulants is complicated because of the extreme range of wavelengths that may or may not be present in single and multi- chip LEDs. These wavelengths can range from the UV (370 nm) to the red (630 nm). The encapsulant of choice has to survive the effects of wavelength as well as high temperature without degradation.

Current LED encapsulants show degradation due to exposure by both UV and blue light, particularly at high intensities, high humidity and at high temperatures. Epoxy and other thermosetting materials are the most common encapsulants used in LEDs today. These materials degrade rapidly under blue light, high humidity and high temperature and limit the useful life of common indicator LEDs to less than a few thousand hours at maximum rated current.

<u>Recommendation</u>: Develop encapsulants for high-power lamps that are: water clear with index >1.6; have >80% transmission through 3mm thick layer from 440nm to 650nm after exposure to 150C and low ppm H2O for 50,000hrs; are able to block wavelengths shorter than 440nm (for the wavelength-conversion approach); and with mechanical properties consistent with low cost manufacture and use.

Impact=WC+CM+Hy; Risk=H; Reward=H.

#### Possible Approaches:

#### Novel heat-resistant materials.

It may be necessary to develop completely new encapsulant materials. For example, bisphenol glycidyl ethers, formed from epoxy monomers and appropriate cure accelerators, are possible encapsulant materials. These materials are fairly heat resistant because of their high glass transition temperature around 130C. However, these components absorb UV light, oxidize and ultimately assume a yellowish hue as a result of production of carbonyl groups. Hydrogenation may help.

#### <u>Novel</u> additives.

Various additives may be necessary to optimize particular properties of the encapsulants. For example, encapsulants with high glass-transition temperatures may also have slow reaction kinetics, and may require improved cure accelerators. Also, encapsulants prone to discoloration due to blue or UV exposure may require discolorationsuppresing anti-oxidants.

#### Thermally managed encapsulants.

The combination of heat and light is especially deadly to encapsulants, accelerating discoloration and mechanical embrittlement. Hence, it may be necessary to manage heat not only through the die-attach interface side of the lamp, but on the phosphor and encapsulant side of the lamp.

#### UV-filtering encapsulants.

For the UV wavelength conversion approach to white light production, it may be necessary for the encapsulant to absorb the residual primary UV light not absorbed by the phosphors, so that no UV leaks out of the lamp. However, the encapsulant must not degrade or discolor as a result of the UV absorption. It may also be possible to apply a thin UV-absorbing/visible-transmitting coating to the outer surface of the encapsulant. This coating would need to be well-CTE-matched to the encapsulant.

# **3.2 Lamps and Electronics**

In this Section, we discuss challenges associated with lamp packaging itself. These lamp packages will have an enormous impact on the efficiency, life and cost of solidstate lighting. They will be more diverse than the chips on which they are based, as they must span the various approaches to white light production, and the various permutations in the chips that are used. Lamps that involve wavelength conversion of light from a single chip may look very different from those that involve color mixing of light from multiple chips.

All lamps, though, must share five common characteristics.

The first is cost. The lamp packaging, normalized to the amount of chip area that is used, must be less than roughly  $75-50/\text{cm}^2$ .

The second is efficient thermal management, due to the need to drive the light-engine chip at high input power densities (400 W/cm<sup>2</sup> by Year 2012). Thermal management will be especially important for multiple color LED illumination strategies as the temperature sensitivities of GaN-based and AlInGaP-based LEDs are significantly different. This may require electronics inside the package to dynamically adjust the ratio of Blue, Red and Green to maintain a constant white point.

The third is efficient optical engineering for wavelength conversion and color mixing that results in: low package re-absorption losses; and uniform color in the angular cone of directed light, independent of chip operating temperature up to 175C.

The fourth is electronic compensation for color drift with time, input power, and ambient temperature.

The fifth is reliability and disposability. The lamp must last 100,000 hours. And, it must be constructed of non-toxic materials that can be disposed of without harming the environment.

# 3.2.1 Power Lamps

The initial step in lamp packaging is to mount the LED light chip "engine" in the package. There are five key issues associated with this mounting.

The first issue is cost. If our Year 2012 target on chip cost is \$75-50/cm<sup>2</sup>, then package cost must be comparable.

The second issue is good electrical and heat conduction into and out of the chip. Our Year 2012 targets for lumens per lamp are 1klm/lamp, and for luminous efficacy are 150lm/W. Hence, it will be necessary to develop lamps that support drive powers of (1klm/lamp)/(150lm/W), or about 7W/lamp. If there is some inefficiency in the lamp driver, and if the driver is integrated into the lamp, then the input power to the lamp could be 30% higher still – 10W/lamp. At the same time, the amount of waste heat that will be generated will be (1klm)/(400lm/W -150lm/W), or about 4W/lamp. Although this is not a lot of heat, it must be dissipated in the lamp over a small chip area of 1klm / (400W/cm<sup>2</sup> x 150lm/W), or 0.017 cm<sup>2</sup>.

We can use the Year 2012 targets to calculate roughly the thermal resistance that the lamp must provide to the chip. As discussed in Sections 2.3 and 3.1, it will be important to increase the operating temperatures of chips and phosphors as much as possible. However, it is likely that the efficiency of the chip will drop significantly at temperatures much above 200C. Also, we can assume that the ambient temperature that the lamp presents to the chip will be less than roughly 75C, due to thermal and thermal stress limitations on the materials from which the lamp is constructed, particularly where it mates to the luminaire. Hence, the die-to-luminaire thermal resistance must be less than (200C-75C)/4W, or about 30C/W. This thermal resistance is comparable to that of current high-power LED packaging, and there is probably room for decreases to the 10-20C/W range, albeit likely at greater cost.

The third issue is thermal stresses, and reliability. The lamp must last 100,000 hours of continuous operation, as well as many tens of thousands of control (turn-on, turnoff, dimming) cycles. Minimizing thermal stress will require improved thermal management, so that temperature gradients within the lamp, and particularly at the interface between the lamp and the chip, are minimized. It will also require development and implementation of lamp materials whose thermal expansion coefficients are well-matched to those of GaAs or Ge (for red LEDs) or of GaN, sapphire or SiC (for green, blue and UV LEDs).

The fourth issue is that the packaging must accommodate both conducting substrate as well as non-conducting substrate light-engine chips.

The fifth issue is that the packaging must be compatible with UV and visible light. It must not degrade under this exposure, and, in order to maintain high efficiency, must absorb very little of the light that it is exposed to.

<u>Recommendation</u>: Develop low-cost ( $\leq 90$ \$/cm<sup>2</sup> of chip area used) substrate packaging approaches with die-to-lamp thermal resistance of  $\leq 25$ C/W, and that accommodate total input powers  $\geq 10$ W.

Impact=WC+CM+Hy; Risk=H; Reward=H.

# Possible Approaches.

Chip-up vs. Chip-down mounting.

There are two general possibilities, illustrated in Figure 22 for the actual mounting of the chip in the lamp.

The first is chip-up mounting, in which the active lightemitting epilayers of the chip face up, and the substrate is attached to the lamp. In this approach current can be





Figure 22. Chip-up and chip-down geometries. After D. A. Steigerwald, J. C. Bhat, D. Collins, R. M. Fletcher, M. O. Holcomb, M. J. Ludowise, P. S. Martin, and S. L. Rudaz, "Illumination With Solid State Lighting Technology," IEEE Journal of Selected Topics in Quantum Electronics 8 (2002) 310-320.

driven into the lamp from a bottom substrate contact, and out of the lamp from a top epilayer contact. Hence this approach is most appropriate for conducting-substrate chips, though it can also be applied to non-conductingsubstrate chips.

The second is chip-down mounting, or flip-chip mounting, in which the active light-emitting epilayers of the chip face down. In this approach, current can be driven into and out of the lamp from two epilayer contacts. Hence, this approach is most appropriate for nonconducting-substrate chips, though it can also be applied to conducting-substrate chips. The highest power lamps currently on the market, by LumiLeds, make use of flipchipping to create a 5W package that produces 180 lumens of white light from a single lamp.

Both of these approaches have advantages and disadvantages.

On the one hand, the chip-down approach enables superior heat-sinking of the light-emitting epilayer. This may also enable the phosphor and encapsulant materials to remain cooler, since they are placed on the substrate side. A factor 2x higher input power densities have been reported using flip-chipping. It also minimizes the current spreading required in the p-type contact and epilayers. Instead, most of the current spreading occurs in n-type epilayers. However, as chip size increases, in both approaches interdigitated contacts may be necessary. And, it enables improved light extraction, since light can escape more easily from the higher-aspect-ratio substrate side of the chip.

On the other hand, the chip-up approach has fewer processing steps, and is less expensive to manufacture.

This fundamental design decision will also depend on the evolution of the chip technology (e.g., if chips end up with conducting or non-conducting substrates) as well as on the evolution of fixture requirements.

#### New package architectures.

Current LED packages were originally designed for lower-power indicator-light applications, and cost pennies to produce. These packages are based on "cube type" LEDs with lengths and widths of 8-12 mils and thicknesses of 8-10 mils. They are also designed for conductingsubstrate LEDs such as AlGaInP/GaAs, with one wirebonded top ohmic contact, and one conductive epoxy bottom ohmic contact.

These packages, including the famous T-1 3/4 (5 mm) lamp, are inadequate for the power densities and optical efficiencies necessary for high power LED lamps. For example, it is estimated that the T-1 3/4 LED lamp has an optical efficiency of <30% with conducting substrate style LEDs and this efficiency is even less with new style InGaN/Al2O3 LEDs that are generally 13 mil square with heights running <5 mils in thickness. SMT device packages are generally known to have optical efficiencies even less than this (<20%). It is clear that the overall geometry and architecture of the lamp must undergo considerable evolution and improvement.

New materials for mounting and heat sinking.

It may be necessary to develop new materials for dieattach (epoxies and solders) and heat sinking that absorb very little UV or visible light, and that do not degrade even at 175C over 100,000 hours. These materials must help minimize thermal expansion mismatch between chip and package. If they are used for heat sinking they must have very high thermal conductivities (e.g., diamond or diamond-like carbon).

Lastly, these materials must be environmentally friendly

(e.g., solders must be lead-free). Since indium-based lead-free solders have low melting temperatures (~120C), it may be necessary to use solder alloys like Sn-Ag and Sn-Cu (Tm~220C), provided their processing temperatures are not too high. The lead-free solder recommended by the National Electronics Manufacturing Initiative (NEMI), e.g., is Sn3.9Ag0.6Cu. Underfills must be also be developed that withstand 175C and UV light.

# Direct chip on board.

The packaging approach has advantages and disadvantages that need to be explored. Advantages of this approach include reduced thermal impedance because the chip is directly placed on the board, removing the package level impedance. It also reduces overall cost by removing a portion of the packaging costs. As die efficiencies and thermal efficiencies improve this packaging approach allows for greater packaging density or lumens/cm<sup>2</sup>. Disadvantages of this approach include that it, like any multi-chip module approach, requires known good bare die to achieve reasonable yields. With the current price of LED lumens this is very important but may become less of an issue later as prices come down. Another disadvantage is the thermal-expansion mismatch between typical inexpensive epoxy resin based and metal core PCBs. This may drive the cost up due to the need for a lower CTE material based on ceramics.

# Low-attachment-stress wire bonding.

Low-stress wire bonding for attaching wires directly on top of active device material. Possibly useful also for edgeemitting laser diodes and vertical-cavity surface-emitting laser diodes (VCSELs).

# 3.2.2 Color-Mixing and Wavelength Conversion

The packaged lamp must provide the optics associated with color mixing, wavelength conversion, and general high-efficiency extraction of light from the lamp. There are four issues.

The first issue is efficiency. In all three approaches to white-light production, we are targeting >90% efficiencies associated with the package – including the optics as well as parasitic package losses. The package efficiency of the current generation of white (blue + phosphor-converted yellow) LEDs has been estimated to be only 50% or less, so there is considerable room for improvement.

The second issue is constancy of the mixing with respect to angle and temperature. This is less of an issue with the wavelength-conversion approach, but is a major issue with the color mixing and hybrid approaches. In the hybrid approach, for example, color non-uniformity occurs because the light from the blue LED is directional while the light from the phosphor radiates over a  $2\pi$  solid angle. Also, since chip and phosphor efficiency may change with temperature, the ratio of the colors that are being blended will also change with temperature.

The third is cost. Normalized per cm<sup>2</sup> of chip area used in the package, it must be less than \$90/cm<sup>2</sup>. Normalized per lumen of light output, it must be less than \$0.40/klm.

The fourth issue is performance over time and long-term reliability. The optics used must not themselves degrade under the expected operating temperatures (150C) and optical fluxes.

<u>Recommendation</u>: Optics for color-mixed, wavelengthconversion, or hybrid lamps with CCT and CRI variation < 10%, over large viewing angles and temperature ranges (175C), with parasitic optical losses <10%, at costs < 0.40\$/klm, and over lifetimes >100,000 hrs.

Impact=CM; Risk=M; Reward=H.

Possible Approaches:

# Modeling Tools.

# Transmission vs. Reflective Approaches.

There are two general approaches to lamp design: transmission and reflective. In both approaches light is emitted by a primary light-source chip (or chips), and is transmitted or partially transmitted through a phosphor blend.

In the transmission approach, the re-emitted and partially transmitted light emerges from the lamp from the phosphor side. In the reflective approach, a mirror is placed over the phosphor, so that the light makes a second pass through the phosphor before emerging from the lamp from the chip side.

Both approaches have advantages and disadvantages. In the transmission approach, which is the one currently used, light is not forced to interact with the chip and mount twice, and the resulting absorption losses can be less. In the reflective approach, light can make a double pass through the phosphor, so the phosphor itself can either be a less efficient absorber, or it can be thinner.

# Integration with sensors.

It may be desirable (and possibly necessary) to control the intensity and color of the light output from the lamp, in response either to external needs or to internal lamp drift. Then, it may also be necessary to integrate sensors into the lamp.

#### Encapsulant-based optics.

If the optical functionality can be combined with the encapsulant functionality, then cost could be reduced. However, this will require precision shaping of the encapsulant.

Compact light randomizers.

One approach may be to co-inject light into cavities in which light makes many bounces before escaping. In this way, light from the various different-colored chips may be randomized, and emerge with the same angular intensity distributions.

Optics that compensate for light-scattering phosphors.

# **3.2.3 Drive Electronics**

Drive electronics supply the lamp with the electrical power required to power the light-engine chips. In principle, these electronics can either be integrated into the luminaire along with the lamp, or they can be separate from the luminaire.

In the early stages of solid-state lighting, both approaches are likely to be explored. However, in the later stages, it is more likely that the electronics, as it has with fluorescent lighting, will, to maximize placement flexibility and to minimize cost, be integrated into the luminaire. It could even, at some point, be integrated into the lamp along with the light-engine chip, but as this involves a fairly complex integration of high-temperature electronics with optoelectronics, we don't consider it here.

There are four main issues associated with the drive electronics.

The first issue is voltage transformation. Semiconductor technologies are low-DC-voltage technologies. Hence, just as Si-based computer chips, they are inherently incompatible with traditional high-AC-voltage (110V and 220V) power systems.

It is possible that, at some point, the ubiquitousness of semiconductor technologies, including electronics and lighting will drive the development of new low-voltage electrical distribution standards for buildings. And, it is possible to design lighting systems that use the low-voltage real-time or time-delayed output of solar cells. However, neither of these is considered likely to be adopted on a massive scale in the next 10-20 years, hence we assume here that it is necessary to transform traditional high-AC voltages into low-DC voltages.

This transformation is somewhat easier than that necessary for fluorescent lamps (viz., from high-AC voltages into very-high-AC voltages). And, the electronics can be somewhat similar to those developed for other semiconductor technologies, such as computers.

Related to this voltage transformation is the possibility of a "back reaction" of large concentrations of nonlinear devices on the quality and safety of electric power in the utility infrastructure (including harmonic content, excessive neutral current, transformer and conductor heating, voltage stressing, etc.).

The second issue is lifetime and cost. Drive circuits for consumer electronics do not need to be in the 100,000 hour range, because the lifetime of the application itself is normally not that long. Hence it will be necessary to develop drive circuits with lifetimes and reliabilities more in the range of those used for high-end high-performance 24/7 electronics applications (e.g., servers and communications systems). A target lifetime 50% longer than that of the lamp would guarantee that the drive electronics are not a factor in system lifetime, so here we target a value of 150,000 hours.

At the same time, the costs must be compatible with those for consumer lighting systems. If our Year 2012 lighting targets are 150 lm/W for luminous efficacy and 5/klm, then the target lighting cost per delivered Watt to must be 0.75/W = (0.005/lm)x(150lm/W). Assuming the power supply can at most be 30% of this cost, we end up with a Year 2012 target for the drive electronics of 0.25/W.

The third issue is programmability. Because solid-state lighting has the unique ability to maintain its luminous efficacy even at very low lumens out, it is likely that dimmability will be an important feature to exploit. Moreover, in the color-mixing and hybrid approaches to white-light production, it may be possible to alter the color type and quality of the lamp by tailoring the currents that drive various chips mounted in the lamp.

We note that on the one hand this programmability is a new feature associated with solid-state lighting. On the other hand, for the color-mixing approach to white light production, it may be a necessary feature, if the intensity and color of lamps drift over time and need to be compensated for, as illustrated in Figure 23. It may also be necessary in order to compensate for spread in lumen output and wavelength of manufactured LEDs. Because the consistency and reproducibility of traditional lighting is so high, it is likely to be similarly demanded of solid-state lighting. Manufacturing tolerances may become much tighter for LEDs, but, if not, programmable drive electronics will be necessary.



Figure 23. The calculated shift in (u,v) chromaticity coordinates of a color-mixed tri-color LED as the temperature is changed in increments of 20C. The RGB-LED has a color temperature of 3500K at a junction temperature of 60C, but color temperatures of 3000K and 4000K at junction temperatures of 0C and 120C. After S. Muthu, F. J. P. Schuurmans, and M. D. Pashley, "Red, Green, and Blue Leds for White Light Illumination," IEEE Journal of Selected Topics in Quantum Electronics 8 (2002) 333-338.

We also note that this programmability will require drive electronics with multiple outputs, where the average voltage or current at each output can be varied in response to system-level needs.

The fourth issue is efficiency. Because wall-plug efficiency is one of the primary motivations for solid-state lighting, it will be necessary to develop drive electronics that are themselves very efficient. Our target is 95% efficiency (85% is already commercially available). This high efficiency will be challenging, particularly as it must be achieved while maintaining high "quality" (e.g., small reactive impedances, and low RF generation), and in a compact form factor consistent with the compactness of the lamp itself. One vision is for the drive electronics to be miniaturized to the point of enabling the power converter to be an integral part of the fixture or ultimately of the chip itself.

<u>Recommendation</u>: Power supplies and drive electronics that transform 100 VAC to 2-5 VDC with >95% efficiency, good quality factor, that have long (150,000 hour) lifetimes, and that can be externally programmed to alter color type and quality, and lamp intensity.

Impact=WC+CM+Hy; Risk=L; Reward=M.

Possible Approaches:

	Incandescent	Fluorescent	SSL-LED
Visible Light	0.10	0.19	0.4
IR Light	0.72	0.31	0.3
Conduction/	0.18	0.36	0.3
Convection			

Table 5. Approximate fractional energy dissipated into various channels for traditional and solid-state lighting technologies. Values for incandescent and fluorescent lighting are from the 1987 IESNA Handbook (courtesy of N. Narendran); values for solid-state lighting are estimated assuming Year 2012 target for efficiency, and assuming a 70C heat sink, 25C ambient, a 5W device in 25cm3 volume (calculation courtesy of P. Martin).

#### Switching power supplies.

Variable pulse-amplitude or pulse-width drive circuits.

The most straightforward approach to dimming or color altering would be to vary the voltage or current that drives one or more of the light-engine chips in a lamp. However, in order for power supplies to maintain high efficiency over a wide average drive current range, it may be necessary to fix the voltage and current, but modulate it in time.

Monolithic drive electronics.

Drive electronics that are integrated with the lamp would ultimately be the most cost-effective. This may require chip-on-board, or integrated GaN/Si semiconductor, technologies.

# **3.3 Luminaires**

In this Section, we discuss challenges associated with the luminaire. This is the fixture that houses the lamp, that ultimately directs light from the lamp onto the work-space, and that the end-user primarily sees and interacts with.

Just as lamp packages are likely to be more diverse than the light-engine chips at their heart, so luminaires are likely to be more diverse even than lamp packages. Not only must they span the various permutations in the lamps; they must also span the various end-uses of white light, all the way from direct task lighting to indirect diffuse lighting.

All luminaires, though, must share five common features.

The first is efficient thermal management. Unlike fluorescent lamps, solid-state lamps will be small and, even though efficient, concentrated sources of waste heat. And, unlike incandescent lamps, solid-state lamps will not dissipate their heat primarily through IR radiation, but, as indicated in Table 5, through a combination of IR radiation and conduction/convection.

The second is efficient optical engineering for directing and focusing light from the lamp. This is an area in which there is much to be gained. In contrast to fluorescent and incandescent lamps, solid-state lamps are directional, nearly-point sources. Hence, for directed-light uses, it should be possible to make more-efficient use of light. Instead, the challenge will be, for indirect-light uses, to disperse the light uniformly.

The third is reliability. If chip and lamp lifetimes are 100,000 hours, luminaire lifetimes must also be equally long.

The fourth is cost. The luminaire fixturing, normalized to the amount of chip area that is used, must not be more than roughly \$180/cm<sup>2</sup>. If we use as a rough guide a 30%:30%:40% break-out across chip:packaging:fixturing, then normalized to the lumens that are output, it must not be more than roughly 40% of \$5/klm, or \$2/klm. For our Year 2012 target lamp, which puts out 1 klm, this means the luminaire must be no more than roughly \$2. However, it should be emphasized that the break-out for solid-state lighting may be very different from 30%:30%:40%.

The final issue is safety. The heat sinks will be at high enough temperatures (>75C) that they should not be easily contacted by people.

# **3.3.1 Power Luminaires**

Although solid-state lighting is expected to be very efficient, it will not be 100% efficient, and waste heat will be generated.

Unlike in fluorescent lamps, where the waste heat is distributed over very large surface-area glass envelopes, in solid-state lighting the waste heat is concentrated in very small lamp volumes. And, unlike in incandescent lamps, where much of the waste heat is infrared light which radiates out into the environment, in solid-state lighting the waste heat must at least partially, and perhaps largely, be conducted from the lamp into the luminaire and finally into the environment.

As a consequence, getting rid of waste heat may be more difficult in luminaires designed for solid-state lighting than those designed for traditional incandescent and fluorescent lighting.

Using our Year 2012 targets, we can calculate the amount of waste heat that must be dissipated per lamp to be (1klm) / (400lm/W - 150lm/W), or 4W. Although this is not a lot of heat, it must be dissipated in the lamp over a small chip area of 1klm / (400W/cm<sup>2</sup> x 150lm/W), or 0.017 cm<sup>2</sup>, and ultimately in the luminaire over a lamp surface areas larger by perhaps 1 order of magnitude, or 0.17 cm<sup>2</sup>.

We can also use our Year 2012 targets to calculate roughly the thermal resistance that the luminaire must provide the lamp. Assuming that the luminaire is much larger than the lamp, and assembled from much less expensive materials, it is not likely to be able to withstand temperatures much above 75C. Then, assuming that the lamp temperature is limited to our target of 175C, the thermal resistance must be less than (175C-75C)/4W, or about 25C/W.

Note that it is critical to meet this thermal resistance target. The power-conversion efficiencies of both the lightengine chip and the wavelength-conversion phosphors decrease with temperature. Developing chips and phosphors that are efficient up to 150-175C will already be very challenging; developing chips and phosphors that are efficient to much higher temperatures would be nearly impossible.

Indeed, if the luminaire can present an even lower thermal resistance to the lamp, it may be possible to relax the chip and phosphor operating temperature targets of 150-175C.

<u>Recommendation</u>: Luminaire materials and designs that present a thermal impedance to the lamp less than 25C/W, and that themselves can be passively cooled through convection from the environment.

Impact=WC+CM+Hy; Risk=L; Reward=M.

#### Possible Approaches.

#### Multi-lamp luminaires.

It may prove impossible to sink the heat associated with single high-power (1klm) lamps. Instead, it may be necessary to design luminaires with multiple lower-power lamps, spaced and arranged to optimize thermal management.

#### <u>Heat sinks.</u>

It may be necessary to mount lamps directly on heat sinks. The heat sink in turn must passively dissipate the heat efficiently to the outside of the luminaire.

#### Location selection.

It is also likely that, just as with traditional lighting, the ability of luminaires to dissipate heat will depend on installation location. If the location supports internal venting, then more heat can be transported convectively; otherwise, more of the heat would need to be transported conductively.

#### Compact luminaires.

For many applications, compact luminaires that are unobtrusive will be desirable. For example, table or desk lighting often requires the luminaire to be placed near the



Figure 24. LumiLeds Luxeon Ring fixture, designed by Philips Lighting and LumiLeds. Twelve Luxeon light sources are used to produce about 2.4klm of white light, roughly that given off by one 150W incandescent lamp. Courtesy of D.A. Steigerwald (LumiLeds Lighting).

work space, without blocking the view of humans sitting around the table. An example is illustrated in Figure 24.

# **3.3.2 Optics for Directing and Diffusing**

Perhaps the most critical aspect of the luminaire is how it distributes light from the lamp into the workspace, according to the application. It is this aspect that will most distinguish luminaires for solid-state lighting from those used in traditional lighting.

Because solid-state lighting lamps are essentially point sources of light, the optics required to collimate, focus and direct are relatively straightforward, and are ideally suited to directed "task-lighting" applications. Indeed, for such applications, solid-state lighting is expected to have a roughly 2x advantage over traditional lighting in the efficiency with which the task area is selectively illuminated [Note from JYT to Chips: reference for this?]

However, because solid-state lighting lamps are point sources of light, it is also necessary to use optics to create the uniform and homogeneous light output necessary for indirect large-area lighting applications. Note, though that these optics can be simpler than those used to convert intermediate-size sources of light.<sup>91</sup> In addition, there are safety considerations, as the lumen output of single lamps is so bright that it could be harmful for humans to look directly at the lamp.

In the early stages of solid-state lighting, luminaire optics will be even more complex, as much of the color-mixing may be done at the luminaire level, and the lack of single lamps with the necessary lumens out will require working with multiple lamps. In the later stages, however, the optics are expected to simplify, as color-mixing and white light production moves to the lamp level, and as single lamps achieve the lumens necessary for single luminaires.

It is likely that there will be a range of luminaire types tailored for the range of end-use applications. However, it is also expected that every human-oriented illumination need will eventually be servable by some solid-statelighting-based luminaire.

<u>Recommendation</u>: Develop efficient (>90%), low-cost, low-aberration plastic optics for homogenizing, diffusing and safely directing light from point-source single and multiple lamps.

Impact=WC+CM+Hy; Risk=L; Reward=H.

# Possible Approaches.

Miniature optics for thin, compact luminaires.

The inherent directionality of light from solid-state lighting lamps may enable ultra miniature optics and very thin, very compact luminaires. These thin, compact luminaires, in turn, will use less raw material, and will be environmentally friendlier as well as less expensive. Combined with the inherent impact and severeenvironment resistance of solid-state lighting, this should enable luminaires to be mounted in a wider range of locations. This will broaden considerably the possibilities for architectural lighting.

# Modeling tools.

Particularly for multiple-lamp luminaires, it will be helpful to develop optical modeling tools. These tools will enable more rapid optimization of designs for uniform and homogeneous distribution of light. It may be necessary for these tools to track vector radiation fields, if polarizationdependent reflection and transmission are important, as it is with guided-wave optics.

Reflective, refractive and guided-wave optics.

<sup>&</sup>lt;sup>91</sup> P. Kan, L. Whitehead, S. J. Pojar, and K. G. Kneipp, "Structure for Efficiently Coupling Large Light Sources Into Prism Light Guides," Journal of the Illuminating Engineering Society 29 (2000) 78.

There are a number of possibilities for luminaire optics. Refractive and reflective optics are the most common for luminaires for traditional incandescent and fluorescent lamps. However, guided-wave optics have some advantages for luminaires for solid-state lighting, due to their ability to diffuse light in thin form factors. Combinations of these types of optics may also be necessary, for example, the use of refractive or reflective optics to focus light into a guided-wave or prism-sheet panel which diffuses and gradually leaks light out into the work-space.

Note that guide-wave optical solutions, such as prism light guides, are especially attractive because of their low maintenance costs, thin form factors, wide variety of sizes and shapes, and uniform light distributions. However, there is the possibility of significant coupling and absorption losses.<sup>92</sup>

Low-cost, manufacturing-tolerant optics.

The materials that luminaire optics are manufactured from are ideally low-cost and highly transparent. Photopolymerizable or injection-molded plastics are both possibilities. Also, the designs should be tolerant of small fabrication errors and tolerances.

# **3.3.3 Luminaire Reliability and Disposal**

The materials from which luminaires are constructed are a final critical area. There are two key issues:

The first is related to luminaire reliability. Our Year 2012 target for lamp lifetime is 100,000 hours. The luminaire should last at least that long. A 50% margin would guarantee that luminaire lifetime is not an issue. That means all luminaire materials, mechanical, optical and electrical, and their interconnections, must have 150,000-hour lifetimes.

The materials that are of special concern are: polymers and plastics, which can discolor with age and with exposure to intense light; solder materials and joints, which can crack over time; and connector systems, which can corrode, particularly in severe-use environments.

The second is related to the life cycle of the luminaire, especially its end-of-life disposal. For traditional mercurycontaining fluorescent lamps, disposal costs are significant. We did not account for these disposal costs in the cost-ofownership analysis in Section 0.3; doing so would only make fluorescent lamp technology less attractive. For solid-state lighting, one important challenge will be to ensure that there are no similar end-of-life disposal costs. This means the use of non-toxic materials (e.g., lead-free solders) throughout the chip, lamp and luminaire. It also means assessing disposal issues related to materials that are mildly toxic, such as the GaAs substrates currently used in AlGaInP-based red LEDs. We note that in this example, it would not be difficult to switch to non-toxic Ge substrates, if necessary.

<u>Recommendation</u>: Luminaires constructed of materials with lifetimes greater than 150,000 hrs, and without environmental disposal concerns.

Impact=WC+CM+Hy; Risk=M; Reward=M.

Possible Approaches:

Long-life Plastics.

Lead-free Solders.

Some examples are: Sn-Ag, Sn-Cu, Sn-Bi and Au-Sn alloys. However, the suitability of their mechanical, adhesion, and wettability properties for solid-state lighting is not yet established.

Corrosion-free wires and connectors.

# **3.4 Lighting Systems**

In this Section, we discuss challenges associated with lighting systems. The light-engine chip, the lamp, and the luminaire, are clearly the technology enablers of the lighting system. However, the other pieces of the lighting system are also critically important, with their own unique challenges:

- Delivering low-voltage high-current electricity in a world dominated by high-voltage low-current sockets.
- Integrating solid-state lighting into building architectures, and the complex and delicate interplay between function and form.
- Understanding the ways in which solid-state lighting interacts with the human visual system to increase comfort and human productivity.
- Adding intelligence to continuously alter the lighting to optimize the balance between energy conservation and human factors.

Throughout these challenges, a common theme is to imagine and implement new (and sometimes radically new)

<sup>&</sup>lt;sup>92</sup> P. Kan, L. A. Whitehead, A. Kotlicki, S. J. Harrison, and C. S. Mcintyre, "High Efficiency Quad Luminaire Prism Light Guide," Journal of the Illuminating Engineering Society 29 (2000) 24.

ways of lighting, rather than to simply build in "backward compatibility" with traditional lighting.

It is new features, not just energy efficiency, that are likely to spur: first, adoption of solid-state lighting into new buildings; and second, conversion of traditional lighting in existing buildings. It is even possible, as has occurred in the past with other semiconductor-based technologies, that new features drive an accelerated turnover in lighting systems even before the actual lamps or luminaires burn out. If so, the lighting market could grow at a rate significantly faster than the historical 3%/year associated with traditional lighting.

Also, it is new features that may enable perhaps the most important spin-off benefit of solid-state lighting: enhanced human productivity. We note that even a 0.1% improvement in human productivity would, in a U.S. economy with a gross domestic product of about \$1T/year?, would represent a benefit of \$10B/year!

And, finally, it is new features and their acceptance by consumers, that will provide necessary guidance to the evolution of the core light-engine chip, lamp and luminaire technologies.

We emphasize that lighting systems is a huge area encompassing a wide variety of disciplines, and encompassing everything beyond the photon creation device, including photon placement, integration into the environment, and interaction with humans. Hence, our thinking about lighting systems is relatively immature. Basic concepts often taken for granted, such as the color rendering index (CRI) or even the definition of the lumen<sup>93</sup> may need to be rethought with respect to solid-state lighting. Nevertheless, lighting systems are the ultimate vehicle for implementing solid-state lighting, so we have tried to take a first look, however imprecise and incomplete, at their issues here.

# **3.4.1 Human Factors and Productivity**

The connection between lighting, the human visual system and, ultimately, human comfort and productivity, has long been complex and controversial.<sup>94</sup> As noted in Section 0.3, even the most basic concept of color rendering quality is not yet well defined.

The connection is all the more critical for solid-state lighting, with its ability to selectively and perhaps programmably fill the visible spectrum through primary light from chips and secondary light from phosphors.

[JYT to Jim George: Needs to be fleshed out...]

<u>Recommendation</u>: Quantify visual and non-visual effects on humans of lighting as producible by solid-state lighting.

Impact=WC+CM+Hy; Risk=H; Reward=H.

#### Possible Approaches.

#### Color quality.

As mentioned above and in Section 0.3, metrics for color quality are not yet well established. The correlated color temperature is a well-established metric for the "type" of white. However, the color-rendering index is a not-wellestablished and controversial metric for color rendering quality.

Hence, it will be important to develop an improved color rendering metric suitable for solid-state lighting. These studies need to be done without regard to the capabilities of currently available lighting -- man was not made for lighting, lighting was made for man!

#### Dynamic lighting.

Solid-state lighting may allow the light system to change color and/or intensity to suit the population of a room or area as well as the mood or activity level of the population.<sup>95</sup> The human factors associated with such changes are in need of further study.

#### Human health and productivity.

Even a small percentage increase in human productivity would be a huge benefit – one that could swamp even the major benefits that derive from energy efficiency alone. Combining the two – increased energy efficiency and human productivity – may also be possible.<sup>96</sup> For example, the human day-night biorhythm is regulated by melatonin, which in turn is based on stimulus by light of various wavelengths. It has been found that shorter wavelengths (470-525nm) have a stronger effect on melatonin regulation

<sup>&</sup>lt;sup>93</sup> Particularly for night-time tasks such as driving. See, e.g., http://www.iaeel.org/IAEEL/NEWL/1995/tval1995/Hum Fa\_2\_95.html.

<sup>&</sup>lt;sup>94</sup> S. L. Mccoll and J. A. Veitch, "Full-Spectrum Fluorescent Lighting: a Review of Its Effects on Physiology and Health," Psychological Medicine 31 (2001) 949-964.

<sup>&</sup>lt;sup>95</sup> Kevin Dowling, "Lighting Systems: Control and Human Factors," OIDA Solid-State Lighting Workshop (Albuquerque, May 30, 2002).

<sup>&</sup>lt;sup>96</sup> J. A. Veitch and G. R. Newsham, "Lighting Quality and Energy-Efficiency Effects on Task Performance, Mood, Health, Satisfaction, and Comfort," Journal of the Illuminating Engineering Society 27 (1998) 107-&.

than longer wavelengths (595-660nm).<sup>97</sup> Hence, it may be possible to control the human day-night biorhythm, as well as create other psychophysical effects, through tailoring of lighting color and sequencing.

#### Animal health and productivity.

There has also been recent interest in improving the visual environment of animals (chickens) to modify mating and other behaviors. It has been found that preferences for different visual environments depends significantly on age, with more mature fowl having a preference for lower light intensities for certain activities.<sup>98</sup>

#### Application-specific lighting optimization.

#### Visual stress and safety.

Because SSL-LED lamps are intense, nearly point sources of light, issues of both safety as well as visual stress will be important. Visual stress can lead, as shown by A.J. Wilkins, to attacks in light-sensitive epileptics and migraine headache sufferers, and can cause a quantitative sensation of discomfort in healthy individuals. Other terms that are sometimes used to characterize visual stress are "glare," "discomfort," and "pleasantness". These kinds of visual stress may also depend on the spatial arrangement, in addition to the absolute intensity, of light sources.

#### Direct vs. indirect lighting

The ratio of direct (task) and indirect (diffuse) lighting is thought to be a significant factor in human comfort and productivity. For single-source lighting the ratio is usually determined by luminaire design. For multiple-source lighting and multiple luminaires there is more flexibility, and it is common in an office building for there to be both overhead ceiling lights as well as directed task lighting. However, the ratio between the two is still set either by the building architecture or by the number and type of installed luminaires. Solid-state lighting would take this flexibility one step further, enabling the ratio of ceiling and directed task lighting to be set by the user at the time of use, rather than at the time of building design.

# Intensity-dependent color.

It has been suggested that the most pleasing color of a light source depends on the level of illumination.<sup>99</sup>

Understanding this phenomena quantitatively will be very interesting, since this independent programmability of intensity and color is a unique feature of solid-state lighting.

# **3.4.2 Aesthetic, Intelligent Buildings**

One of the most fascinating aspects of solid-state lighting technology is sure to be the development of building and lighting architectures that, at a system level, exploit the unique characteristics of solid state lighting while still appealing at a consumer level to human ergonomics. Many of these efforts are already ongoing (e.g., the RPI Lighting Research Center, Lawrence Berkeley National Laboratory's Lighting Systems Research Group, and other efforts connected to the U.S. Department of Energy's Office of Building Technology, State and Community Programs).

Some of these unique features are related to the physical form factors (compactness) and environmental compatibility (rugged and vibration resistant) of SSL-LEDs. These physical characteristics will enable SSL-LEDs to be integrated more readily with building architectures and architectural materials.

Some of these unique features are related to the programmability of SSL-LEDs – including dimmability while maintaining high luminous efficacy, and color tailoring.

Especially in buildings in which lighting is a mix between artificial and natural (daylight) sources, programmable (dimmable) lighting can save significant amounts of energy.<sup>100</sup> Note that the most obvious means of programmability – to turn lights off automatically when a room is vacant, are not unique to solid-state lighting. However, solid-state lighting adds a new dimension to programmability – modifying lights according to the use of a room.

Indeed, for traditional lighting, there is a trade-off between programmability and energy efficiency. For an incandescent lamp, e.g., dimming the bulb lowers the filament temperature, which means more of the blackbody spectrum occurs in the invisible infrared. Hence, changing intensity or color quality often results in a decrease in energy efficiency, and compromises must be made. Highefficiency, high-intensity discharge lamps are even more difficult to dim, due to their need for carefully stabilized

<sup>&</sup>lt;sup>97</sup> H. R. Wright and L. C. Lack, "Effect of light wavelength on suppression and phase delay of the melatonin rhythm," Chronobiology International 18 (2001) 801-808.

<sup>&</sup>lt;sup>98</sup> N. J. Davis, N. B. Prescott, C. J. Savory, and C. M. Wathes, "Preferences of Growing Fowls for Different Light Intensities in Relation to Age, Strain and Behaviour," Animal

Welfare 8 (1999) 193-203. <sup>99</sup> A.A. Kruithof, "Tubular luminescence lamps for general illumination," Philips Tech. Rev. 6(3):65-73 (1941).

<sup>&</sup>lt;sup>100</sup> D. H. W. Li and J. C. Lam, "Evaluation of Lighting Performance in Office Buildings With Daylighting Controls," Energy and Buildings 33 (2001) 793-803.

discharge currents, prompting the development of external and cumbersome large-area modulators.<sup>101</sup>

For solid-state lighting, these compromises may not need to be made – human comfort and productivity through programmable lighting can be optimized more independently of energy efficiency.

The common theme is to make use of both the "hardware" and "software" aspects of SSL-LEDs to create a new generation of more aesthetic and more energy-efficient buildings and homes.

<u>Recommendation:</u> Novel concepts in building architectures that exploit unique characteristics of SSL-LEDs to simultaneously optimize energy efficiency, human comfort and productivity.

Impact=WC+CM+Hy; Risk=M; Reward=H.

Possible Approaches.

Intelligent networked lights.

# Integration with sensors.

The opportunity to have lighting systems that modulate their intensity to supplement natural light, and according to the need for illumination would add a further dimension to the value of solid-state lighting. Such systems will require the integration of solid-state lighting control systems with sensors.

For each kind of "control", different sensors will be required. Occupancy-linked systems will need occupancy sensors (infra-red, ultrasonic, acoustic or microwave) which detect either movement or noise. Daylight-linked systems will need photocells for both ambient and task areas.

Integration with environmental systems (HVAC).

Integration with building security systems.

Intelligent lighting solutions for human factors engineering.

Integration with architectural materials.

Integration with office information systems.

# Low-profile ceiling integration

Furthermore, the low profile of tile-- shaped LED light sources could call into question the need for drop ceilings that currently hide fluorescent lighting fixtures. Although not the only elements overhead, lighting fixtures may be the critical ones. So consider that in a multistory building, replacing overhead fixtures and their associated drop ceilings could add up. Space savings may be equivalent to an additional story.

Even now, LEDs are enabling the development of lighting designs that were previously impractical. A striking example of such LED lighting illuminates the text frieze that encircles the interior of the Jefferson Memorial in Washington, D.C. (Fig. 1). In this application, a series of 17,000 surface mount LEDs are assembled on 17-in. linear strips, mounted on a high ledge just below the frieze. The entire 250-ft. long fixture mixes white and yellow LED strips to produce a hue of light that nicely matches the marble wall. Before the LED lighting was installed, the frieze remained unlit because the ledge holding the LED strips was too shallow to sit a conventional light fixture on.

<sup>&</sup>lt;sup>101</sup> H. Fujikake, Y. Tanaka, S. Kimura, H. Asakawa, T. Tamura, H. Kita, K. Takeuchi, H. Ogawa, A. Nagashima, Y. Utsumi, and K. Takizawa, "Heat-Resistant Liquid Crystal Light Modulator Containing Polymer Network for High-Power Luminaires," Japanese Journal of Applied Physics Part 1 39 (2000) 5870-5874.

# **A APPENDIX: ROADMAPPING PROCESS AND RESOURCES**

This Roadmap was put together in several stages.

2002 Feb. To initiate the Roadmap, OIDA (Arpad Bergh), in consultation with DOE (Jim Brodrick) and NEMA (Kyle Pitsor) identified a facilitator (Jeff Tsao, Sandia) and a technical steering committee (George Craford, LumiLeds, Michael Coltrin, Sandia, Steve DenBaars, UC Santa Barbara, and Jim George, Permalight. Then, OIDA, the facilitator and the steering committee identified the scope of the Roadmap update and the invited speakers for the workshop.

2002 Mar-May. Based on a number of primary references identified by OIDA, the facilitator, the steering committee and the invited speakers, the facilitator created a first-draft Roadmap, including introductory material and a comprehensive set of technical targets, challenges and possible approaches. These primary references are listed in Section 0.

2002 May 30. A technical workshop was held in Albuquerque, NM. The workshop brought together experts from Universities, National Laboratories and Industry. These experts heard invited talks in various technical challenge areas; and in breakout sessions debated and fleshed out the targets, challenges, and possible approaches outlined in the first-draft Roadmap. They also binned the individual challenges by risk and reward, and identified reviewers for them.

2002 Jun-Jul. Based on comments from the May 30 workshop, the facilitator created a more-comprehensive second-draft Roadmap, including a revised set of technical targets, challenges and possible approaches. Explanatory background text was also added. This second-draft Roadmap was sent (in stages) to the steering committee and to the reviewers identified at the workshop.

2002 Jul-Aug. Based on final comments from the steering committee and from the individual challenge reviewers, the facilitator created a third-and-final-draft Roadmap. Figures and references were also added.

2002 Aug. Finally, the Roadmap was separated into two parts: a Roadmap Update 2002, which summarizes the Targets, Decision Points, Challenges and Possible Approaches; and a Roadmap Tutorial, which provides more detail on the Targets, as well as introductory material to the various Challenge Areas.

# **A-1 Primary References**

The primary references used in constructing the firstdraft Roadmap are listed here. We do not include secondary references to specific technical research, as these are listed in footnotes to the text of the Roadmap.

- 1. A survey of the solid-state-lighting journal and patent literature over the period 2001 mid-Oct through 2002 early-Feb. The survey was done by Perspectives, a firm that specializes in technical and market intelligence, on behalf of Sandia National Laboratories. The survey can be viewed at <u>http://lighting.sandia.gov</u> under Issue 11 of the Science, Technology, Business and Headline News section.
- The Year 2000 Review of Japan's "Light for the 21st Century" Project, translated by K.V. Sereda and J.Y. Tsao, 2002 Mar 29, available from the Optoelectronics Industry Development Association (www.oida.org).
- 3. Last year's DOE/OIDA solid-state lighting Roadmap, "Light Emitting Diodes for General Illumination", edited by E.D. Jones, March, 2001, available from the Optoelectronics Industry Development Association (www.oida.org). The executive summaries of this and the organic LED available roadmap are at http://lighting.sandia.gov in the Vision and Overview section.
- 4. A white paper first presented at a Washington, D.C. OIDA Forum in October, 1999, by R. Haitz, F. Kish, J.Y. Tsao and J. Nelson, "The Case for a National Research Program on Semiconductor Lighting," available from the Optoelectronics Industry Development Association (www.oida.org) and at <a href="http://lighting.sandia.gov">http://lighting.sandia.gov</a> in the National Initiatives section.
- A review article by J.W. Orton and C.T. Foxon, "Group III Nitride Semiconductors for Short Wavelength Light-Emitting Devices," Reports on Progress in Physics 61 (1998) 1.
- 6. A review article by A. Bergh, G. Craford, A. Duggal and R. Haitz, "The Promise and

Challenge of Solid-State Lighting," Physics Today **54** (December, 2001) 42-47.

- A special issue of IEEE Journal of Selected Topics in Quantum Electronics on High-Efficiency Light-Emitting Diodes Volume 8, Issue 2 (March-April 2002), edited by M.R. Krames, H. Amano, J.J. Brown and P.L. Heremans.
- 8. A viewgraph tutorial put together in 2000 by E.F. Schubert on "Light Emitting Diodes," available at <u>www.lightemittingdiodes.org</u>.
- A review volume edited by G.B. Stringfellow and M.G. Craford "High Brightness Light Emitting Diodes," Semiconductors and Semimetals Volume 48, R.K. Willardson and E.R. Weber, Series Editors (Academic Press, San Diego, 1997).
- 10. M.S. Rea, Ed., "The IESNA Lighting Handbook," 9<sup>th</sup> Edition (Illuminating Engineering Society of North America, New York, 2000).
- A new book by A. Zukauskas, M. S. Shur and R. Caska, "Introduction to Solid-state Lighting" (John Wiley & Sons, 2002).

# A-2 Workshop Agenda

# LED Workshop

#### Wyndham Albuquerque Hotel • Albuquerque, NM May 30, 2002

- 7:30 Registration & Continental breakfast
- 8:00 Welcome and Introductions Arpad Bergh, OIDA
- 8:10 National Security Implications of SSL Al Romig, Sandia National Laboratory
- 8:30 Materials and Device Research: Steve DenBaars, UCSB
- 8:40 Make the Photon Then Get It Out: Strategies for Efficient Semiconductor Light Emitters – Arto Nurmikko, Brown University
- 9:00 Efficient Light Emitters Based on Photonic Crystals and Metallic Extraction Gratings – Axel Scherer, CALTECH
- 9:20 Alternative Substrates for Growth of III-Nitride-based Light-emitting Device Structures with Reduced Densities of Defects and/or Cost – *Robert Davis, NC State University*
- 9:40 Physics of Optical Response in Group-III Nitride Active Structures Weng Chom, Sandia National Laboratory
- 10:00 Issues in GaN Growth Chemistry and Reactor Design Thomas Kuech, University of Wisconsin
- 10:20 Status of GaN LEDs and Lasers for Solid-State Lighting & Displays *Shuji* Nakamura, UCSB
- 10:40 Break
- 11:00 Lighting Systems: James F. George, Permalight Products
- 11:10 Chips Chipalkatti, OSRAM
- 11:30 Solid State Lighting: Systems/ Applications Issues Nadarajah Narendran, Rensselaer Polytechnic Institute
- 11:50 Kevin Dowling, Color Kinetics
- 12:10 Lunch Speaker: Jonathan Epstein, Legislative Fellow, US Senate
- 1:10 Wavelength Conversion Materials Alok Srivastava, GELcore
- 1:30 Paul Martin, LumiLeds Lighting
- 1:50 Program Priorities & Breakout Objectives: George Craford, LumiLeds
- 2:00 Break out sessions & Break
  - Substrates, Buffers & Epitaxy Bob Davis / Tom Kuech
  - Physics, Processing & Devices Steve DenBaar / Bernd Keller
  - Packaging & White Light Production George Craford / Paul Martin
  - Lighting Fixtures & Systems Jim George / Chips Chipalkatti
- 5:00 Break
- 5:30 Breakout reports, Conclusions and Recommendations (15 min. per group)
- 6:30 *Reception*

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2.3.1 Red LEDs	Mike Krames
2.3.2 Green, Blue and UV	Shuji Nakamura, Bernd
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2.3.3 Monolithic White LEDs	Ed Stokes
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2.4.1 Resonant-Cavity and	Steve Denbaars, Arto
Super-Luminescent LEDs	Nurmikko
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2.4.3 VCSELs	Steve Denbaars, Arto
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3 Lamps, Luminaires and	George Craford, Jim
Systems	George
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3.4 Lighting Systems	Jim George
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	Narendran
3.4.2 Aesthetic, Intelligent	Kevin Dowling, Chips
Buildings	Chipalkatti
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